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PSP 103.1

The PSP model is a joint development of Arizona State University and NXP Semiconductors Research

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Unclassified Report

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Title: PSP 103.1

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Abstract: The PSP model is a compact MOSFET model intended for digital, analogue, and RF-

design, which is jointly developed by NXP Semiconductors (formerly part of Philips) and Arizona State University (formerly at The Pennsylvania State University). The roots of PSP lie in both MOS Model 11 (developed by Philips Research) and SP (developed by Penn State University). PSP is a surface-potential based MOS Model, containing all relevant physical effects (mobility reduction, velocity saturation, DIBL, gate current, lateral doping gradient effects, STI stress, etc.) to model present-day and upcoming deepsubmicron bulk CMOS technologies. A source/drain junction model, c.q. the JUNCAP2 model, is an integrated part of PSP. This report contains a full description of the PSP model, including parameter sets, scaling rules, model equations, and a description of the

parameter extraction procedure.

In December 2005, the Compact Model Council (CMC) has elected PSP as the new industrial standard model for compact MOSFET modeling.

Conclusions:

History of model and documentation

History of the model

April 2005 Release of PSP 100.0 (which includes JUNCAP2 200.0) as part of SiMKit 2.1. A Verilog-A implementation of the PSP-model is made available as well. The PSP-NQS model is released as Verilog-A code only.

August 2005 Release of PSP 100.1 (which includes JUNCAP2 200.1) as part of SiMKit 2.2. Similar to the previous version, a Verilog-A implementation of the PSP-model is made available as well and the PSP-NQS model is released as Verilog-A code only. Focus of this release was mainly on the optimization of the evaluation speed of PSP. Moreover, the PSP implementation has been extended with operating point output (SiMKit-version only).

March 2006 Release of PSP 101.0 (which includes JUNCAP2 200.1) as part of SiMKit 2.3. PSP 101.0 is *not* backward compatible with PSP 100.1. Similar to the previous version, a Verilog-A implementation of the PSP-model is made available as well and the PSP-NQS model is released as Verilog-A code only. Focus of this release was on the implementation of requirements for CMC standardization, especially those which could not preserve backward compatibility.

June 2006 Release of PSP 102.0 (which includes JUNCAP2 200.1) as part of SiMKit 2.3.2. PSP 102.0 is backward compatible with PSP 101.0 in all practical cases, provided a simple transformation to the parameter set is applied (see description below). Similar to the previous version, a Verilog-A implementation of the PSP-model is made available as well and the PSP-NQS model is released as Verilog-A code only.

Global parameter sets for PSP 101.0 can be transformed to PSP 102.0 by replacing **DPHIBL** (in 102.0 parameter set) by **DPHIBO** · **DPHIBL** (from 101.0 parameter set). After this transformation, the simulation results of PSP 102.0 are identical to those of PSP 101.0 in all practical situations.

October 2006 Release of PSP 102.1 (which includes JUNCAP2 200.2) as part of SiMKit 2.4. PSP 102.1 is backward compatible with PSP 102.0. SiMKit 2.4 includes a preliminary implementation of the PSP-NQS model. Similar to the previous version, a Verilog-A implementation of the PSP-model is available as well.

October 2007 Release of PSP 102.2 (which includes JUNCAP2 200.3). PSP 102.2 is backward compatible with PSP 102.1. This release provides an express version of JUNCAP2.

April 2008 Release of PSP 102.3 (which includes JUNCAP2 200.3) as part of SiMKit 3.1. PSP 102.3 is backward compatible with PSP 102.2. Focus of this release is on the implementation of asymmetric models for both junction and overlap regions of the drain side.

November 2008 Release of PSP 103.0 (which includes JUNCAP 200.3) as part of SiMKit 3.2. PSP 103.0 is *not* fully backward compatible with PSP 102.3. The main changes are:

- Global, local and binning models are unified. When **SWGEO** = 1 (default) global model is used. When **SWGEO** = 0 local model is selected. The binning model is invoked if **SWGEO** is set to 2.
- Added non-uniform doping (NUD) model. The model can be invoked on by setting SWNUD = 1 or 2.
 When SWNUD = 1, a separate surface potential calculation is carried out and the NUD model does not affect the CV results. This avoids non-reciprocal capacitances. When SWNUD = 2, the extra surface potential calculation is skipped and this may result in non-reciprocal capacitances.
 Added related model parameters GFACNUDO, GFACNUDL, GFACNUDLEXP, GFACNUDW, GFACNUDLW, VSBNUDO and DVSBNUDO to global, GFACNUD, VSBNUD and DVSBNUD to local and POGFACNUD,

PLGFACNUD, PWGFACNUD, PLWGFACNUD, POVSBNUD and PODVSBNUD to binning models.

- Added $V_{\rm th}$ -adjustment model for CV. It can be turned on by setting SWDELVTAC = 1. Note that this requires extra computation of surface potentials. Added related model parameters FACNEFFACO, FACNEFFACL, FACNEFFACW, FACNEFFACLW, DELVTACO, DELVTACL, DELVTACLEXP, DELVTACW and DELVTACLW to global, FACNEFFAC and DELVTAC to local and POFACNEFFAC, PLFACNEFFAC, PWFACNEFFAC, PLWFACNEFFAC, PODELVTAC, PLDELVTAC, PWDELVTAC and PLWDELVTAC to binning model.
- Added external diffusion resistances to source and drain. Added instance parameters NRS and NRD;
 added model parameters RSH to global and binning, RSE and RDE to local model.
- Modified the geometrical scaling rules of following parameters: VFB, STVFB, DPHIB, STBET and STTHESAT.
- Modified the binning rule of **BETN**.
- Removed the effect of **FETA** from CV.
- Added local parameter values to OP-output.
- Some minor bug-fixes and implementation changes.

May 2009 Release of PSP 103.1 (which includes JUNCAP 200.3) as part of SiMKit 3.3. The main changes are:

- Added external sheet resistance **RSHD** for drain diffusion (used when **SWJUNASYM** = 1)
- Bug-fix and minor implementation change in NUD-model
- Minor bug fix in conditional for SP-calculation of overlap areas.
- Added noise source labeling (vA-code only)

History of the documentation

April 2005 First release of PSP (PSP 100.0) documentation.

August 2005 Documentation updated for PSP 100.1, errors corrected and new items added.

March 2006 Documentation adapted to PSP 101.0. Added more details on noise-model implementation and a full description of the NQS-model.

June 2006 Documentation adapted to PSP 102.0 and some errors corrected.

October 2006 Documentation adapted to PSP 102.1 and some errors corrected.

October 2007 Documentation adapted to PSP 102.2 and some errors corrected.

April 2008 Documentation adapted to PSP 102.3 and some errors corrected.

November 2008 Documentation adapted to PSP 103.0 and some errors corrected.

June 2009 Documentation adapted to PSP 103.1 and some errors corrected.

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Section 1

Introduction

1.1 Origin and purpose

The PSP model is a compact MOSFET model intended for digital, analogue, and RF-design, which is jointly developed by NXP Semiconductors Research (formerly part of Philips) and Arizona State University (formerly at The Pennsylvania State University). The roots of PSP lie in both *MOS Model 11* (developed by Philips) and *SP* (developed by Penn State University). PSP is a surface-potential based MOS Model, containing all relevant physical effects (mobility reduction, velocity saturation, DIBL, gate current, lateral doping gradient effects, STI stress, etc.) to model present-day and upcoming deep-submicron bulk CMOS technologies. The source/drain junction model, c.q. the JUNCAP2 model, is fully integrated in PSP.

PSP not only gives an accurate description of currents, charges, and their first order derivatives (i.e. transconductance, conductance and capacitances), but also of the higher order derivatives, resulting in an accurate description of electrical distortion behavior. The latter is especially important for analog and RF circuit design. The model furthermore gives an accurate description of the noise behavior of MOSFETs. Finally, PSP has an option for simulation of non-quasi-static (NQS) effects.

The source code of PSP and the most recent version of this documentation are available on the PSP model web site: pspmodel.asu.edu and the NXP Semiconductors web site: www.nxp.com/models.

1.2 Structure of PSP

The PSP model has a hierarchical structure, similar to that of MOS Model 11 and SP. This means that there is a strict separation of the geometry scaling in the global model and the model equations in the local model.

As a consequence, PSP can be used at either one of two levels.

- Global level One uses a global parameter set, which describes a whole geometry range. Combined with instance parameters (such as L and W), a local parameter set is internally generated and further processed at the local level in exactly the same way as a custom-made local parameter set.
- Local level One uses a custom-made local parameter set to simulate a transistor with a specific geometry. Temperature scaling is included at this level.

The set of parameters which occur in the equations for the various electrical quantities is called the *local* parameter set. In PSP, temperature scaling parameters are included in the local parameter set. An overview of the local parameters in PSP is given in Section 2.5.2. Each of these parameters can be determined by purely electrical measurements. As a consequence, a local parameter set gives a complete description of the electrical properties of a device of *one* particular geometry.

Since most of these (local) parameters scale with geometry, all transistors of a particular process can be described by a (larger) set of parameters, called the *global* parameter set. An overview of the global parameters

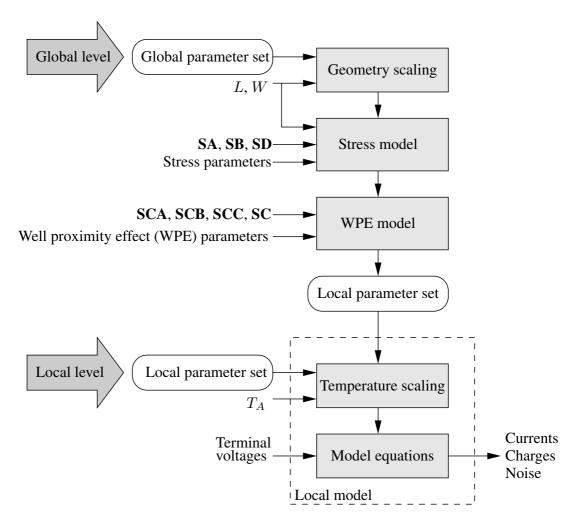


Figure 1.1: Simplified schematic overview of PSP's hierarchical structure.

in PSP is given in Section 2.5.2. Roughly speaking, this set contains all local parameters for a long/wide device plus a number of sensitivity coefficients. From the global parameter set, one can obtain a local parameter set for a specific device by applying a set of scaling rules (see Section 3.2). The geometric properties of that specific device (such as its length and width) enter these scaling rules as *instance parameters*.

From PSP 101.0 onwards it is possible to use a set of binning rules (see Section 3.3) as an alternative to the geometrical (physics based) scaling rules. These binning rules come with their own set of parameters (see Section 2.5.2). Similar to the geometrical scaling rules, the binning rules yield a local parameter set which is used as input for the local model.

PSP is preferably used at global level when designing a circuit in a specific technology for which a global parameter set is available. On the other hand, using PSP at local level can be advantageous during parameter extraction.

As an option, it is possible to deal with the modifications of transistor properties due to stress and well proximity effect (WPE). In PSP, this is implemented by additional sets of transformation rules, which are optionally applied to the intermediate local parameter set generated at the global level. The parameters associated with the stress and WPE models are consequently part of the global parameter set (both geometrical and binning).

The model structure described above is schematically depicted in Fig. 1.1.

The JUNCAP2 model is implemented in such a way that the same set of JUNCAP2 parameters can be used at both the global and the local level. This is further explained in Section 6.4.

1.3 Availability

The PSP model developers (The Arizona State University and NXP Semiconductors Research) distribute the PSP code in two formats:

- 1. Verilog-A code
- 2. C-code (as part of SiMKit-library)

The C-version is automatically generated from the Verilog-A version by the software package ADMS [1]. This procedure guarantees the two implementations to contain identical equations. Nevertheless—due to some specific limitations/capabilities of the two formats—there are a few minor differences, which are described in Section 6.5.

1.3.1 SiMKit

SiMKit is a simulator-independent compact transistor model library. Simulator-specific connections are handled through so-called adapters that provide the correct interfacing to the circuit simulator of choice. Currently, adapters to the following circuit simulators are provided:

- 1. Spectre (Cadence)
- 2. Pstar (NXP Semiconductors)
- 3. ADS (Agilent)

Section 2

Constants and Parameters

2.1 Nomenclature

The nomenclature of the quantities listed in the following sections has been chosen to express their purpose and their relation to other quantities and to preclude ambiguity and inconsistency. Throughout this document, all PSP parameter names are printed in boldface capitals. Parameters which refer to the long transistor limit and/or the reference temperature have a name containing an 'O', while the names of scaling parameters end with the letter 'L' and/or 'W' for length or width scaling, respectively. Parameters for temperature scaling start with 'ST', followed by the name of the parameter to which the temperature scaling applies. Parameters used for the binning model start with 'PO', 'PL', 'PW', or 'PLW', followed by the name of the local parameter they refer to.

2.2 Parameter clipping

For most parameters, a maximum and/or minimum value is given in the tables below. In PSP, all parameters are limited (clipped) to this pre-specified range in order to prevent difficulties in the numerical evaluation of the model, such as division by zero.

N.B. After computation of the scaling rules (either physical or binning), stress and well proximity effect equations, the resulting local parameters are subjected to the clipping values as given in Section 2.5.2.

2.3 Circuit simulator variables

External electrical variables

The definitions of the external electrical variables are illustrated in Fig. 2.1. The relationship between these external variables and the internal variables used in Chapter 4 is given in Fig. 6.1.

Symbol	Unit	Description
$V_{ m D}^e$	V	Potential applied to drain node
$V_{ m G}^e$	V	Potential applied to gate node
$V_{ m S}^e$	V	Potential applied to source node
$V_{ m B}^e$	V	Potential applied to bulk node
$I_{ m D}^e$	A	DC current into drain node

... continued from previous page

Symbol	Unit	Description
$I_{ m G}^e$	A	DC current into gate node
$I_{ m S}^e$	A	DC current into source node
$I_{ m B}^e$	A	DC current into bulk node
S_{fl}^{e}	A^2s	Spectral density of flicker noise current in the channel
S_{id}^e	A^2s	Spectral density of thermal noise current in the channel
$S_{\mathrm{ig,S}}^e$	A^2s	Spectral density of induced gate noise at source side
$S_{ m ig,D}^e$	A^2s	Spectral density of induced gate noise at drain side
$S_{ m igs}^e$	A^2s	Spectral density of gate current shot noise at source side
$S_{ m igd}^e$	A^2s	Spectral density of gate current shot noise at drain side
$S^e_{ m j,S}$	A^2s	Spectral density of source junction shot noise
$S_{ m j,D}^e$	A^2s	Spectral density of drain junction shot noise
S_{igid}^{e}	A^2s	Cross spectral density between S_{id}^e and $(S_{\mathrm{igS}}^e$ or $S_{\mathrm{igD}}^e)$

Other circuit simulator variables

Next to the electrical variables described above, the quantities in the table below are also provided to the model by the circuit simulator.

Symbol Unit		Description
$T_{ m A}$	°C	Ambient circuit temperature
$f_{\rm op}$	Hz	Operation frequency

2.4 Model constants

In the following table the symbolic representation, the value and the description of the various physical constants used in the PSP model are given.

No.	Symbol	Unit	Value	Description
1	T_0	K	273.15	Offset between Celsius and Kelvin temperature scale
2	k_{B}	J/K	$1.3806505 \cdot 10^{-23}$	Boltzmann constant
3	\hbar	J s	$1.05457168 \cdot 10^{-34}$	Reduced Planck constant
4	q	C	$1.6021918 \cdot 10^{-19}$	Elementary unit charge
5	m_0	kg	$9.1093826 \cdot 10^{-31}$	Electron rest mass
6	ϵ_0	F/m	$8.8541878176 \cdot 10^{-12}$	Permittivity of free space
7	$\epsilon_{ m r,Si}$	_	11.8	Relative permittivity of silicon
8	$QM_{ m N}$	$V m^{\frac{4}{3}} C^{-\frac{2}{3}}$	5.951993	Constant of quantum-mechanical behavior of electrons
9	$QM_{ m P}$	$V m^{\frac{4}{3}} C^{-\frac{2}{3}}$	7.448711	Constant of quantum-mechanical behavior of holes

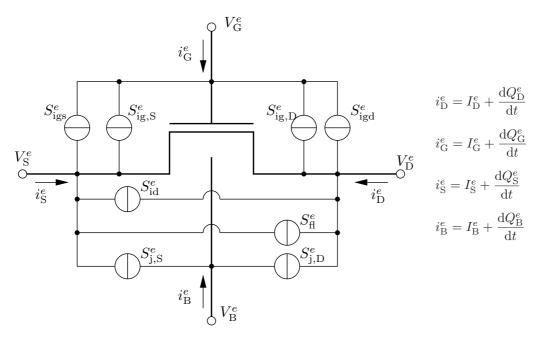


Figure 2.1: Definition of external electrical quantities.

2.5 Model parameters

In this section all parameters of the PSP-model are described. The parameters for the intrinsic MOS model, the stress and well proximity effect models and the junction model are given in separate tables. The complete parameter list for each of the model entry levels is composed of several parts, as indicated in the table below.

Entry level	Sections
Global (geometrical scaling)	2.5.1 (instance parameters)
	2.5.2 (intrinsic MOS)
	2.5.3 (stress)
	2.5.4 (well proximity effect)
	2.5.5 (junctions)
	2.5.6 (parasitic resistances)
Binning	2.5.1 (instance parameters)
	2.5.2 (intrinsic MOS)
	2.5.3 (stress)
	2.5.4 (well proximity effect)
	2.5.5 (junctions)
	2.5.6 (parasitic resistances)
Local	2.5.1 (instance parameters)
	2.5.2 (intrinsic MOS)
	2.5.5 (junctions)
	2.5.6 (parasitic resistances)

2.5.1 Instance parameters

The instant parameters for global, local and binning models are listed in the table below. The last column of **Geo.** shows for which value of **SWGEO** the listed parameter is used. Note that, as explained in Section 6.4, the instance parameters for the JUNCAP2 model are used at the local level as well.

No.	Name	Unit	Default	Min.	Max.	Description	Geo.
0	L	m	10^{-6}	10^{-9}	_	Drawn channel length	1, 2
1	W	m	10^{-6}	10^{-9}	_	Drawn channel width (total width)	1, 2
2	ABSOURCE	m^2	10^{-12}	0	_	Source junction area	0, 1, 2
3	LSSOURCE	m	10^{-6}	0	-	STI-edge part of source junction perimeter	0, 1, 2
4	LGSOURCE	m	10^{-6}	0	_	 Gate-edge part of source junction perimeter 	
5	ABDRAIN	m^2	10^{-12}	0	_	Drain junction area	0, 1, 2
6	LSDRAIN	m	10^{-6}	0	_	STI-edge part of drain junction perimeter	0, 1, 2
7	LGDRAIN	m	10^{-6}	0	_	Gate-edge part of drain junction perimeter	0, 1, 2
8	AS	m^2	10^{-12}	0	_	Source junction area (alternative spec.)	0, 1, 2
9	PS	m	10^{-6}	0	-	Source STI-edge perimeter (alternative spec.)	0, 1, 2
10	AD	m^2	10^{-12}	0	_	Drain junction area (alternative spec.)	0, 1, 2
11	PD	m	10^{-6}	0	_	Drain STI-edge perimeter (alternative spec.)	0, 1, 2
12	\mathbf{JW}	m	$1 \cdot 10^{-6}$	0	_	Junction width	0
13	DELVTO	V	0	_	_	Threshold voltage shift parameter	0, 1, 2
14	FACTUO	_	1	0	_	Zero-field mobility pre-factor	0, 1, 2
15	SA	m	0		-	Distance between OD-edge and poly at source side	1, 2
16	SB	m	0	_	_	Distance between OD-edge and poly at drain side	1, 2
17	SD	m	0	_	_	Distance between neighboring fingers	1, 2
18	SCA	-	0	0	_	Integral of the first distribution function for scattered well dopant	1, 2
19	SCB	-	0	0	_	Integral of the second distribution function for scattered well dopant	
20	SCC	-	0	0	-	- Integral of the third distribution function for scattered well dopant	
21	SC	m	0	_	-	Distance between OD edge and nearest well edge	
22	NRS	-	0	_	-	Number of squares of source diffusion	1, 2
23	NRD	-	0	_	_	Number of squares of drain diffusion	1, 2
24	NGCON	_	1	1	2	Number of gate contacts	1, 2

... continued from previous page

No.	Name	Unit	Default	Min.	Max.	Description	Geo.
25	XGW	m	10^{-7}	-	-	Distance from the gate contact to the channel edge	1, 2
26	NF	_	1	1	_	Number of fingers; internally rounded to the nearest integer	1, 2
27	MULT	-	1	0	_	Number of devices in parallel	0, 1, 2

Note that if both **SA** and **SB** are set to 0 the stress-equations are not computed. If **SCA**, **SCB**, **SCC** and **SC** are all set to 0 the well proximity effect equations are not computed.

The switching parameter **SWJUNCAP** is used to determine the meaning and usage of the junction instance parameters, where **AB** (junction area), **LS** (STI-edge part of junction perimeter), and **LG** (gate-edge part of junction perimeter) are the instance parameters of a single instance (source or drain) of the JUNCAP2 model.

		source			drain	
SWJUNCAP	AB	LS	LG	AB	LS	LG
0	0	0	0	0	0	0
1	ABSOURCE	LSSOURCE	LGSOURCE	ABDRAIN	LSDRAIN	LGDRAIN
2	AS	PS	$W_{ m E}$	AD	PD	$W_{ m E}$
3	AS	$\mathbf{PS} - W_{\mathrm{E}}$	$W_{ m E}$	AD	$\mathbf{PD}-W_{\mathrm{E}}$	$W_{ m E}$

At the local level, the switching parameter **SWJUNCAP** is used to determine the meaning and usage of the junction instance parameters, where **AB** (junction area), **LS** (STI-edge part of junction perimeter), and **LG** (gate-edge part of junction perimeter) are the instance parameters of a single instance (source or drain) of the JUNCAP2 model. Because the transistor width W is not available at the local level, an additional instance parameter **JW** (junction width) is required when **SWJUNCAP** = 2 or 3.

		source			drain	
SWJUNCAP	AB	LS	LG	AB	LS	LG
0	0	0	0	0	0	0
1	ABSOURCE	LSSOURCE	LGSOURCE	ABDRAIN	LSDRAIN	LGDRAIN
2	AS	PS	JW	AD	PD	$\mathbf{J}\mathbf{W}$
3	AS	$\mathbf{PS} - \mathbf{JW}$	JW	AD	PD-JW	$\mathbf{J}\mathbf{W}$

2.5.2 Intrinsic model

The model parameters for the intrinsic part of the MOSFET are listed in the table below. The last column of **Geo.** shows for which value of **SWGEO** the listed parameter is used. The convention used in this table is that, if a scaling rule exists for a local parameter its scaling (global and/or binning) parameters are grouped underneath. Note also some parameters do not have their local counterparts.

No.	Name	Unit	Default	Min.	Max.	Description	Geo.
0	LEVEL	_	103	_	-	Model selection parameter; see Sec. 6.1	0, 1, 2
1	TYPE	_	1	-1	1	Channel type parameter; $1 \leftrightarrow NMOS, -1 \leftrightarrow PMOS^1$	0, 1, 2
2	TR	$^{\circ}\mathrm{C}$	21	-273	_	Reference temperature	0, 1, 2
3	DTA	K	0	_	_	Temperature offset w.r.t. ambient circuit temperature	0, 1, 2
			5	Switche	s		
4	SWGEO	-	1	0	2	Flag for geometrical model (0 \leftrightarrow local, 1 \leftrightarrow global, 2 \leftrightarrow binning)	0, 1, 2
5	SWIGATE	_	0	0	1	Flag for gate current (0 \leftrightarrow "off")	0, 1, 2
6	SWIMPACT	_	0	0	1	Flag for impact ionization current $(0 \leftrightarrow \text{``off''})$	0, 1, 2
7	SWGIDL	_	0	0	1	Flag for GIDL/GISL current (0 \leftrightarrow "off")	0, 1, 2
8	SWJUNCAP	_	0	0	3	Flag for JUNCAP $(0 \leftrightarrow \text{``off''})$	0, 1, 2
9	SWJUNASYM	_	0	_	_	Flag for asymmetric junctions (0	0, 1, 2
10	SWNUD	_	0	0	2	Flag for NUD-effect (0 \leftrightarrow "off")	0, 1, 2
11	SWDELVTAC	_	0	0	1	Flag for separate charge calculation $(0 \leftrightarrow \text{``off''})$	0, 1, 2
12	QMC	_	1	0	-	Quantum-mechanical correction factor	0, 1, 2
			Labels	for binı	ning se	et	
13	LMIN	m	0	_	_	Dummy parameter to label binning set	2
14	LMAX	m	1	_	_	Dummy parameter to label binning set	2
15	WMIN	m	0	_	_	Dummy parameter to label binning set	2
16	WMAX	m	1	_	-	Dummy parameter to label binning set	2
			Proces	ss Parai	neters	:	
17	LVARO	m	0	_	_	Geometry independent difference between actual and programmed poly-silicon gate length	1, 2
18	LVARL	_	0	_	_	Length dependence of ΔL_{PS}	1, 2
19	LVARW	_	0	_	_	Width dependence of ΔL_{PS}	1, 2

 $^{^{1}}$ See Section 6.3.1 for more information on usage of **TYPE** in various simulators.

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21 Y 22 Y 23 Y 24 Y 25 II 26 II 27 Y 28 29 30 31	LAP WVARO WVARL WVARW WOT DLQ DWQ VFB	m m m m	0 0 0 0 0		-	Effective channel length reduction per side due to lateral diffusion of source/drain dopant ions Geometry independent difference between actual and programmed field-oxide opening Length dependence of $\Delta W_{\rm OD}$ Width dependence of $\Delta W_{\rm OD}$ Effective reduction of channel width per side due to lateral diffusion of channel-stop dopant	1, 2 1, 2 1, 2 1, 2 1, 2 1, 2
22	WVARL WVARW WOT DLQ DWQ	- - m	0 0 0	- - -	- - -	between actual and programmed field-oxide opening Length dependence of $\Delta W_{\rm OD}$ Width dependence of $\Delta W_{\rm OD}$ Effective reduction of channel width per side due to lateral	1, 2 1, 2
23 Y 24 Y 25 I 26 I 27 Y 28 29 30 31	WVARW WOT DLQ DWQ	m	0	_ _ _	_ _ _	Width dependence of $\Delta W_{\rm OD}$ Effective reduction of channel width per side due to lateral	1, 2
24 Y 25 I 26 I 27 Y 28 29 30 31	WOT DLQ DWQ	m	0	_	_	Effective reduction of channel width per side due to lateral	
25 I 26 I 27 V 28 29 30 31	DLQ DWQ	m		_	_	width per side due to lateral	1, 2
26 I 27 Y 28 29 30 31	DWQ		0	_		ions	
27 Y 28 29 30 31		m			-	Effective channel length offset for CV	1, 2
28 29 30 31	VFB		0	-	_	Effective channel width offset for CV	1, 2
29 30 31		V	-1	_	_	Flat-band voltage at TR	0
30 31	VFBO	V	-1	_	_	Geometry-independent part	1
31	VFBL	V	0	_	_	Length dependence	1
	VFBW	V	0	_	_	Width dependence	1
	VFBLW	V	0	_	_	Area dependence	1
32	POVFB	V	-1	_	_	Geometry independent part	2
33	PLVFB	V	0	_	_	Length dependence	2
34	PWVFB	V	0	-	_	Width dependence	2
35	PLWVFB	V	0	_	_	Length times width dependence	2
36	STVFB	V/K	$5\cdot 10^{-4}$	_	_	Temperature dependence of VFB	0
37	STVFBO	V/K	$5\cdot 10^{-4}$	_	_	Geometry-independent part	1
38	STVFBL	V/K	0	-	_	Length dependence	1
39	STVFBW	V/K	0	_	_	Width dependence	1
40	STVFBLW	V/K	0	_	_	Area dependence	1
41	POSTVFB	V/K	$5 \cdot 10^{-4}$	_	_	Geometry independent part	2
42	PLSTVFB	V/K	0	_	_	Length dependence	2
43	PWSTVFB	V/K	0	_	_	Width dependence	2
44	PLWSTVFB	V/K	0	_	_	Length times width dependence	2
45	TOX	m	$2 \cdot 10^{-9}$	10^{-10}	_	Gate oxide thickness	0
46	TOXO	m	$2\cdot 10^{-9}$	10^{-10}	_	Gate oxide thickness	1
47	POTOX	m	$2\cdot 10^{-9}$	_	_	Geometry independent part	2
48]	EPSROX	_	3.9	1	_	Relative permittivity of gate dielectric	0
49	EPSROXO		3.9	1		Geometry independent part	1

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No.	Name	Unit	Default	Min.	Max.	Description	Geo.
50	POEPSROX	_	3.9	1	_	Geometry independent part	2
51	NEFF	${\rm m}^{-3}$	$5\cdot 10^{23}$	10^{20}	10^{26}	Substrate doping	0
52	NSUBO	m^{-3}	$3\cdot 10^{23}$	10^{20}	_	Geometry independent substrate doping	1
53	NSUBW	_	0	_	_	Width dependence of substrate doping due to segregation	1
54	WSEG	m	10^{-8}	10^{-10}	_	Characteristic length for segregation of substrate doping	1
55	NPCK	m^{-3}	10^{24}	0	_	Pocket doping level	1
56	NPCKW	-	0	-	-	Width dependence of NPCK due to segregation	1
57	WSEGP	m	10^{-8}	10^{-10}	_	Characteristic length for segregation of pocket doping	1
58	LPCK	m	10^{-8}	10^{-10}	-	Characteristic length for lateral doping profile	1
59	LPCKW	-	0	_	-	Width dependence of LPCK due to segregation	1
60	FOL1	-	0	_	-	First order length dependence of short channel body-effect	1
61	FOL2	-	0	-	_	Second order length dependence of short channel body-effect	1
62	PONEFF	m^{-3}	$5\cdot 10^{23}$	_	_	Geometry independent part	2
63	PLNEFF	m^{-3}	0	_	_	Length dependence	2
64	PWNEFF	m^{-3}	0	_	_	Width dependence	2
65	PLWNEFF	m^{-3}	0	_	_	Length times width dependence	2
66	FACNEFFAC	_	1	0	_	Pre-factor for effective substrate doping in separate charge calculation when SWDELVTAC = 1	0
67	FACNEFFACO	_	1	0	_	Geometry independent part	1
68	FACNEFFACL	_	0	_	_	Length dependence	1
69	FACNEFFACW	_	0	_	_	Width dependence	1
70	FACNEFFACLW	_	0	_	_	Area dependence	1
71	POFACNEFFAC	_	1	_	_	Geometry independent part	2
72	PLFACNEFFAC	_	0	_	_	Length dependence	2
73	PWFACNEFFAC	_	0	_	_	Width dependence	2
74	PLWFACNEFFAC	-	0	_	_	Area dependence	2
75	GFACNUD	-	1	0.01	_	Bodyfactor change due to NUD-effect	0
76	GFACNUDO	_	1	_	_	Geometry independent part	1
77	GFACNUDL	_	0	_	_	Length dependence	1
78	GFACNUDLEXP	_	1	_	_	Exponent for length dependence	1

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No.	Name	Unit	Default	Min.	Max.	Description	Geo.
79	GFACNUDW	_	0	_	_	Width dependence	1
80	GFACNUDLW	-	0	_	_	Area dependence	1
81	POGFACNUD	_	1	_	_	Geometry independent part	2
82	PLGFACNUD	_	0	_	_	Length dependence	2
83	PWGFACNUD	_	0	_	_	Width dependence	2
84	PLWGFACNUD	_	0	_	_	Area dependence	2
85	VSBNUD	V	0	0	_	Lower V_{SB} -value for NUD-effect	0
86	VSBNUDO	V	0	_	_	Geometry independent part	1
87	POVSBNUD	V	0		_	Geometry independent part	2
88	DVSBNUD	V	1	0.1	-	V_{SB} -range for NUD-effect	0
89	DVSBNUDO	V	1	_	-	Geometry independent part	1
90	PODVSBNUD	V	1	_	_	Geometry independent part	2
91	VNSUB	V	0	-	-	Effective doping bias-dependence parameter	0
92	VNSUBO	V	0	_	-	Geometry independent part	1
93	POVNSUB	V	0	_	_	Geometry independent part	2
94	NSLP	V	0.05	10^{-3}	_	Effective doping bias-dependence parameter	0
95	NSLPO	V	0.05	_	_	Geometry independent part	1
96	PONSLP	V	0.05	_	_	Geometry independent part	2
97	DNSUB	V^{-1}	0	0	1	Effective doping bias-dependence parameter	0
98	DNSUBO	V^{-1}	0	_	_	Geometry independent part	1
99	PODNSUB	V^{-1}	0	_	_	Geometry independent part	2
100	DPHIB	V	0	_	_	Offset of $arphi_{ m B}$	0
101	DPHIBO	V	0	_	_	Geometry independent part	1
102	DPHIBL	V	0	_	_	Length dependence	1
103	DPHIBLEXP	_	1	_	_	Exponent for length dependence	1
104	DPHIBW	V	0	_	_	Width dependence	1
105	DPHIBLW	V	0	_	_	Area dependence	1
106	PODPHIB	V	0	_	_	Geometry independent part	2
107	PLDPHIB	V	0	_	_	Length dependence	2
108	PWDPHIB	V	0	_	_	Width dependence	2
109	PLWDPHIB	V	0		_	Length times width dependence	2
110	DELVTAC	V	0	_	_	Offset of $\varphi_{\rm B}$ in separate charge calculation when ${\bf SWDELVTAC}=1$	0

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No.	Name	Unit	Default	Min.	Max.	Description	Geo.
111	DELVTACO	V	0	_	_	Geometry independent part	1
112	DELVTACL	V	0	_	_	Length dependence	1
113	DELVTACLEXP	_	1	_	_	Exponent for length dependence	1
114	DELVTACW	V	0	_	_	Width dependence	1
115	DELVTACLW	V	0	_	_	Area dependence	1
116	PODELVTAC	V	0	_	_	Geometry independent part	2
117	PLDELVTAC	V	0	_	_	Length dependence	2
118	PWDELVTAC	V	0	_	_	Width dependence	2
119	PLWDELVTAC	V	0	_	_	Length times width dependence	2
120	NP	m^{-3}	10^{26}	0	_	Gate poly-silicon doping	0
121	NPO	m^{-3}	10^{26}	_	_	Geometry-independent part	1
122	NPL	-	0	_	_	Length dependence	1
123	PONP	m^{-3}	10^{26}	_	_	Geometry independent part	2
124	PLNP	m^{-3}	0	_	_	Length dependence	2
125	PWNP	m^{-3}	0	_	_	Width dependence	2
126	PLWNP	m^{-3}	0	_	_	Length times width dependence	2
127	CT	_	0	0	_	Interface states factor	0
128	СТО	_	0	_	_	Geometry-independent part	1
129	CTL	_	0	_	_	Length dependence	1
130	CTLEXP	_	1	_	_	Exponent for length dependence	1
131	CTW	_	0	_	_	Width dependence	1
132	CTLW	-	0	_	_	Area dependence	1
133	POCT	_	0	_	_	Geometry independent part	2
134	PLCT	_	0	_	_	Length dependence	2
135	PWCT	_	0	_	_	Width dependence	2
136	PLWCT	-	0	_	_	Length times width dependence	2
137	TOXOV	m	$2\cdot 10^{-9}$	10^{-10}	-	Overlap oxide thickness	0
138	TOXOVO	m	$2\cdot 10^{-9}$	10^{-10}	_	Geometry independent part	1
139	POTOXOV	m	$2\cdot 10^{-9}$	_	_	Geometry independent part	2
140	TOXOVD	m	$2\cdot 10^{-9}$	10-10	_	Overlap oxide thickness for drain side	0
141	TOXOVDO	m	$2\cdot 10^{-9}$	10^{-10}	_	Geometry independent part	1
142	POTOXOVD	m	$2\cdot 10^{-9}$	_		Geometry independent part	2
143	LOV	m	0	0		Overlap length for overlap capacitance	1
144	LOVD	m	0	0	_	Overlap length for gate/drain overlap capacitance	1

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No.	Name	Unit	Default	Min.	Max.	Description	Geo.
145	NOV	m^{-3}	$5\cdot 10^{25}$	10^{20}	10^{27}	Effective doping of overlap region	0
146	NOVO	m^{-3}	$5\cdot 10^{25}$	_	_	Geometry independent part	1
147	PONOV	m^{-3}	$5\cdot 10^{25}$	_	_	Geometry independent part	2
148	PLNOV	m^{-3}	0	_	_	Length dependence	2
149	PWNOV	m^{-3}	0	_	_	Width dependence	2
150	PLWNOV	m^{-3}	0	_	_	Length times width dependence	2
151	NOVD	${\rm m}^{-3}$	$5\cdot 10^{25}$	10^{20}	10^{27}	Effective doping of overlap region for drain side	0
152	NOVDO	m^{-3}	$5\cdot 10^{25}$	_	_	Geometry independent part	1
153	PONOVD	m^{-3}	$5\cdot 10^{25}$	_	_	Geometry independent part	2
154	PLNOVD	m^{-3}	0	_	_	Length dependence	2
155	PWNOVD	m^{-3}	0	_	_	Width dependence	2
156	PLWNOVD	m^{-3}	0	_	_	Length times width dependence	2
			DIBL	. Param	eters		
157	CF	-	0	0	_	DIBL parameter	0
158	CFL	_	0	_	_	Length dependence	1
159	CFLEXP	_	2	_	_	Exponent for length dependence	1
160	CFW	_	0	_	_	Width dependence	1
161	POCF	_	0	_	_	Geometry independent part	2
162	PLCF	_	0	_	_	Length dependence	2
163	PWCF	_	0	_	_	Width dependence	2
164	PLWCF	_	0	_	_	Length times width dependence	2
165	CFB	V^{-1}	0	0	1	Back-bias dependence of CF	0
166	CFBO	V^{-1}	0	_	_	Geometry independent part	1
167	POCFB	V^{-1}	0	_	_	Geometry independent part	2
			Mobili	ty Para	meter	s	
168	BETN	m ² /V/s	$7 \cdot 10^{-2}$	0	-	Product of channel aspect ratio and zero-field mobility at TR	0
169	UO	$m^2/V/s$	$5\cdot 10^{-2}$	_	_	Zero-field mobility at TR	1
170	FBET1	_	0	_	-	Relative mobility decrease due to first lateral profile	1
171	FBET1W	_	0	_	_	Width dependence of FBET1	1
172	LP1	m	10^{-8}	10^{-10}	-	Mobility-related characteristic length of first lateral profile	1
173	LP1W	_	0	_	_	Width dependence of LP1	1
174	FBET2	_	0	_	_	Relative mobility decrease due to second lateral profile	1
175	LP2	m	10^{-8}	10^{-10}	-	Mobility-related characteristic length of second lateral profile	1

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No.	Name	Unit	Default	Min.	Max.	Description	Geo.
176	BETW1	_	0	_	_	First higher-order width scaling coefficient of BETN	1
177	BETW2	-	0	_	_	Second higher-order width scaling coefficient of BETN	1
178	WBET	m	10^{-9}	10^{-10}	_	Characteristic width for width scaling of BETN	1
179	POBETN	$m^2/V/s$	$7\cdot 10^{-2}$	_	_	Geometry independent part	2
180	PLBETN	$m^2/V/s$	0	_	_	Length dependence	2
181	PWBETN	$m^2/V/s$	0	_	_	Width dependence	2
182	PLWBETN	$m^2/V/s$	0	_	_	Length times width dependence	2
183	STBET	-	1	_	_	Temperature dependence of BETN	0
184	STBETO	_	1	_	_	Geometry independent part	1
185	STBETL	_	0	_	_	Length dependence	1
186	STBETW	_	0	_	_	Width dependence	1
187	STBETLW	_	0	_	_	Area dependence	1
188	POSTBET	_	1	_	_	Geometry independent part	2
189	PLSTBET	_	0	_	_	Length dependence	2
190	PWSTBET	_	0	_	_	Width dependence	2
191	PLWSTBET	_	0	_	_	Length times width dependence	2
192	MUE	m/V	0.5	0	_	Mobility reduction coefficient at TR	0
193	MUEO	m/V	0.5	_	_	Geometry independent part	1
194	MUEW	_	0	_	_	Width dependence	1
195	POMUE	m/V	0.5	_	_	Geometry independent part	2
196	PLMUE	m/V	0	_	_	Length dependence	2
197	PWMUE	m/V	0	_	_	Width dependence	2
198	PLWMUE	m/V	0	_	_	Length times width dependence	2
199	STMUE	-	0	_	_	Temperature dependence of MUE	0
200	STMUEO	_	0	_	_	Geometry independent part	1
201	POSTMUE	_	0	_	_	Geometry independent part	2
202	THEMU	_	1.5	0	_	Mobility reduction exponent at TR	0
203	THEMUO	-	1.5	0	_	Geometry independent part	1
204	POTHEMU		1.5			Geometry independent part	2
205	STTHEMU	_	1.5	_	_	Temperature dependence of THEMU	0
206	STTHEMUO	-	1.5	_	_	Geometry independent part	1
207	POSTTHEMU		1.5			Geometry independent part	2

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No.	Name	Unit	Default	Min.	Max.	Description	Geo.
208	CS	-	0	0	_	Coulomb scattering parameter at TR	0
209	CSO	_	0	_	_	Geometry independent part	1
210	CSL	_	0	_	_	Length dependence	1
211	CSLEXP	_	1	_	_	Exponent for length dependence	1
212	CSW	-	0	_	_	Width dependence	1
213	CSLW	_	0	_	_	Area dependence	1
214	POCS	_	0	_	_	Geometry independent part	2
215	PLCS	_	0	_	_	Length dependence	2
216	PWCS	_	0	_	_	Width dependence	2
217	PLWCS	_	0	_	_	Length times width dependence	2
218	STCS	_	0	_	_	Temperature dependence of CS	0
219	STCSO	_	0	_	_	Geometry independent part	1
220	POSTCS	_	0	_	_	Geometry independent part	2
221	XCOR	V^{-1}	0	0	_	Non-universality parameter	0
222	XCORO	V^{-1}	0	_	_	Geometry independent part	1
223	XCORL	_	0	_	_	Length dependence	1
224	XCORW	_	0	_	_	Width dependence	1
225	XCORLW	-	0	_	_	Area dependence	1
226	POXCOR	V^{-1}	0	_	_	Geometry independent part	2
227	PLXCOR	V^{-1}	0	_	_	Length dependence	2
228	PWXCOR	V^{-1}	0	_	_	Width dependence	2
229	PLWXCOR	V^{-1}	0	_	_	Length times width dependence	2
230	STXCOR	_	0	_	_	Temperature dependence of XCOR	0
231	STXCORO	-	0	_	_	Geometry independent part	1
232	POSTXCOR	_	0	_	_	Geometry independent part	2
233	FETA	_	1	0	_	Effective field parameter	0
234	FETAO	_	1	_	_	Geometry independent part	1
235	POFETA	_	1	_	_	Geometry independent part	2
			Series Resi	stance	Param	eters	
236	RS	Ω	30	0	_	Source/drain series resistance at TR	0
237	RSW1	Ω	50	_	_	Source/drain series resistance for a channel width W_{EN}	1
238	RSW2	_	0	_	-	Higher-order width scaling	1
239	PORS	Ω	30	_	_	Geometry independent part	2
240	PLRS	Ω	0	_	_	Length dependence	2

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No.	Name	Unit	Default	Min.	Max.	Description	Geo
241	PWRS	Ω	0	_	_	Width dependence	2
242	PLWRS	Ω	0	_	_	Length times width dependence	2
243	STRS	_	1	_	_	Temperature dependence of RS	0
244	STRSO	_	1	_	_	Geometry dependent part	1
245	POSTRS	-	1	_	_	Geometry independent part	2
246	RSB	V^{-1}	0	-0.5	1	Back-bias dependence of RS	0
247	RSBO	V^{-1}	0	_	_	Geometry independent part	1
248	PORSB	V^{-1}	0	_	_	Geometry independent part	2
249	RSG	V^{-1}	0	-0.5	_	Gate-bias dependence of RS	0
250	RSGO	V^{-1}	0	_	_	Geometry independent part	1
251	PORSG	V^{-1}	0	_	_	Geometry independent part	2
			Velocity Sati	uration	Parar	meters	
252	THESAT	V^{-1}	1	0	_	Velocity saturation parameter at TR	0
253	THESATO	V^{-1}	0	_	_	Geometry independent part	1
254	THESATL	V^{-1}	0.05	_	_	Length dependence	1
255	THESATLEXP	_	1	_	_	Exponent for length dependence	1
256	THESATW	_	0	_	_	Width dependence	1
257	THESATLW	_	0	_	_	Area dependence	1
258	POTHESAT	\mathbf{V}^{-1}	1	_	_	Geometry independent part	2
259	PLTHESAT	V^{-1}	0	_	_	Length dependence	2
260	PWTHESAT	\mathbf{V}^{-1}	0	_	_	Width dependence	2
261	PLWTHESAT	V^{-1}	0	_	_	Length times width dependence	2
262	STTHESAT	_	1	_	_	Temperature dependence of THESAT	0
263	STTHESATO	-	1	_	_	Geometry independent temperature dependence	1
264	STTHESATL	_	0	_	_	Length dependence	1
265	STTHESATW	_	0	_	_	Width dependence	1
266	STTHESATLW	-	0	_	_	Area dependence	1
267	POSTTHESAT	_	1	_	_	Geometry independent part	2
268	PLSTTHESAT	_	0	_	_	Length dependence	2
269	PWSTTHESAT	_	0	_	_	Width dependence	2
270	PLWSTTHESAT	_	0	_	_	Length times width dependence of temperature dependence	2
271	THESATB	V^{-1}	0	-0.5	1	Back-bias dependence of velocity saturation	0

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No.	Name	Unit	Default	Min.	Max.	Description	Geo.
272	THESATBO	V^{-1}	0	_	_	Geometry independent part	1
273	POTHESATB	V^{-1}	0	_	_	Geometry independent part	2
274	PLTHESATB	V^{-1}	0	_	_	Length dependence	2
275	PWTHESATB	V^{-1}	0	_	_	Width dependence	2
276	PLWTHESATB	V^{-1}	0	_	_	Length times width dependence	2
277	THESATG	V^{-1}	0	-0.5	_	Gate-bias dependence of velocity saturation	0
278	THESATGO	V^{-1}	0	_	_	Geometry independent part	1
279	POTHESATG	V^{-1}	0	_	_	Geometry independent part	2
280	PLTHESATG	V^{-1}	0	_	_	Length dependence	2
281	PWTHESATG	V^{-1}	0	_	_	Width dependence	2
282	PLWTHESATG	V^{-1}	0	_	_	Length times width dependence	2
			Saturation	Voltage	Parai	neter	
283	AX	-	3	2	_	Linear/saturation transition factor	0
284	AXO	_	18	_	_	Geometry independent	1
285	AXL	_	0.4	0	_	Length dependence	1
286	POAX	_	3	_	_	Geometry independent part	2
287	PLAX	_	0	_	_	Length dependence	2
288	PWAX	_	0	_	_	Width dependence	2
289	PLWAX	_	0	_	_	Length times width dependence	2
		Channel	Length Mo	dulatio	n (CLI	M) Parameters	
290	ALP	_	0.01	0	_	CLM pre-factor	0
291	ALPL	_	$5\cdot 10^{-4}$	_	_	Length dependence	1
292	ALPLEXP	_	1	_	_	Exponent for length dependence	1
293	ALPW	_	0	_	_	Width dependence	1
294	POALP	_	0.01	_	_	Geometry independent part	2
295	PLALP	_	0	_	_	Length dependence	2
296	PWALP	_	0	_	_	Width dependence	2
297	PLWALP	_	0	_	_	Length times width dependence	2
298	ALP1	V	0	0	_	CLM enhancement factor above threshold	0
299	ALP1L1	V	0	_	_	Length dependence	1
300	ALP1LEXP	_	0.5	_	_	Exponent for length dependence	1
301	ALP1L2	_	0	0	_	Second order length dependence	1
302	ALP1W	-	0	_	_	Width dependence	1
303	POALP1	V	0	_	_	Geometry independent part	2
304	PLALP1	V	0	_	_	Length dependence	2
305	PWALP1	V	0	_	_	Width dependence	2

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No.	Name	Unit	Default	Min.	Max.	Description	Geo.				
306	PLWALP1	V	0	_	_	Length times width dependence	2				
307	ALP2	V^{-1}	0	0	_	CLM enhancement factor below threshold	0				
308	ALP2L1	V	0	_	_	Length dependence	1				
309	ALP2LEXP	_	0.5	_	_	Exponent for length dependence	1				
310	ALP2L2	_	0	0	_	Second order length dependence	1				
311	ALP2W	_	0	_	_	Width dependence	1				
312	POALP2	\mathbf{V}^{-1}	0	_	_	Geometry independent part	2				
313	PLALP2	V^{-1}	0	_	_	Length dependence	2				
314	PWALP2	V^{-1}	0	_	_	Width dependence	2				
315	PLWALP2	V^{-1}	0	_	_	Length times width dependence	2				
316	VP	V	0.05	10^{-10}	_	CLM logarithmic dependence parameter	0				
317	VPO	V	0.05	_	_	Geometry independent part	1				
318	POVP	V	0.05	_	_	Geometry independent part	2				
Impact Ionization (II) Parameters											
319	A1	_	1	0	_	Impact-ionization pre-factor	0				
320	A10	_	1	_	_	Geometry independent part	1				
321	A1L	_	0	_	_	Length dependence	1				
322	A1W	_	0	_	_	Width dependence	1				
323	POA1	_	1	_	_	Geometry independent part	2				
324	PLA1	_	0	_	_	Length dependence	2				
325	PWA1	_	0	_	_	Width dependence	2				
326	PLWA1	_	0	_	_	Length times width dependence	2				
327	A2	V	10	0	_	Impact-ionization exponent at TR	0				
328	A2O	V	10	_	_	Geometry independent part	1				
329	POA2	V	10	_	_	Geometry independent part	2				
330	STA2	V	0	_	_	Temperature dependence of A2	0				
331	STA2O	V	0	_	_	Geometry independent part	1				
332	POSTA2	V	0	_	_	Geometry independent part	2				
333	A3	_	1	0	_	Saturation-voltage dependence of II	0				
334	A3O	_	1	_	_	Geometry independent part	1				
335	A3L	_	0	_	_	Length dependence	1				
336	A3W	_	0	_	_	Width dependence	1				
337	POA3	_	1	_	_	Geometry independent part	2				
	PLA3		0			Length dependence	2				

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No.	Name	Unit	Default	Min.	Max.	Description	Geo.
339	PWA3	_	0	_	_	Width dependence	2
340	PLWA3	_	0	_	_	Length times width dependence	2
341	A4	$V^{-\frac{1}{2}}$	0	0	_	Back-bias dependence of II	0
342	A4O	$V^{-\frac{1}{2}}$	0	_	_	Geometry independent part	1
343	A4L	_	0	_	_	Length dependence	1
344	A4W	_	0	_	_	Width dependence	1
345	POA4	$V^{-\frac{1}{2}}$	0	_	_	Geometry independent part	2
346	PLA4	$V^{-\frac{1}{2}}$	0	_	_	Length dependence	2
347	PWA4	$V^{-\frac{1}{2}}$	0	_	_	Width dependence	2
348	PLWA4	$V^{-\frac{1}{2}}$	0	_	_	Length times width dependence	2
			Gate Cur	rent Pa	ramet	ers	
349	GCO	-	0	-10	10	Gate tunnelling energy adjustment	0
350	GCOO	_	0	_	_	Geometry independent part	1
351	POGCO	_	0	_	_	Geometry independent part	2
352	IGINV	A	0	0	_	Gate channel current pre-factor	0
353	IGINVLW	A	0	_	_	Gate channel current pre-factor for a channel area of $W_{\rm EN} \cdot L_{\rm EN}$	1
354	POIGINV	A	0	_	_	Geometry independent part	2
355	PLIGINV	A	0	_	_	Length dependence	2
356	PWIGINV	A	0	-	_	Width dependence	2
357	PLWIGINV	A	0	_	_	Length times width dependence	2
358	IGOV	A	0	0	_	Gate overlap current pre-factor	0
359	IGOVW	A	0	_	-	Gate overlap current pre-factor for a channel width of $W_{\rm EN}$	1
360	POIGOV	A	0	_	_	Geometry independent part	2
361	PLIGOV	A	0	_	_	Length dependence	2
362	PWIGOV	A	0	_	_	Width dependence	2
363	PLWIGOV	A	0	_	_	Length times width dependence	2
364	IGOVD	A	0	0	-	Gate overlap current pre-factor for drain side	0
365	IGOVDW	A	0	_	-	Gate overlap current pre-factor for a channel width of $W_{\rm EN}$ for drain side	1
366	POIGOVD	A	0	_	_	Geometry independent part	2
367	PLIGOVD	A	0	_	_	Length dependence	2
368	PWIGOVD	A	0	_	_	Width dependence	2
369	PLWIGOVD	A	0	_	_	Length times width dependence	2

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No.	Name	Unit	Default	Min.	Max.	Description	Geo.				
370	STIG	-	2	_	_	Temperature dependence of gate current	0				
371	STIGO	_	2	_	_	Geometry independent part	1				
372	POSTIG	_	2	_	_	Geometry independent part	2				
373	GC2	_	0.375	0	10	Gate current slope factor	0				
374	GC2O	_	0.375	_	_	Geometry independent part	1				
375	POGC2	_	$3.75 \cdot 10^{-1}$	_	_	Geometry independent part	2				
376	GC3	-	0.063	-2	2	Gate current curvature factor	0				
377	GC3O	_	0.063	_	_	Geometry independent part	1				
378	POGC3	_	$6.3\cdot10^{-2}$	_	_	Geometry independent part	2				
379	СНІВ	V	3.1	1	_	Tunnelling barrier height	0				
380	СНІВО	V	3.1	_	_	Geometry independent part	1				
381	POCHIB	V	3.1	_	_	Geometry independent part	2				
Gate-Induced Drain Leakage (GIDL) Parameters											
382	AGIDL	A/V ³	0	0	_	GIDL pre-factor	0				
383	AGIDLW	A/V^3	0	_	_	Width dependence	1				
384	POAGIDL	A/V^3	0	_	_	Geometry independent part	2				
385	PLAGIDL	A/V^3	0	_	_	Length dependence	2				
386	PWAGIDL	A/V^3	0	_	_	Width dependence	2				
387	PLWAGIDL	A/V^3	0	_	_	Length times width dependence	2				
388	AGIDLD	A/V ³	0	0	_	GIDL pre-factor for drain side	0				
389	AGIDLDW	A/V^3	0	_	_	Width dependence	1				
390	POAGIDLD	A/V^3	0	_	_	Geometry independent part	2				
391	PLAGIDLD	A/V^3	0	_	_	Length dependenceof	2				
392	PWAGIDLD	A/V^3	0	_	_	Width dependence of	2				
393	PLWAGIDLD	A/V^3	0	_	_	Length times width dependence	2				
394	BGIDL	V	41	0	_	GIDL probability factor at TR	0				
395	BGIDLO	V	41	_	_	Geometry independent part	1				
396	POBGIDL	V	41	_	_	Geometry independent part	2				
397	BGIDLD	V	41	0	_	GIDL probability factor at TR for drain side	0				
398	BGIDLDO	V	41	_	_	Geometry independent part	1				
399	POBGIDLD	V	41	_	_	Geometry independent part	2				

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No.	Name	Unit	Default	Min.	Max.	Description	Geo.
400	STBGIDL	V/K	0	_	-	Temperature dependence of BGIDL	0
401	STBGIDLO	V/K	0	_	_	Geometry independent part	1
402	POSTBGIDL	V/K	0	_	_	Geometry independent part	2
403	STBGIDLD	V/K	0	_	_	Temperature dependence of BGIDL for drain side	0
404	STBGIDLDO	V/K	0	_	_	Geometry independent part	1
405	POSTBGIDLD	V/K	0	_	_	Geometry independent part	2
406	CGIDL	_	0	_	_	Back-bias dependence of GIDL	0
407	CGIDLO	_	0	_	_	Geometry independent part	1
408	POCGIDL	_	0	_	_	Geometry independent part	2
409	CGIDLD	-	0	_	-	Back-bias dependence of GIDL for drain side	0
410	CGIDLDO	_	0	_	_	Geometry independent part	1
411	POCGIDLD	_	0	_	_	Geometry independent part	2
			Charge M	odel P	arame	ters	
412	COX	F	10^{-14}	0	_	Oxide capacitance for intrinsic channel	0
413	POCOX	F	10^{-14}	_	_	Geometry independent part	2
414	PLCOX	F	0	_	_	Length dependence	2
415	PWCOX	F	0	_	_	Width dependence	2
416	PLWCOX	F	0	_	-	Length times width dependence	2
417	CGOV	F	10^{-15}	0	-	Oxide capacitance for gate–drain/source overlap	0
418	POCGOV	F	10^{-15}	_	_	Geometry independent part	2
419	PLCGOV	F	0	_	_	Length dependence	2
420	PWCGOV	F	0	_	_	Width dependence	2
421	PLWCGOV	F	0	_	_	Length times width dependence	2
422	CGOVD	F	10^{-15}	0	_	Oxide capacitance for gate–drain/source overlap for drain side	0
423	POCGOVD	F	10^{-15}	_	_	Geometry independent part	2
424	PLCGOVD	F	0	_	_	Length dependence	2
425	PWCGOVD	F	0	_	_	Width dependence	2
426	PLWCGOVD	F	0	_	_	Length times width dependence	2
427	CGBOV	F	0	0	-	Oxide capacitance for gate-bulk overlap	0

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No.	Name	Unit	Default	Min.	Max.	Description	Geo.
428	CGBOVL	F	0	-	_	Oxide capacitance for gate-bulk overlap for a channel length of L_{EN}	1
429	POCGBOV	F	0	_	_	Geometry independent part	2
430	PLCGBOV	F	0	_	_	Length dependence	2
431	PWCGBOV	F	0	_	-	Width dependence	2
432	PLWCGBOV	F	0	_	_	Length times width dependence	2
433	CFR	F	0	0	_	Outer fringe capacitance	0
434	CFRW	F	0	-	-	Outer fringe capacitance for a channel width of $W_{\rm EN}$	1
435	POCFR	F	0	_	_	Geometry independent part	2
436	PLCFR	F	0	_	_	Length dependence	2
437	PWCFR	F	0	_	_	Width dependence	2
438	PLWCFR	F	0	_	_	Length times width dependence	2
439	CFRD	F	0	0	_	Outer fringe capacitance for drain side	0
440	CFRDW	F	0	_	_	Outer fringe capacitance for a channel width of $W_{\rm EN}$ for drain side	1
441	POCFRD	F	0	_	_	Geometry independent part	2
442	PLCFRD	F	0	_	_	Length dependence	2
443	PWCFRD	F	0	_	-	Width dependence	2
444	PLWCFRD	F	0	_		Length times width dependence	2
			Noise Mo	odel Pa	ramete	ers	
445	FNT	_	1	0	_	Thermal noise coefficient	0
446	FNTO	_	1	_	_	Geometry independent part	1
447	POFNT	_	1	_	_	Geometry independent part	2
448	NFA	$\mathrm{V}^{-1}/\mathrm{m}^4$	$8\cdot 10^{22}$	0	_	First coefficient of flicker noise	0
449	NFALW	$ m V^{-1}/m^4$	$8\cdot 10^{22}$	_	_	First coefficient of flicker noise for a channel area of $W_{\rm EN} \cdot L_{\rm EN}$	1
450	PONFA	V^{-1}/m^4	$8 \cdot 10^{22}$	_	_	Geometry independent part	2
451	PLNFA	V^{-1}/m^4	0	_	_	Length dependence	2
452	PWNFA	$\mathrm{V}^{-1}/\mathrm{m}^4$	0	_	_	Width dependence	2
453	PLWNFA	V^{-1}/m^4	0		_	Length times width dependence	2
454	NFB	V^{-1}/m^2	$3 \cdot 10^7$	0	_	Second coefficient of flicker noise	0
455	NFBLW	V^{-1}/m^2	$3 \cdot 10^7$	_	_	Second coefficient of flicker noise	1
455						for a channel area of $W_{\rm EN} \cdot L_{\rm EN}$	

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No.	Name	Unit	Default	Min.	Max.	Description	Geo.
457	PLNFB	V^{-1}/m^2	0	_	_	Length dependence	2
458	PWNFB	$ m V^{-1}/m^2$	0	_	_	Width dependence	2
459	PLWNFB	$\mathrm{V}^{-1}/\mathrm{m}^2$	0	_	_	Length times width dependence	2
460	NFC	V^{-1}	0	0	_	Third coefficient of flicker noise	0
461	NFCLW	V^{-1}	0	-	-	Third coefficient of flicker noise for a channel area of $W_{\rm EN} \cdot L_{\rm EN}$	1
462	PONFC	V^{-1}	0	_	_	Geometry independent part	2
463	PLNFC	\mathbf{V}^{-1}	0	_	_	Length dependence	2
464	PWNFC	\mathbf{V}^{-1}	0	_	_	Width dependence	2
465	PLWNFC	V^{-1}	0	_	_	Length times width dependence	2
466	EF	-	1	0	-	Flicker noise frequency exponent	0
467	EFO	_	1	_	_	Geometry independent part	1
468	POEF		1			Geometry independent part	2
469	LINTNOI	m	0	_	_	Length offset for flicker noise	1
470	ALPNOI	_	2	_	_	Exponent for length offset	1

2.5.3 Parameters for stress model

The stress model of BSIM4.4.0 has been adopted in PSP with as little modifications as possible. Parameter names have been copied, but they have been subjected to PSP conventions by replacing every zero by an 'O'. Moreover, the parameters **STK2** and **LODK2** are not available in PSP. Except for these changes, stress parameters determined for BSIM can be directly applied in PSP. Some trivial conversion of parameters BSIM→PSP is still necessary, see [2].

The parameters in this section are part of PSP's global parameter set (both geometrical and binning).

No.	Name	Unit	Default	Min.	Max.	Description	Geo.
0	SAREF	m	10^{-6}	10^{-9}	_	Reference distance between OD edge to Poly from one side	1, 2
1	SBREF	m	10^{-6}	10^{-9}	-	Reference distance between OD edge to Poly from other side	1, 2
2	WLOD	m	0	_	_	Width parameter	1, 2
3	KUO	m	0	-	_	Mobility degradation/enhancement coefficient	1, 2
4	KVSAT	m	0	-1	1	Saturation velocity degradation/enhancement parameter	1, 2
5	TKUO	_	0	_	_	Temperature coefficient of KUO	1, 2
6	LKUO	m ^{LLODKUO}	0	_	_	Length dependence of KUO	1, 2
7	WKUO	mWLODKUO	0	_	_	Width dependence of KUO	1, 2
8	PKUO	$m^{\textbf{LLODKUO} + \textbf{WLODKUO}}$	0	_	_	Cross-term dependence of KUO	1, 2
9	LLODKUO	-	0	0	_	Length parameter for mobility stress effect	1, 2
10	WLODKUO	_	0	0	_	Width parameter for mobility stress effect	1, 2
11	KVTHO	Vm	0	_	_	Threshold shift parameter	1, 2
12	LKVTHO	m ^{LLODVTH}	0	_	_	Length dependence of KVTHO	1, 2
13	WKVTHO	mWLODVTH	0	_	_	Width dependence of KVTHO	1, 2
14	PKVTHO	$m^{\textbf{LLODVTH}+\textbf{WLODVTH}}$	0	-	_	Cross-term dependence of KVTHO	1, 2
15	LLODVTH	_	0	0	_	Length parameter for threshold voltage stress effect	1, 2
16	WLODVTH	_	0	0	-	Width parameter for threshold voltage stress effect	1, 2
17	STETAO	m	0	-	-	ETAO shift factor related to threshold voltage change	1, 2
18	LODETAO	_	1	0	_	ETAO shift modification factor	1, 2

2.5.4 Parameters for well proximity effect model

The WPE model of BSIM4.5.0 has been adopted in PSP with as little modifications as possible. Parameter names have been copied, but they have been subjected to PSP conventions by replacing every zero by an 'O'. Moreover, the parameter **K2WE** is not available in PSP. Except for some trivial conversion of parameters BSIM \rightarrow PSP [2], WPE parameters from BSIM can be used directly in PSP. The WPE parameters have both geometrical and binning rules included as explained in Section 3.6.2. Consequently one of the following parameter sets can be used depending on which scaling rule is selected.

No.	Name	Unit	Default	Min.	Max.	Description	Geo.
0	SCREF	m	$1 \cdot 10^{-6}$	0	_	Distance between OD-edge and well edge of a reference device	1, 2
1	WEB	_	0	_	_	Coefficient for SCB	1, 2
2	WEC	_	0	_	_	Coefficient for SCC	1, 2
3	KVTHOWEO	-	0	_	-	Geometry independent threshold shift parameter	1
4	KVTHOWEL	_	0	_	_	Length dependence	1
5	KVTHOWEW	_	0	_	_	Width dependence	1
6	KVTHOWELW	_	0	_	_	Area dependence	1
7	POKVTHOWE	-	0	_	_	Geometry independent part of threshold shift parameter	2
8	PLKVTHOWE	_	0	_	_	Length dependence	2
9	PWKVTHOWE	_	0	_	_	Width dependence	2
10	PLWKVTHOWE	_	0	_	_	Length times width dependence	2
11	KUOWEO	_	0	_	_	Geometry independent mobility degradation factor	1
12	KUOWEL	_	0	_	_	Length dependence	1
13	KUOWEW	_	0	_	_	Width dependence	1
14	KUOWELW	_	0	_	_	Area dependence	1
15	POKUOWE	-	0	_	_	Geometry independent part of mobility degradation factor	2
16	PLKUOWE	_	0	_	_	Length dependence	2
17	PWKUOWE	_	0	_	_	Width dependence	2
18	PLWKUOWE	_	0	_	_	Length times width dependence	2

2.5.5 Parameters for source-bulk and drain-bulk junction model

The JUNCAP2 parameters are part of both the global and the local parameter sets. The last column of **Asym.** shows for which value of **SWJUNASYM** the listed parameter is enabled: i.e., when **SWJUNASYM** = 0, parameters No. 3-45 are used for both source-bulk and drain-bulk junctions and parameters No. 46-88 are ignored; when **SWJUNASYM** = 1, parameters No. 3-45 are used for source-bulk junction and No. 46-88 are used for drain-bulk junction; parameters No. 0-2 are used in both situations.

Name	Unit	Default	Min.	Max.	Description	Asym.
TRJ	°C	21	T_{\min}	_	Reference temperature	0, 1
SWJUNEXP	-	0	0	1	Flag for JUNCAP2 Express; $0 \leftrightarrow$ full JUNCAP2 model, $1 \leftrightarrow$ Express model	0, 1
IMAX	A	1000	10^{-12}	_	Maximum current up to which forward current behaves exponentially	0, 1
		Capacita	nce Para	meters	S	
CJORBOT	F/m ²	10^{-3}	10^{-12}	_	Zero-bias capacitance per unit-of-area of bottom component for source-bulk junction	0, 1
CJORSTI	F/m	10^{-9}	10^{-18}	_	Zero-bias capacitance per unit-of-length of STI-edge component for source-bulk junction	0, 1
CJORGAT	F/m	10^{-9}	10^{-18}	_	Zero-bias capacitance per unit-of-length of gate-edge component for source-bulk junction	0, 1
VBIRBOT	V	1	$V_{ m bi,low}$	_	Built-in voltage at the reference temperature of bottom component for source-bulk junction	0, 1
VBIRSTI	V	1	$V_{ m bi,low}$	_	Built-in voltage at the reference temperature of STI-edge component for source-bulk junction	0, 1
VBIRGAT	V	1	$V_{ m bi,low}$	_	Built-in voltage at the reference temperature of gate-edge component for source-bulk junction	0, 1
PBOT	_	0.5	0.05	0.95	Grading coefficient of bottom component for source-bulk junction	0, 1
PSTI	-	0.5	0.05	0.95	Grading coefficient of STI-edge component for source-bulk junction	0, 1
PGAT	_	0.5	0.05	0.95	Grading coefficient of gate-edge component for source-bulk junction	0, 1
	TRJ SWJUNEXP IMAX CJORBOT CJORGAT VBIRBOT VBIRSTI VBIRGAT PBOT PSTI	TRJ °C - SWJUNEXP - IMAX A CJORBOT F/m² CJORGAT F/m VBIRBOT V VBIRSTI V VBIRGAT V PBOT - PSTI -	TRJ SWJUNEXP °C - 0 21 o o IMAX A 1000 CJORBOT F/m² 10-3 CJORSTI F/m 10-9 VBIRBOT V 1 VBIRSTI V 1 VBIRGAT V 1 PBOT - 0.5 PSTI - 0.5	TRJ SWJUNEXP °C 21 0 0 Tmin 0 0 IMAX A 1000 10 ⁻¹² Capacitance Para CJORBOT F/m² 10 ⁻³ 10 ⁻¹² CJORSTI F/m 10 ⁻⁹ 10 ⁻¹⁸ VBIRBOT V 1 V _{bi,low} VBIRSTI V 1 V _{bi,low} PBOT - 0.5 0.05 PSTI - 0.5 0.05	TRJ SWJUNEXP °C - 21 0 Tmin 0 -	TRJ °C 21 T_{min} − Reference temperature SWJUNEXP − 0 0 1 Flag for JUNCAP2 Express; 0 → full JUNCAP2 model, 1 → Express model IMAX A 1000 10^{-12} − Maximum current up to which forward current behaves exponentially CJORBOT F/m² 10^{-3} 10^{-12} − Zero-bias capacitance per unit-of-area of bottom component for source-bulk junction CJORSTI F/m 10^{-9} 10^{-18} − Zero-bias capacitance per unit-of-length of STI-edge component for source-bulk junction CJORGAT F/m 10^{-9} 10^{-18} − Zero-bias capacitance per unit-of-length of gate-edge component for source-bulk junction VBIRBOT V 1 $V_{bi,low}$ − Built-in voltage at the reference temperature of bottom component for source-bulk junction VBIRGAT V 1 $V_{bi,low}$ − Built-in voltage at the reference temperature of gate-edge component for source-bulk junction PBOT − 0.5 0.05 0.95 Grading coefficient of bottom component for source-bulk junction PBOT − 0.5 0.05 0.95 Grading coef

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No.	Name	Unit	Default	Min.	Max.	Description	Asym
12	PHIGBOT	V	1.16	_	_	Zero-temperature bandgap voltage of bottom component for source-bulk junction	0, 1
13	PHIGSTI	V	1.16	_	_	Zero-temperature bandgap voltage of STI-edge component for source-bulk junction	0, 1
14	PHIGGAT	V	1.16	_	_	Zero-temperature bandgap voltage of gate-edge component for source-bulk junction	0, 1
15	IDSATRBOT	A/m ²	10^{-12}	0	_	Saturation current density at the reference temperature of bottom component for source-bulk junction	0, 1
16	IDSATRSTI	A/m	10^{-18}	0	_	Saturation current density at the reference temperature of STI-edge component for source-bulk junction	0, 1
17	IDSATRGAT	A/m	10^{-18}	0	_	Saturation current density at the reference temperature of gate-edge component for source-bulk junction	0, 1
		Sh	ockley-Rea	nd-Hall	Parame	eters	
18	CSRHBOT	A/m ³	10^{2}	0	_	Shockley-Read-Hall prefactor of bottom component for source-bulk junction	0, 1
19	CSRHSTI	A/m ²	10^{-4}	0	-	Shockley-Read-Hall prefactor of STI-edge component for source-bulk junction	0, 1
20	CSRHGAT	A/m ²	10^{-4}	0	_	Shockley-Read-Hall prefactor of gate-edge component for source-bulk junction	0, 1
21	XJUNSTI	m	10^{-7}	10^{-9}	_	Junction depth of STI-edge component for source-bulk junction	0, 1
22	XJUNGAT	m	10^{-7}	10^{-9}	_	Junction depth of gate-edge component for source-bulk junction	0, 1
		Trap	o-assisted T	unnelin	g Paraı	meters	
23	СТАТВОТ	A/m ³	10^{2}	0	_	Trap-assisted tunneling prefactor of bottom component for source-bulk junction	0, 1
24	CTATSTI	A/m ²	10^{-4}	0	_	Trap-assisted tunneling prefactor of STI-edge component for source-bulk junction	0, 1
25	CTATGAT	A/m ²	10^{-4}	0	_	Trap-assisted tunneling prefactor of gate-edge component for source-bulk junction	0, 1

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No.	Name	Unit	Default	Min.	Max.	Description	Asym
26	MEFFTATBOT	-	0.25	.01	_	Effective mass (in units of m_0) for trap-assisted tunneling of bottom component for source-bulk junction	0, 1
27	MEFFTATSTI	-	0.25	.01	_	Effective mass (in units of m_0) for trap-assisted tunneling of STI-edge component for source-bulk junction	0, 1
28	MEFFTATGAT	-	0.25	.01	_	Effective mass (in units of m_0) for trap-assisted tunneling of gate-edge component for source-bulk junction	0, 1
		Band	-to-band T	Tunnelir	ıg Para	meters	
29	СВВТВОТ	AV^{-3}	10^{-12}	0	_	Band-to-band tunneling prefactor of bottom component for source-bulk junction	0, 1
30	CBBTSTI	$AV^{-3}m$	10^{-18}	0	_	Band-to-band tunneling prefactor of STI-edge component for source-bulk junction	0, 1
31	CBBTGAT	$AV^{-3}m$	10^{-18}	0	_	Band-to-band tunneling prefactor of gate-edge component for source-bulk junction	0, 1
32	FBBTRBOT	$ m Vm^{-1}$	10^{9}	_	_	Normalization field at the reference temperature for band-to-band tunneling of bottom component for source-bulk junction	0, 1
33	FBBTRSTI	Vm^{-1}	10 ⁹	_	_	Normalization field at the reference temperature for band-to-band tunneling of STI-edge component for source-bulk junction	0, 1
34	FBBTRGAT	Vm^{-1}	10 ⁹	-	_	Normalization field at the reference temperature for band-to-band tunneling of gate-edge component for source-bulk junction	0, 1
35	STFBBTBOT	K^{-1}	-10^{-3}	_	_	Temperature scaling parameter for band-to-band tunneling of bottom component for source-bulk junction	0, 1
36	STFBBTSTI	K^{-1}	-10^{-3}	_	_	Temperature scaling parameter for band-to-band tunneling of STI-edge component for source-bulk junction	0, 1
37	STFBBTGAT	K ⁻¹	-10^{-3}	_	_	Temperature scaling parameter for band-to-band tunneling of gate-edge component for source-bulk junction	0, 1

Avalanche and Breakdown Parameters

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No.	Name	Unit	Default	Min.	Max.	Description	Asym.
38	VBRBOT	V	10	0.1		Breakdown voltage of bottom component for source-bulk junction	0, 1
39	VBRSTI	V	10	0.1	_	Breakdown voltage of STI-edge component for source-bulk junction	0, 1
40	VBRGAT	V	10	0.1	_	Breakdown voltage of gate-edge component for source-bulk junction	0, 1
41	PBRBOT	V	4	0.1	_	Breakdown onset tuning parameter of bottom component for source-bulk junction	0, 1
42	PBRSTI	V	4	0.1	_	Breakdown onset tuning parameter of STI-edge component for source-bulk junction	0, 1
43	PBRGAT	V	4	0.1	_	Breakdown onset tuning parameter of gate-edge component for source-bulk junction	0, 1
		J	UNCAP E	xpress P	aramet	ers	
44	VJUNREF	V	2.5	0.5	_	Typical maximum source-bulk junction voltage; usually about $2 \cdot V_{\text{sup}}$	0, 1
45	FJUNQ	V	0.03	0	_	Fraction below which source-bulk junction capacitance components are neglected	0, 1
			Capacita	nce Para	ameters	S	
46	CJORBOTD	F/m ²	10^{-3}	10^{-12}	_	Zero-bias capacitance per unit-of-area of bottom component for drain-bulk junction	1
47	CJORSTID	F/m	10^{-9}	10^{-18}	_	Zero-bias capacitance per unit-of-length of STI-edge component for drain-bulk junction	1
48	CJORGATD	F/m	10^{-9}	10^{-18}	_	Zero-bias capacitance per unit-of-length of gate-edge component for drain-bulk junction	1
49	VBIRBOTD	V	1	$V_{ m bi,low}$	_	Built-in voltage at the reference temperature of bottom component for drain-bulk junction	1
50	VBIRSTID	V	1	$V_{ m bi,low}$	_	Built-in voltage at the reference temperature of STI-edge component for drain-bulk junction	1
51	VBIRGATD	V	1	$V_{ m bi,low}$	_	Built-in voltage at the reference temperature of gate-edge component for drain-bulk junction	1
52	PBOTD	_	0.5	0.05	0.95	Grading coefficient of bottom component for drain-bulk junction	1

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No.	Name	Unit	Default	Min.	Max.	Description	Asym
53	PSTID	_	0.5	0.05	0.95	Grading coefficient of STI-edge component for drain-bulk junction	1
54	PGATD	-	0.5	0.05	0.95	Grading coefficient of gate-edge component for drain-bulk junction	1
			Ideal-curi	ent Par	ameter	s	
55	PHIGBOTD	V	1.16	_	_	Zero-temperature bandgap voltage of bottom component for drain-bulk junction	1
56	PHIGSTID	V	1.16	_	_	Zero-temperature bandgap voltage of STI-edge component for drain-bulk junction	1
57	PHIGGATD	V	1.16	_	_	Zero-temperature bandgap voltage of gate-edge component for drain-bulk junction	1
58	IDSATRBOTD	A/m ²	10^{-12}	0	_	Saturation current density at the reference temperature of bottom component for drain-bulk junction	1
59	IDSATRSTID	A/m	10^{-18}	0	_	Saturation current density at the reference temperature of STI-edge component for drain-bulk junction	1
60	IDSATRGATD	A/m	10^{-18}	0	_	Saturation current density at the reference temperature of gate-edge component for drain-bulk junction	1
		Sh	ockley-Rea	d-Hall	Parame	eters	
61	CSRHBOTD	A/m ³	10^{2}	0	_	Shockley-Read-Hall prefactor of bottom component for drain-bulk junction	1
62	CSRHSTID	A/m ²	10^{-4}	0	_	Shockley-Read-Hall prefactor of STI-edge component for drain-bulk junction	1
63	CSRHGATD	A/m ²	10^{-4}	0	_	Shockley-Read-Hall prefactor of gate-edge component for drain-bulk junction	1
64	XJUNSTID	m	10^{-7}	10^{-9}	_	Junction depth of STI-edge component for drain-bulk junction	1
65	XJUNGATD	m	10^{-7}	10^{-9}	-	Junction depth of gate-edge component for drain-bulk junction	1
		Trap	o-assisted T	unnelin	g Paraı	neters	
66	CTATBOTD	A/m ³	10^{2}	0	_	Trap-assisted tunneling prefactor of bottom component for drain-bulk junction	1
67	CTATSTID	A/m ²	10^{-4}	0	_	Trap-assisted tunneling prefactor of STI-edge component for drain-bulk junction	1

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No.	Name	Unit	Default	Min.	Max.	Description	Asym
68	CTATGATD	A/m ²	10^{-4}	0	_	Trap-assisted tunneling prefactor of gate-edge component for drain-bulk junction	1
69	MEFFTATBOTD	_	0.25	.01	_	Effective mass (in units of m_0) for trap-assisted tunneling of bottom component for drain-bulk junction	1
70	MEFFTATSTID	_	0.25	.01	_	Effective mass (in units of m_0) for trap-assisted tunneling of STI-edge component for drain-bulk junction	1
71	MEFFTATGATD	_	0.25	.01	_	Effective mass (in units of m_0) for trap-assisted tunneling of gate-edge component for drain-bulk junction	1
		Band	-to-band T	Tunnelir	ng Para	meters	
72	СВВТВОТО	AV^{-3}	10^{-12}	0	_	Band-to-band tunneling prefactor of bottom component for drain-bulk junction	1
73	CBBTSTID	AV^{-3} m	10^{-18}	0	_	Band-to-band tunneling prefactor of STI-edge component for drain-bulk junction	1
74	CBBTGATD	AV^{-3} m	10^{-18}	0	_	Band-to-band tunneling prefactor of gate-edge component for drain-bulk junction	1
75	FBBTRBOTD	Vm ⁻¹	10^{9}	_	_	Normalization field at the reference temperature for band-to-band tunneling of bottom component for drain-bulk junction	1
76	FBBTRSTID	Vm ⁻¹	10^{9}	_	_	Normalization field at the reference temperature for band-to-band tunneling of STI-edge component for drain-bulk junction	1
77	FBBTRGATD	Vm^{-1}	10^{9}	_	-	Normalization field at the reference temperature for band-to-band tunneling of gate-edge component for drain-bulk junction	1
78	STFBBTBOTD	K^{-1}	-10^{-3}	_	_	Temperature scaling parameter for band-to-band tunneling of bottom component for drain-bulk junction	1
79	STFBBTSTID	\mathbf{K}^{-1}	-10^{-3}	_	-	Temperature scaling parameter for band-to-band tunneling of STI-edge component for drain-bulk junction	1
80	STFBBTGATD	K^{-1}	-10^{-3}	_	_	Temperature scaling parameter for band-to-band tunneling of gate-edge component for drain-bulk junction	1

Avalanche and Breakdown Parameters

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No.	Name	Unit	Default	Min.	Max.	Description	Asym.
81	VBRBOTD	V	10	0.1	_	Breakdown voltage of bottom component for drain-bulk junction	1
82	VBRSTID	V	10	0.1	_	Breakdown voltage of STI-edge component for drain-bulk junction	1
83	VBRGATD	V	10	0.1	_	Breakdown voltage of gate-edge component for drain-bulk junction	1
84	PBRBOTD	V	4	0.1	_	Breakdown onset tuning parameter of bottom component for drain-bulk junction	1
85	PBRSTID	V	4	0.1	_	Breakdown onset tuning parameter of STI-edge component for drain-bulk junction	1
86	PBRGATD	V	4	0.1	_	Breakdown onset tuning parameter of gate-edge component for drain-bulk junction	1
		J	UNCAP Ex	xpress P	aramet	ers	
87	VJUNREFD	V	2.5	0.5	_	Typical maximum drain-bulk junction voltage; usually about $2 \cdot V_{\mathrm{sup}}$	1
88	FJUNQD	V	0.03	0	_	Fraction below which drain-bulk junction capacitance components are neglected	1

2.5.6 Parameters for parasitic resistances

The parameters for parasitic resistances are listed in the table below. The last column of Geo. shows for which value of SWGEO the listed parameter is used.

No.	Name	Unit	Default	Min.	Max.	Description	Geo.
0	RG	Ω	0	0	_	Gate resistance $R_{ m gate}$	0
1	RGO	Ω	0	_	_	Gate resistance $R_{ m gate}$	1, 2
2	RINT	Ω ·m ²	0	0	_	Contact resistance between silicide and ploy	1, 2
3	RVPOLY	$\Omega{\cdot}m^2$	0	0	_	Vertical poly resistance	1, 2
4	RSHG	Ω/\Box	0	0	_	Gate electrode diffusion sheet resistance	1, 2
5	DLSIL	m	0	_	_	Silicide extension over the physical gate length	1, 2
6	RSE	Ω	0	0	_	External source resistance	0
7	RDE	Ω	0	0	_	External drain resistance	0
8	RSH	Ω/\Box	0	_	_	Sheet resistance of source diffusion	1, 2
9	RSHD	Ω/\Box	0	_	_	Sheet resistance of drain diffusion	1, 2
10	RBULK	Ω	0	0	_	Bulk resistance R_{bulk}	0
11	RBULKO	Ω	0	_	_	Bulk resistance $R_{ m bulk}$	1, 2
12	RWELL	Ω	0	0	_	Well resistance $R_{ m well}$	0
13	RWELLO	Ω	0	_	_	Well resistance $R_{ m well}$	1, 2
14	RJUNS	Ω	0	0	_	Source-side bulk resistance $R_{ m juns}$	0
15	RJUNSO	Ω	0	_	_	Source-side bulk resistance R_{juns}	1, 2
16	RJUND	Ω	0	0	_	Drain-side bulk resistance $R_{ m jund}$	0
17	RJUNDO	Ω	0	_	_	Drain-side bulk resistance $R_{ m jund}$	1, 2

2.5.7 Parameters for NQS

No.	Name	Unit	Default	Min.	Max.	Description	Geo.
0	SWNQS	-	0	0	9	Switch for NQS effects / number of collocation points	0, 1, 2
1	MUNQS	-	1	0	_	Relative mobility for NQS modeling	0
2	MUNQSO	-	1	_	_	Relative mobility for NQS modeling	1, 2

Section 3

Geometry dependence and Other effects

3.1 Introduction

The physical geometry scaling rules of PSP (Section 3.2) have been developed to give a good description over the whole geometry range of CMOS technologies. As an alternative, the binning-rules can be used (Section 3.3) to allow for a more phenomenological geometry dependency. (Note that the user has to choose between the two options; the geometrical scaling rules and the binning scaling rules cannot be used at the same time.) In both cases, the result is a local parameter set (for a transistor of the specified L and W), which is fed into the local model.

Stress and well proximity effects are included in PSP. Use of the stress model (Section 3.5) and/or well proximity effect model (Section 3.6) leads to modification of some of the local parameters calculated from the geometrical or binning scaling rules.

3.2 Geometrical scaling rules

The physical scaling rules to calculate the local parameters from a global parameter set are given in this section.

Note:

- After calculation of the local parameters (and possible application of the stress equations in Section 3.5), clipping is applied according to Section 2.5.2.
- The geometrical scaling equations are *only* calculated when **SWGEO** = 1.

Effective length and width

$$W_{\rm f} = \frac{W}{\mathbf{NF}} \tag{3.1}$$

$$L_{\rm EN} = 10^{-6} \tag{3.2}$$

$$W_{\rm EN} = 10^{-6} \tag{3.3}$$

$$\Delta L_{\rm PS} = \mathbf{LVARO} \cdot \left(1 + \mathbf{LVARL} \cdot \frac{L_{\rm EN}}{L} \right) \cdot \left(1 + \mathbf{LVARW} \cdot \frac{W_{\rm EN}}{W_{\rm f}} \right)$$
(3.4)

$$\Delta W_{\rm OD} = \mathbf{WVARO} \cdot \left(1 + \mathbf{WVARL} \cdot \frac{L_{\rm EN}}{L} \right) \cdot \left(1 + \mathbf{WVARW} \cdot \frac{W_{\rm EN}}{W_{\rm f}} \right)$$
(3.5)

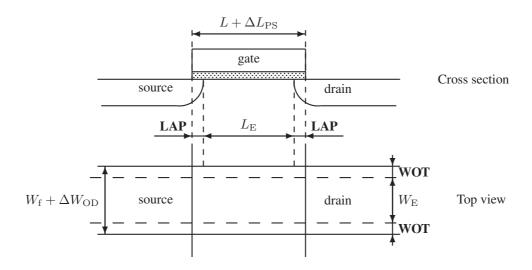


Figure 3.1: Specification of the dimensions of a MOS transistor

$$L_{\rm E} = L - \Delta L = L + \Delta L_{\rm PS} - 2 \cdot \mathbf{LAP} \tag{3.6}$$

$$W_{\rm E} = W_{\rm f} - \Delta W = W_{\rm f} + \Delta W_{\rm OD} - 2 \cdot \mathbf{WOT} \tag{3.7}$$

$$L_{\text{E.CV}} = L + \Delta L_{\text{PS}} - 2 \cdot \mathbf{LAP} + \mathbf{DLQ}$$
(3.8)

$$W_{\rm E,CV} = W_{\rm f} + \Delta W_{\rm OD} - 2 \cdot \mathbf{WOT} + \mathbf{DWQ}$$
(3.9)

$$L_{G,CV} = L + \Delta L_{PS} + \mathbf{DLQ} \tag{3.10}$$

$$W_{G,CV} = W_f + \Delta W_{OD} + \mathbf{DWQ} \tag{3.11}$$

Note: If the calculated $L_{\rm E}$, $W_{\rm E}$, $L_{\rm E,CV}$, $W_{\rm E,CV}$, $L_{\rm G,CV}$, or $W_{\rm G,CV}$ is smaller than 1 nm (10⁻⁹ m), the value is clipped to this lower bound of 1 nm.

Process Parameters

$$\mathbf{VFB} = \mathbf{VFBO} + \mathbf{VFBL} \cdot \frac{L_{\mathrm{EN}}}{L_{\mathrm{E}}} + \mathbf{VFBW} \cdot \frac{W_{\mathrm{EN}}}{W_{\mathrm{E}}} + \mathbf{VFBLW} \cdot \frac{W_{\mathrm{EN}} \cdot L_{\mathrm{EN}}}{W_{\mathrm{E}} \cdot L_{\mathrm{E}}} \quad (3.12)$$

$$\mathbf{STVFB} = \mathbf{STVFBO} + \mathbf{STVFBL} \cdot \frac{L_{\mathrm{EN}}}{L_{\mathrm{E}}} + \mathbf{STVFBW} \cdot \frac{W_{\mathrm{EN}}}{W_{\mathrm{E}}} + \mathbf{STVFBLW} \cdot \frac{W_{\mathrm{EN}} \cdot L_{\mathrm{EN}}}{W_{\mathrm{E}} \cdot L_{\mathrm{E}}} \quad (3.13)$$

$$TOX = TOXO (3.14)$$

$$EPSROX = EPSROXO (3.15)$$

$$N_{\mathrm{sub0,eff}} = \mathbf{NSUBO} \cdot \mathbf{MAX} \left(\left[1 + \mathbf{NSUBW} \cdot \frac{W_{\mathrm{EN}}}{W_{\mathrm{E}}} \cdot \ln \left(1 + \frac{W_{\mathrm{E}}}{\mathbf{WSEG}} \right) \right], 10^{-3} \right)$$
 (3.16)

$$N_{\text{pck,eff}} = \text{NPCK} \cdot \text{MAX} \left(\left[1 + \text{NPCKW} \cdot \frac{W_{\text{EN}}}{W_{\text{E}}} \cdot \ln \left(1 + \frac{W_{\text{E}}}{\text{WSEGP}} \right) \right], 10^{-3} \right)$$
(3.17)

$$L_{\text{pck,eff}} = \mathbf{LPCK} \cdot \text{MAX} \left(\left[1 + \mathbf{LPCKW} \cdot \frac{W_{\text{EN}}}{W_{\text{E}}} \cdot \ln \left(1 + \frac{W_{\text{E}}}{\mathbf{WSEGP}} \right) \right], 10^{-3} \right)$$
(3.18)

$$a = 7.5 \cdot 10^{10} \tag{3.19}$$

$$b = \sqrt{N_{\text{sub0,eff}} + 0.5 \cdot N_{\text{pck,eff}}} - \sqrt{N_{\text{sub0,eff}}}$$
(3.20)

$$N_{\rm sub0,eff} + N_{\rm pck,eff} \cdot \left[2 - \frac{L_{\rm E}}{L_{\rm pck,eff}}\right] \qquad \text{for } L_{\rm E} < L_{\rm pck,eff}$$

$$N_{\rm sub0,eff} + N_{\rm pck,eff} \cdot \frac{L_{\rm pck,eff}}{L_{\rm E}} \qquad \text{for } L_{\rm pck,eff} \le L_{\rm E} \le 2 \cdot L_{\rm pck,eff}$$

$$\left[\sqrt{N_{\rm sub0,eff}} + a \cdot \ln\left(1 + 2 \cdot \frac{L_{\rm pck,eff}}{L_{\rm E}} \cdot \left[\exp\left(\frac{b}{a}\right) - 1\right]\right)\right]^{2} \qquad \text{for } L_{\rm E} > 2 \cdot L_{\rm pck,eff}$$

$$(3.21)$$

$$\mathbf{NEFF} = N_{\text{sub}} \cdot \left(1 - \mathbf{FOL1} \cdot \frac{L_{\text{EN}}}{L_{\text{E}}} - \mathbf{FOL2} \cdot \left[\frac{L_{\text{EN}}}{L_{\text{E}}} \right]^2 \right)$$
(3.22)

 $\mathbf{FACNEFFAC} = \mathbf{FACNEFFACO} + \mathbf{FACNEFFACL} \cdot \frac{L_{\mathrm{EN}}}{L_{\mathrm{E}}}$

+ FACNEFFACW
$$\cdot \frac{W_{\rm EN}}{W_{\rm E}}$$
 + FACNEFFACLW $\cdot \frac{L_{\rm EN} \cdot W_{\rm EN}}{L_{\rm E} \cdot W_{\rm E}}$ (3.23)

 $\mathbf{GFACNUD} = \mathbf{GFACNUDO} + \mathbf{GFACNUDL} \cdot \left[\frac{L_{\mathrm{EN}}}{L_{\mathrm{E}}} \right]^{\mathbf{GFACNUDLEXP}}$

+ GFACNUDW ·
$$\frac{W_{\rm EN}}{W_{\rm E}}$$
 + GFACNUDLW · $\frac{L_{\rm EN} \cdot W_{\rm EN}}{L_{\rm E} \cdot W_{\rm E}}$ (3.24)

$$VSBNUD = VSBNUDO (3.25)$$

$$DVSBNUD = DVSBNUDO (3.26)$$

$$VNSUB = VNSUBO (3.27)$$

$$NSLP = NSLPO (3.28)$$

$$DNSUB = DNSUBO (3.29)$$

$$\begin{aligned} \textbf{DPHIB} &= \textbf{DPHIBO} + \textbf{DPHIBL} \cdot \left[\frac{L_{\text{EN}}}{L_{\text{E}}}\right]^{\textbf{DPHIBLEXP}} \\ &+ \textbf{DPHIBW} \cdot \frac{W_{\text{EN}}}{W_{\text{E}}} + \textbf{DPHIBLW} \cdot \frac{W_{\text{EN}} \cdot L_{\text{EN}}}{W_{\text{E}} \cdot L_{\text{E}}} \end{aligned} \quad (3.30) \end{aligned}$$

$$\mathbf{DELVTAC} = \mathbf{DELVTACO} + \mathbf{DELVTACL} \cdot \left[\frac{L_{\mathrm{EN}}}{L_{\mathrm{E}}} \right]^{\mathbf{DELVTACLEXP}}$$

$$+ \, \mathbf{DELVTACW} \cdot \frac{W_{\mathrm{EN}}}{W_{\mathrm{E}}} + \mathbf{DELVTACLW} \cdot \frac{W_{\mathrm{EN}} \cdot L_{\mathrm{EN}}}{W_{\mathrm{E}} \cdot L_{\mathrm{E}}} \quad (3.31)$$

$$\mathbf{NP} = \mathbf{NPO} \cdot \text{MAX} \left(10^{-6}, 1 + \mathbf{NPL} \cdot \frac{L_{\text{EN}}}{L_{\text{E}}} \right)$$
 (3.32)

$$\mathbf{CT} = \left(\mathbf{CTO} + \mathbf{CTL} \cdot \left[\frac{L_{\mathrm{EN}}}{L_{\mathrm{E}}}\right]^{\mathbf{CTLEXP}}\right) \cdot \left(1 + \mathbf{CTW} \cdot \frac{W_{\mathrm{EN}}}{W_{\mathrm{E}}}\right)$$

$$\cdot \left(1 + \mathbf{CTLW} \cdot \frac{W_{\mathrm{EN}} \cdot L_{\mathrm{EN}}}{W_{\mathrm{E}} \cdot L_{\mathrm{E}}}\right) \quad (3.33)$$

$$TOXOV = TOXOVO (3.34)$$

$$TOXOVD = TOXOVDO (3.35)$$

$$NOV = NOVO (3.36)$$

$$NOVD = NOVDO (3.37)$$

DIBL Parameters

$$\mathbf{CF} = \mathbf{CFL} \cdot \left[\frac{L_{\text{EN}}}{L_{\text{E}}} \right]^{\mathbf{CFLEXP}} \cdot \left(1 + \mathbf{CFW} \cdot \frac{W_{\text{EN}}}{W_{\text{E}}} \right)$$
(3.38)

$$\mathbf{CFB} = \mathbf{CFBO} \tag{3.39}$$

Mobility Parameters

$$F_{\beta 1,\text{eff}} = \mathbf{FBET1} \cdot \left(1 + \mathbf{FBET1W} \cdot \frac{W_{\text{EN}}}{W_{\text{E}}} \right)$$
(3.40)

$$L_{\text{P1,eff}} = \mathbf{LP1} \cdot \text{MAX} \left(\left[1 + \mathbf{LP1W} \cdot \frac{W_{\text{EN}}}{W_{\text{E}}} \right], 10^{-3} \right)$$
 (3.41)

$$G_{\rm P,E} = 1 + F_{\beta 1,\rm eff} \cdot \frac{L_{\rm P1,eff}}{L_{\rm E}} \cdot \left[1 - \exp\left(-\frac{L_{\rm E}}{L_{\rm P1,eff}}\right) \right]$$
(3.42)

$$+ \mathbf{FBET2} \cdot \frac{\mathbf{LP2}}{L_{\mathrm{E}}} \cdot \left[1 - \exp\left(-\frac{L_{\mathrm{E}}}{\mathbf{LP2}}\right) \right]$$

$$G_{\mathrm{W,E}} = 1 + \mathbf{BETW1} \cdot \frac{W_{\mathrm{EN}}}{W_{\mathrm{E}}} + \mathbf{BETW2} \cdot \frac{W_{\mathrm{EN}}}{W_{\mathrm{E}}} \cdot \ln\left(1 + \frac{W_{\mathrm{E}}}{\mathbf{WBET}}\right)$$
(3.43)

$$\mathbf{BETN} = \frac{\mathbf{UO}}{G_{\text{P.E.}}} \cdot \frac{W_{\text{E}}}{L_{\text{E.}}} \cdot G_{\text{W,E}}$$
(3.44)

$$\mathbf{STBET} = \mathbf{STBETO} + \mathbf{STBETL} \cdot \frac{L_{\mathrm{EN}}}{L_{\mathrm{E}}} + \mathbf{STBETW} \cdot \frac{W_{\mathrm{EN}}}{W_{\mathrm{E}}} + \mathbf{STBETLW} \cdot \frac{W_{\mathrm{EN}} \cdot L_{\mathrm{EN}}}{W_{\mathrm{E}} \cdot L_{\mathrm{E}}} \quad (3.45)$$

$$\mathbf{MUE} = \mathbf{MUEO} \cdot \left[1 + \mathbf{MUEW} \cdot \frac{W_{\text{EN}}}{W_{\text{E}}} \right]$$
 (3.46)

$$STMUE = STMUEO (3.47)$$

$$THEMU = THEMUO (3.48)$$

$$STTHEMU = STTHEMUO (3.49)$$

$$\mathbf{CS} = \left(\mathbf{CSO} + \mathbf{CSL} \cdot \left[\frac{L_{\mathrm{EN}}}{L_{\mathrm{E}}}\right]^{\mathbf{CSLEXP}}\right) \cdot \left(1 + \mathbf{CSW} \cdot \frac{W_{\mathrm{EN}}}{W_{\mathrm{E}}}\right)$$

$$\cdot \left(1 + \mathbf{CSLW} \cdot \frac{W_{\mathrm{EN}} \cdot L_{\mathrm{EN}}}{W_{\mathrm{E}} \cdot L_{\mathrm{E}}}\right) \quad (3.50)$$

$$STCS = STCSO (3.51)$$

$$\mathbf{XCOR} = \mathbf{XCORO} \cdot \left(1 + \mathbf{XCORL} \cdot \frac{L_{\mathrm{EN}}}{L_{\mathrm{E}}}\right) \cdot \left(1 + \mathbf{XCORW} \cdot \frac{W_{\mathrm{EN}}}{W_{\mathrm{E}}}\right)$$

$$\cdot \left(1 + \mathbf{XCORLW} \cdot \frac{W_{\mathrm{EN}} \cdot L_{\mathrm{EN}}}{W_{\mathrm{E}} \cdot L_{\mathrm{E}}}\right) \quad (3.52)$$

$$STXCOR = STXCORO (3.53)$$

$$\mathbf{FETA} = \mathbf{FETAO} \tag{3.54}$$

Series Resistance Parameters

$$\mathbf{RS} = \mathbf{RSW1} \cdot \frac{W_{\text{EN}}}{W_{\text{E}}} \cdot \left[1 + \mathbf{RSW2} \cdot \frac{W_{\text{EN}}}{W_{\text{E}}} \right]$$
(3.55)

$$STRS = STRSO (3.56)$$

$$\mathbf{RSB} = \mathbf{RSBO} \tag{3.57}$$

$$RSG = RSGO (3.58)$$

Velocity Saturation Parameters

$$\begin{aligned} \textbf{THESAT} &= \left(\textbf{THESATO} + \textbf{THESATL} \cdot \frac{G_{\text{W,E}}}{G_{\text{P,E}}} \cdot \left[\frac{L_{\text{EN}}}{L_{\text{E}}} \right]^{\textbf{THESATLEXP}} \right) \\ & \cdot \left(1 + \textbf{THESATW} \cdot \frac{W_{\text{EN}}}{W_{\text{E}}} \right) \cdot \left(1 + \textbf{THESATLW} \cdot \frac{W_{\text{EN}} \cdot L_{\text{EN}}}{W_{\text{E}} \cdot L_{\text{E}}} \right) \end{aligned} \tag{3.59}$$

 $\mathbf{STTHESAT} = \mathbf{STTHESATO} + \mathbf{STTHESATL} \cdot \frac{L_{\mathrm{EN}}}{L_{\mathrm{E}}}$

$$+$$
 STTHESATW $\cdot \frac{W_{\mathrm{EN}}}{W_{\mathrm{E}}} +$ STTHESATLW $\cdot \frac{W_{\mathrm{EN}} \cdot L_{\mathrm{EN}}}{W_{\mathrm{E}} \cdot L_{\mathrm{E}}}$ (3.60)

$$THESATB = THESATBO (3.61)$$

$$THESATG = THESATGO (3.62)$$

Saturation Voltage Parameter

$$\mathbf{AX} = \frac{\mathbf{AXO}}{1 + \mathbf{AXL} \cdot \frac{L_{\text{EN}}}{L_{\text{E}}}}$$
(3.63)

Channel Length Modulation (CLM) Parameters

$$\mathbf{ALP} = \mathbf{ALPL} \cdot \left[\frac{L_{\mathrm{EN}}}{L_{\mathrm{E}}} \right]^{\mathbf{ALPLEXP}} \cdot \left(1 + \mathbf{ALPW} \cdot \frac{W_{\mathrm{EN}}}{W_{\mathrm{E}}} \right)$$
(3.64)

$$\mathbf{ALP1} = \frac{\mathbf{ALP1L1} \cdot \left[\frac{L_{\mathrm{EN}}}{L_{\mathrm{E}}}\right]^{\mathbf{ALP1LEXP}}}{1 + \mathbf{ALP1L2} \cdot \left[\frac{L_{\mathrm{EN}}}{L_{\mathrm{E}}}\right]^{\mathbf{ALP1LEXP}+1}} \cdot \left(1 + \mathbf{ALP1W} \cdot \frac{W_{\mathrm{EN}}}{W_{\mathrm{E}}}\right)$$
(3.65)

$$\mathbf{ALP2} = \frac{\mathbf{ALP2L1} \cdot \left[\frac{L_{\mathrm{EN}}}{L_{\mathrm{E}}}\right]^{\mathbf{ALP2LEXP}}}{1 + \mathbf{ALP2L2} \cdot \left[\frac{L_{\mathrm{EN}}}{L_{\mathrm{E}}}\right]^{\mathbf{ALP2LEXP}+1}} \cdot \left(1 + \mathbf{ALP2W} \cdot \frac{W_{\mathrm{EN}}}{W_{\mathrm{E}}}\right)$$
(3.66)

$$\mathbf{VP} = \mathbf{VPO} \tag{3.67}$$

Impact Ionization (II) Parameters

$$\mathbf{A1} = \mathbf{A10} \cdot \left(1 + \mathbf{A1L} \cdot \frac{L_{\text{EN}}}{L_{\text{E}}} \right) \cdot \left(1 + \mathbf{A1W} \cdot \frac{W_{\text{EN}}}{W_{\text{E}}} \right)$$
(3.68)

$$\mathbf{A2} = \mathbf{A20} \tag{3.69}$$

$$STA2 = STA2O (3.70)$$

$$\mathbf{A3} = \mathbf{A3O} \cdot \left(1 + \mathbf{A3L} \cdot \frac{L_{\text{EN}}}{L_{\text{E}}} \right) \cdot \left(1 + \mathbf{A3W} \cdot \frac{W_{\text{EN}}}{W_{\text{E}}} \right)$$
(3.71)

$$\mathbf{A4} = \mathbf{A4O} \cdot \left(1 + \mathbf{A4L} \cdot \frac{L_{\text{EN}}}{L_{\text{E}}} \right) \cdot \left(1 + \mathbf{A4W} \cdot \frac{W_{\text{EN}}}{W_{\text{E}}} \right)$$
(3.72)

Gate Current Parameters

$$GCO = GCOO (3.73)$$

$$\mathbf{IGINV} = \mathbf{IGINVLW} \cdot \frac{W_{\mathrm{E}} \cdot L_{\mathrm{E}}}{W_{\mathrm{EN}} \cdot L_{\mathrm{EN}}}$$
(3.74)

$$\mathbf{IGOV} = \mathbf{IGOVW} \cdot \frac{W_{\text{E}} \cdot \mathbf{LOV}}{W_{\text{EN}} \cdot L_{\text{EN}}}$$
(3.75)

$$\mathbf{IGOVD} = \mathbf{IGOVDW} \cdot \frac{W_{\text{E}} \cdot \mathbf{LOVD}}{W_{\text{EN}} \cdot L_{\text{EN}}}$$
(3.76)

$$STIG = STIGO (3.77)$$

$$GC2 = GC2O (3.78)$$

$$GC3 = GC3O (3.79)$$

$$\mathbf{CHIB} = \mathbf{CHIBO} \tag{3.80}$$

Gate-Induced Drain Leakage (GIDL) Parameters

$$\mathbf{AGIDL} = \mathbf{AGIDLW} \cdot \frac{W_{\mathrm{E}} \cdot \mathbf{LOV}}{W_{\mathrm{EN}} \cdot L_{\mathrm{EN}}}$$
(3.81)

$$\mathbf{AGIDLD} = \mathbf{AGIDLDW} \cdot \frac{W_{\mathrm{E}} \cdot \mathbf{LOVD}}{W_{\mathrm{EN}} \cdot L_{\mathrm{EN}}}$$
(3.82)

$$BGIDL = BGIDLO (3.83)$$

$$\mathbf{BGIDLD} = \mathbf{BGIDLDO} \tag{3.84}$$

$$STBGIDL = STBGIDLO (3.85)$$

$$STBGIDLD = STBGIDLDO (3.86)$$

$$CGIDL = CGIDLO (3.87)$$

$$CGIDLD = CGIDLDO (3.88)$$

Charge Model Parameters

$$\epsilon_{\rm ox} = \epsilon_0 \cdot \mathbf{EPSROX} \tag{3.89}$$

$$\mathbf{COX} = \epsilon_{\text{ox}} \cdot \frac{W_{\text{E,CV}} \cdot L_{\text{E,CV}}}{\mathbf{TOX}}$$
(3.90)

$$\mathbf{CGOV} = \epsilon_{ox} \cdot \frac{W_{E,CV} \cdot \mathbf{LOV}}{\mathbf{TOXOV}}$$
(3.91)

$$\mathbf{CGOVD} = \epsilon_{ox} \cdot \frac{W_{E,CV} \cdot \mathbf{LOVD}}{\mathbf{TOXOVD}}$$
(3.92)

$$\mathbf{CGBOV} = \mathbf{CGBOVL} \cdot \frac{L_{G,CV}}{L_{EN}}$$
(3.93)

$$\mathbf{CFR} = \mathbf{CFRW} \cdot \frac{W_{G,CV}}{W_{EN}} \tag{3.94}$$

$$\mathbf{CFRD} = \mathbf{CFRDW} \cdot \frac{W_{G,CV}}{W_{EN}} \tag{3.95}$$

Noise Model Parameters

$$L_{\text{noi}} = \text{MAX}\left(1 - \frac{2 \cdot \text{LINTNOI}}{L_{\text{E}}}, 10^{-3}\right)$$
(3.96)

$$L_{\text{noi}} = \text{MAX} \left(1 - \frac{2 \cdot \text{LINTNOI}}{L_{\text{E}}}, 10^{-3} \right)$$

$$L_{\text{red}} = \frac{1}{L_{\text{noi}}^{\text{ALPNOI}}}$$
(3.96)

$$NFA = L_{red} \cdot NFALW \cdot \frac{W_{EN} \cdot L_{EN}}{W_{E} \cdot L_{E}}$$
(3.98)

$$NFB = L_{red} \cdot NFBLW \cdot \frac{W_{EN} \cdot L_{EN}}{W_{E} \cdot L_{E}}$$
(3.99)

$$NFC = L_{red} \cdot NFCLW \cdot \frac{W_{EN} \cdot L_{EN}}{W_{E} \cdot L_{E}}$$
(3.100)

$$\mathbf{EF} = \mathbf{EFO} \tag{3.101}$$

WPE parameters

$$K_{\rm vthowe} = \textbf{KVTHOWEO} + \textbf{KVTHOWEL} \cdot \frac{L_{\rm EN}}{L_{\rm E}} + \textbf{KVTHOWEW} \cdot \frac{W_{\rm EN}}{W_{\rm E}} \\ + \textbf{KVTHOWELW} \cdot \frac{L_{\rm EN} \cdot W_{\rm EN}}{L_{\rm E} \cdot W_{\rm E}} \quad (3.102)$$

$$K_{\rm uowe} = {\bf KUOWEO} + {\bf KUOWEL} \cdot \frac{L_{\rm EN}}{L_{\rm E}} + {\bf KUOWEW} \cdot \frac{W_{\rm EN}}{W_{\rm E}} \\ \\ + {\bf KUOWELW} \cdot \frac{L_{\rm EN} \cdot W_{\rm EN}}{L_{\rm E} \cdot W_{\rm E}} \quad (3.103)$$

3.3 Binning equations

The binning equations are provided as a (phenomenological) alternative to the physical scaling equations for computing local parameters. The physical geometrical scaling rules have been developed to give a good description over the whole geometry range of CMOS technologies. For processes under development, however, it is sometimes useful to have more flexible scaling relations. In that case on could opt for a binning strategy, where the accuracy with geometry is mostly determined by the number of bins used. The physical scaling rules of Section 3.2 are generally not suitable for binning strategies, since they may result in discontinuities in local parameter values at the bin boundaries. Consequently, special binning geometrical scaling relations have been developed, which guarantee continuity of the resulting local model parameters at the bin boundaries.

Note: The binning equations are *only* calculated when **SWGEO** = 2.

Only four different types of binning scaling rules are used, which are based on first order developments of the geometrical scaling rules in terms of $L_{\rm E}$, $1/L_{\rm E}$, $W_{\rm E}$, and $1/W_{\rm E}$ (examples below are for a fictitious parameter YYY):

1. Type I

$$\mathbf{YYY} = \mathbf{POYYY} + \mathbf{PLYYY} \cdot \frac{L_{\text{EN}}}{L_{\text{E}}} + \mathbf{PWYYY} \cdot \frac{W_{\text{EN}}}{W_{\text{E}}} + \mathbf{PLWYYY} \cdot \frac{L_{\text{EN}} \cdot W_{\text{EN}}}{L_{\text{E}} \cdot W_{\text{E}}}$$
(3.104)

2. Type II

$$\mathbf{YYY} = \mathbf{POYYY} + \mathbf{PLYYY} \cdot \frac{L_{\mathrm{E}}}{L_{\mathrm{EN}}} + \mathbf{PWYYY} \cdot \frac{W_{\mathrm{E}}}{W_{\mathrm{EN}}} + \mathbf{PLWYYY} \cdot \frac{L_{\mathrm{E}} \cdot W_{\mathrm{E}}}{L_{\mathrm{EN}} \cdot W_{\mathrm{EN}}}$$
(3.105)

3. Type III

$$\mathbf{YYY} = \mathbf{POYYY} + \mathbf{PLYYY} \cdot \frac{L_{\mathrm{EN}}}{L_{\mathrm{E}}} + \mathbf{PWYYY} \cdot \frac{W_{\mathrm{E}}}{W_{\mathrm{EN}}} + \mathbf{PLWYYY} \cdot \frac{W_{\mathrm{E}} \cdot L_{\mathrm{EN}}}{W_{\mathrm{EN}} \cdot L_{\mathrm{E}}}$$
(3.106)

4. Type IV (no binning)

$$\mathbf{YYY} = \mathbf{POYYY} \tag{3.107}$$

In Table 3.1 a survey of the binning type used for each local parameter is given. In some cases where the geometrical scaling rule is constant, the binning rule is chosen to be more flexible.

When using the binning rules above, the binning parameters for one bin can be directly calculated from the local parameter sets of the four corner devices of the bin (see Sec. 7.6). This results in a *separate parameter set* for each bin. The binning scheme ensures that the local parameters are exactly reproduced at the bin corners and that no humps occur in the local parameter values across bin boundaries.

Note: After calculation of the local parameters from the binning rules (and possible applications of the stress equations in Section 3.5 and well proximity equations in Section 3.6), clipping is applied according to Section 2.5.2.

Table 3.1: Overview of local parameters and binning type. The third column indicates whether there is a physical geometrical scaling rule for the local parameters.

#	parameter	physical scaling	binning	#	parameter	physical scaling	binning
0	VFB	yes	type I	40	THESATG	no	type I
1	STVFB	yes	type I	41	$\mathbf{A}\mathbf{X}$	yes	type I
2	TOX	no	no	42	ALP	yes	type I
3	EPSROX	no	no	43	ALP1	yes	type I
4	NEFF	yes	type I	44	ALP2	yes	type I
5	FACNEFFAC	yes	type I	45	VP	no	no
6	GFACNUD	yes	type I	46	A1	yes	type I
7	VSBNUD	no	no	47	A2	no	no
8	DVSBNUD	no	no	48	STA2	no	no
9	VNSUB	no	no	49	A3	yes	type I
10	NSLP	no	no	50	A4	yes	type I
11	DNSUB	no	no	51	GCO	no	no
12	DPHIB	yes	type I	52	IGINV	yes	type II
13	DELVTAC	yes	type I	53	IGOV	yes	type III
14	NP	yes	type I	54	IGOVD	yes	type III
15	CT	yes	type I	55	STIG	no	no
16	TOXOV	no	no	56	GC2	no	no
17	TOXOVD	no	no	57	GC3	no	no
18	NOV	no	type I	58	CHIB	no	no
19	NOVD	no	Type I	59	AGIDL	yes	type III
20	CF	yes	type I	60	AGIDLD	yes	type III
21	CFB	no	no	61	BGIDL	no	no
22	BETN	yes	type III	62	BGIDLD	no	no
23	STBET	yes	type I	63	STBGIDL	no	no
24	MUE	yes	type I	64	STBGIDLD	no	no
25	STMUE	no	no	65	CGIDL	no	no
26	THEMU	no	no	66	CGIDLD	no	no
27	STTHEMU	no	no	67	COX	yes	type II
28	CS	yes	type I	68	CGOV	yes	type III
29	STCS	no	no	69	CGOVD	yes	type III
30	XCOR	yes	type I	70	CGBOV	yes	type II
31	STXCOR	no	no	71	CFR	yes	type III
32	FETA	no	no	72	CFRD	yes	type III
33	RS	yes	type I	73	FNT	no	no
34	STRS	no	no	74	NFA	yes	type I
35	RSB	no	no	75	NFB	yes	type I
36	RSG	no	no	76	NFC	yes	type I
37	THESAT	yes	type I	77	EF	no	no
38	STTHESAT	yes	type I	78	DTA	no	no
39	THESATB	no	type I				

Effective length and width

$$L_{\rm EN} = 10^{-6} \tag{3.108}$$

$$W_{\rm EN} = 10^{-6} \tag{3.109}$$

$$\Delta L_{\rm PS} = \mathbf{LVARO} \cdot \left(1 + \mathbf{LVARL} \cdot \frac{L_{\rm EN}}{L} \right)$$
 (3.110)

$$\Delta W_{\rm OD} = \mathbf{WVARO} \cdot \left(1 + \mathbf{WVARW} \cdot \frac{W_{\rm EN}}{W_{\rm f}} \right)$$
 (3.111)

$$L_{\rm E} = L - \Delta L = L + \Delta L_{\rm PS} - 2 \cdot \mathbf{LAP}$$
(3.112)

$$W_{\rm E} = W_{\rm f} - \Delta W = W_{\rm f} + \Delta W_{\rm OD} - 2 \cdot \mathbf{WOT}$$
(3.113)

$$L_{\text{E,CV}} = L + \Delta L_{\text{PS}} - 2 \cdot \mathbf{LAP} + \mathbf{DLQ}$$
(3.114)

$$W_{E,CV} = W_f + \Delta W_{OD} - 2 \cdot WOT + DWQ$$
 (3.115)

$$L_{G,CV} = L + \Delta L_{PS} + \mathbf{DLQ} \tag{3.116}$$

$$W_{G,CV} = W_f + \Delta W_{OD} + \mathbf{DWQ} \tag{3.117}$$

Note: If the calculated $L_{\rm E}$, $W_{\rm E}$, $L_{\rm E,CV}$, $W_{\rm E,CV}$, $L_{\rm G,CV}$, or $W_{\rm G,CV}$ is smaller than 1 nm (10⁻⁹ m), the value is clipped to this lower bound of 1 nm.

Process Parameters

$$\mathbf{VFB} = \mathbf{POVFB} + \mathbf{PLVFB} \cdot \frac{L_{\mathrm{EN}}}{L_{\mathrm{E}}} + \mathbf{PWVFB} \cdot \frac{W_{\mathrm{EN}}}{W_{\mathrm{E}}} + \mathbf{PLWVFB} \cdot \frac{L_{\mathrm{EN}} \cdot W_{\mathrm{EN}}}{L_{\mathrm{E}} \cdot W_{\mathrm{E}}}$$
(3.118)

 $\mathbf{STVFB} = \mathbf{POSTVFB} + \mathbf{PLSTVFB} \cdot \frac{L_{\mathrm{EN}}}{L_{\mathrm{E}}}$

+ PWSTVFB
$$\cdot \frac{W_{\text{EN}}}{W_{\text{E}}}$$
 + PLWSTVFB $\cdot \frac{L_{\text{EN}} \cdot W_{\text{EN}}}{L_{\text{E}} \cdot W_{\text{E}}}$ (3.119)

$$TOX = POTOX (3.120)$$

$$EPSROX = POEPSROX (3.121)$$

$$\mathbf{NEFF} = \mathbf{PONEFF} + \mathbf{PLNEFF} \cdot \frac{L_{\mathrm{EN}}}{L_{\mathrm{E}}} + \mathbf{PWNEFF} \cdot \frac{W_{\mathrm{EN}}}{W_{\mathrm{E}}} + \mathbf{PLWNEFF} \cdot \frac{L_{\mathrm{EN}} \cdot W_{\mathrm{EN}}}{L_{\mathrm{E}} \cdot W_{\mathrm{E}}}$$
(3.122)

 $\mathbf{FACNEFFAC} = \mathbf{POFACNEFFAC} + \mathbf{PLFACNEFFAC} \cdot \frac{L_{\mathrm{EN}}}{L_{\mathrm{E}}}$

+ PWFACNEFFAC
$$\cdot \frac{W_{\text{EN}}}{W_{\text{E}}}$$
 + PLWFACNEFFAC $\cdot \frac{L_{\text{EN}} \cdot W_{\text{EN}}}{L_{\text{E}} \cdot W_{\text{E}}}$ (3.123)

 $\mathbf{GFACNUD} = \mathbf{POGFACNUD} + \mathbf{PLGFACNUD} \cdot \frac{L_{\mathrm{EN}}}{L_{\mathrm{E}}}$

+ PWGFACNUD ·
$$\frac{W_{\text{EN}}}{W_{\text{E}}}$$
 + PLWGFACNUD · $\frac{L_{\text{EN}} \cdot W_{\text{EN}}}{L_{\text{E}} \cdot W_{\text{E}}}$ (3.124)

$$VSBNUD = POVSBNUD (3.125)$$

$$DVSBNUD = PODVSBNUD (3.126)$$

$$VNSUB = POVNSUB$$
 (3.127)

$$NSLP = PONSLP (3.128)$$

$$DNSUB = PODNSUB$$
 (3.129)

 $\mathbf{DPHIB} = \mathbf{PODPHIB} + \mathbf{PLDPHIB} \cdot \frac{L_{\mathrm{EN}}}{L_{\mathrm{E}}}$

+ PWDPHIB
$$\cdot \frac{W_{\text{EN}}}{W_{\text{E}}}$$
 + PLWDPHIB $\cdot \frac{L_{\text{EN}} \cdot W_{\text{EN}}}{L_{\text{E}} \cdot W_{\text{E}}}$ (3.130)

 $\mathbf{DELVTAC} = \mathbf{PODELVTAC} + \mathbf{PLDELVTAC} \cdot \frac{L_{\mathrm{EN}}}{L_{\mathrm{E}}}$

+ PWDELVTAC
$$\cdot \frac{W_{\rm EN}}{W_{\rm E}}$$
 + PLWDELVTAC $\cdot \frac{L_{\rm EN} \cdot W_{\rm EN}}{L_{\rm E} \cdot W_{\rm E}}$ (3.131)

$$\mathbf{NP} = \mathbf{PONP} + \mathbf{PLNP} \cdot \frac{L_{\mathrm{EN}}}{L_{\mathrm{E}}} + \mathbf{PWNP} \cdot \frac{W_{\mathrm{EN}}}{W_{\mathrm{E}}} + \mathbf{PLWNP} \cdot \frac{L_{\mathrm{EN}} \cdot W_{\mathrm{EN}}}{L_{\mathrm{E}} \cdot W_{\mathrm{E}}}$$
(3.132)

$$\mathbf{CT} = \mathbf{POCT} + \mathbf{PLCT} \cdot \frac{L_{\mathrm{EN}}}{L_{\mathrm{E}}} + \mathbf{PWCT} \cdot \frac{W_{\mathrm{EN}}}{W_{\mathrm{E}}} + \mathbf{PLWCT} \cdot \frac{L_{\mathrm{EN}} \cdot W_{\mathrm{EN}}}{L_{\mathrm{E}} \cdot W_{\mathrm{E}}}$$
(3.133)

$$TOXOV = POTOXOV (3.134)$$

$$TOXOVD = POTOXOVD (3.135)$$

$$\mathbf{NOV} = \mathbf{PONOV} + \mathbf{PLNOV} \cdot \frac{L_{\mathrm{EN}}}{L_{\mathrm{E}}} + \mathbf{PWNOV} \cdot \frac{W_{\mathrm{EN}}}{W_{\mathrm{E}}} + \mathbf{PLWNOV} \cdot \frac{L_{\mathrm{EN}} \cdot W_{\mathrm{EN}}}{L_{\mathrm{E}} \cdot W_{\mathrm{E}}}$$
(3.136)

$$\mathbf{NOVD} = \mathbf{PONOVD} + \mathbf{PLNOVD} \cdot \frac{L_{\mathrm{EN}}}{L_{\mathrm{E}}} + \mathbf{PWNOVD} \cdot \frac{W_{\mathrm{EN}}}{W_{\mathrm{E}}} + \mathbf{PLWNOVD} \cdot \frac{L_{\mathrm{EN}} \cdot W_{\mathrm{EN}}}{L_{\mathrm{E}} \cdot W_{\mathrm{E}}} \quad (3.137)$$

DIBL Parameters

$$\mathbf{CF} = \mathbf{POCF} + \mathbf{PLCF} \cdot \frac{L_{\mathrm{EN}}}{L_{\mathrm{E}}} + \mathbf{PWCF} \cdot \frac{W_{\mathrm{EN}}}{W_{\mathrm{E}}} + \mathbf{PLWCF} \cdot \frac{L_{\mathrm{EN}} \cdot W_{\mathrm{EN}}}{L_{\mathrm{E}} \cdot W_{\mathrm{E}}}$$
(3.138)

$$\mathbf{CFB} = \mathbf{POCFB} \tag{3.139}$$

Mobility Parameters

$$\begin{aligned} \mathbf{BETN} &= \frac{W_{\mathrm{E}}}{L_{\mathrm{E}}} \cdot \left(\mathbf{POBETN} + \mathbf{PLBETN} \cdot \frac{L_{\mathrm{EN}}}{L_{\mathrm{E}}} \right. \\ &+ \mathbf{PWBETN} \cdot \frac{W_{\mathrm{EN}}}{W_{\mathrm{E}}} + \mathbf{PLWBETN} \cdot \frac{L_{\mathrm{EN}} \cdot W_{\mathrm{EN}}}{L_{\mathrm{E}} \cdot W_{\mathrm{E}}} \right) \end{aligned} \tag{3.140}$$

(See Section 7.6.1 for an explanation of this binning rule.)

$$\mathbf{STBET} = \mathbf{POSTBET} + \mathbf{PLSTBET} \cdot \frac{L_{\mathrm{EN}}}{L_{\mathrm{E}}}$$

+ **PWSTBET**
$$\cdot \frac{W_{\text{EN}}}{W_{\text{E}}}$$
 + **PLWSTBET** $\cdot \frac{L_{\text{EN}} \cdot W_{\text{EN}}}{L_{\text{E}} \cdot W_{\text{E}}}$ (3.141)

$$\mathbf{MUE} = \mathbf{POMUE} + \mathbf{PLMUE} \cdot \frac{L_{\mathrm{EN}}}{L_{\mathrm{E}}} + \mathbf{PWMUE} \cdot \frac{W_{\mathrm{EN}}}{W_{\mathrm{E}}} + \mathbf{PLWMUE} \cdot \frac{L_{\mathrm{EN}} \cdot W_{\mathrm{EN}}}{L_{\mathrm{E}} \cdot W_{\mathrm{E}}}$$
(3.142)

$$STMUE = POSTMUE \tag{3.143}$$

$$THEMU = POTHEMU (3.144)$$

$$\mathbf{STTHEMU} = \mathbf{POSTTHEMU} \tag{3.145}$$

$$\mathbf{CS} = \mathbf{POCS} + \mathbf{PLCS} \cdot \frac{L_{\mathrm{EN}}}{L_{\mathrm{E}}} + \mathbf{PWCS} \cdot \frac{W_{\mathrm{EN}}}{W_{\mathrm{E}}} + \mathbf{PLWCS} \cdot \frac{L_{\mathrm{EN}} \cdot W_{\mathrm{EN}}}{L_{\mathrm{E}} \cdot W_{\mathrm{E}}}$$
(3.146)

$$STCS = POSTCS (3.147)$$

$$\mathbf{XCOR} = \mathbf{POXCOR} + \mathbf{PLXCOR} \cdot \frac{L_{\mathrm{EN}}}{L_{\mathrm{E}}} + \mathbf{PWXCOR} \cdot \frac{W_{\mathrm{EN}}}{W_{\mathrm{E}}} + \mathbf{PLWXCOR} \cdot \frac{L_{\mathrm{EN}} \cdot W_{\mathrm{EN}}}{L_{\mathrm{E}} \cdot W_{\mathrm{E}}} \quad (3.148)$$

$$STXCOR = POSTXCOR (3.149)$$

$$\mathbf{FETA} = \mathbf{POFETA} \tag{3.150}$$

Series Resistance Parameters

$$\mathbf{RS} = \mathbf{PORS} + \mathbf{PLRS} \cdot \frac{L_{\mathrm{EN}}}{L_{\mathrm{E}}} + \mathbf{PWRS} \cdot \frac{W_{\mathrm{EN}}}{W_{\mathrm{E}}} + \mathbf{PLWRS} \cdot \frac{L_{\mathrm{EN}} \cdot W_{\mathrm{EN}}}{L_{\mathrm{E}} \cdot W_{\mathrm{E}}}$$
(3.151)

$$STRS = POSTRS$$
 (3.152)

$$\mathbf{RSB} = \mathbf{PORSB} \tag{3.153}$$

$$RSG = PORSG \tag{3.154}$$

Velocity Saturation Parameters

 $\mathbf{THESAT} = \mathbf{POTHESAT} + \mathbf{PLTHESAT} \cdot \frac{L_{\mathrm{EN}}}{L_{\mathrm{E}}}$

$$+ \mathbf{PWTHESAT} \cdot \frac{W_{\mathrm{EN}}}{W_{\mathrm{E}}} + \mathbf{PLWTHESAT} \cdot \frac{L_{\mathrm{EN}} \cdot W_{\mathrm{EN}}}{L_{\mathrm{E}} \cdot W_{\mathrm{E}}} \quad (3.155)$$

 $\textbf{STTHESAT} = \textbf{POSTTHESAT} + \textbf{PLSTTHESAT} \cdot \frac{L_{\mathrm{EN}}}{L_{\mathrm{E}}}$

+ PWSTTHESAT ·
$$\frac{W_{\rm EN}}{W_{\rm E}}$$
 + PLWSTTHESAT · $\frac{L_{\rm EN} \cdot W_{\rm EN}}{L_{\rm E} \cdot W_{\rm E}}$ (3.156)

 $\mathbf{THESATB} = \mathbf{POTHESATB} + \mathbf{PLTHESATB} \cdot \frac{L_{\mathrm{EN}}}{L_{\mathrm{E}}}$

+ PWTHESATB
$$\cdot \frac{W_{\text{EN}}}{W_{\text{E}}}$$
 + PLWTHESATB $\cdot \frac{L_{\text{EN}} \cdot W_{\text{EN}}}{L_{\text{E}} \cdot W_{\text{E}}}$ (3.157)

 $\mathbf{THESATG} = \mathbf{POTHESATG} + \mathbf{PLTHESATG} \cdot \frac{L_{\mathrm{EN}}}{L_{\mathrm{E}}}$

+ PWTHESATG
$$\cdot \frac{W_{\text{EN}}}{W_{\text{E}}}$$
 + PLWTHESATG $\cdot \frac{L_{\text{EN}} \cdot W_{\text{EN}}}{L_{\text{E}} \cdot W_{\text{E}}}$ (3.158)

Saturation Voltage Parameters

$$\mathbf{AX} = \mathbf{POAX} + \mathbf{PLAX} \cdot \frac{L_{\text{EN}}}{L_{\text{E}}} + \mathbf{PWAX} \cdot \frac{W_{\text{EN}}}{W_{\text{E}}} + \mathbf{PLWAX} \cdot \frac{L_{\text{EN}} \cdot W_{\text{EN}}}{L_{\text{E}} \cdot W_{\text{E}}}$$
(3.159)

Channel Length Modulation (CLM) Parameters

$$\mathbf{ALP} = \mathbf{POALP} + \mathbf{PLALP} \cdot \frac{L_{\mathrm{EN}}}{L_{\mathrm{E}}} + \mathbf{PWALP} \cdot \frac{W_{\mathrm{EN}}}{W_{\mathrm{E}}} + \mathbf{PLWALP} \cdot \frac{L_{\mathrm{EN}} \cdot W_{\mathrm{EN}}}{L_{\mathrm{E}} \cdot W_{\mathrm{E}}}$$
(3.160)

$$\mathbf{ALP1} = \mathbf{POALP1} + \mathbf{PLALP1} \cdot \frac{L_{\mathrm{EN}}}{L_{\mathrm{E}}} + \mathbf{PWALP1} \cdot \frac{W_{\mathrm{EN}}}{W_{\mathrm{E}}} + \mathbf{PLWALP1} \cdot \frac{L_{\mathrm{EN}} \cdot W_{\mathrm{EN}}}{L_{\mathrm{E}} \cdot W_{\mathrm{E}}} \tag{3.161}$$

$$\mathbf{ALP2} = \mathbf{POALP2} + \mathbf{PLALP2} \cdot \frac{L_{\mathrm{EN}}}{L_{\mathrm{E}}} + \mathbf{PWALP2} \cdot \frac{W_{\mathrm{EN}}}{W_{\mathrm{E}}} + \mathbf{PLWALP2} \cdot \frac{L_{\mathrm{EN}} \cdot W_{\mathrm{EN}}}{L_{\mathrm{E}} \cdot W_{\mathrm{E}}}$$
(3.162)

$$\mathbf{VP} = \mathbf{POVP} \tag{3.163}$$

Impact Ionization (II) Parameters

$$\mathbf{A1} = \mathbf{POA1} + \mathbf{PLA1} \cdot \frac{L_{\text{EN}}}{L_{\text{E}}} + \mathbf{PWA1} \cdot \frac{W_{\text{EN}}}{W_{\text{E}}} + \mathbf{PLWA1} \cdot \frac{L_{\text{EN}} \cdot W_{\text{EN}}}{L_{\text{E}} \cdot W_{\text{E}}}$$
(3.164)

$$\mathbf{A2} = \mathbf{POA2} \tag{3.165}$$

$$STA2 = POSTA2 (3.166)$$

$$\mathbf{A3} = \mathbf{POA3} + \mathbf{PLA3} \cdot \frac{L_{\mathrm{EN}}}{L_{\mathrm{E}}} + \mathbf{PWA3} \cdot \frac{W_{\mathrm{EN}}}{W_{\mathrm{E}}} + \mathbf{PLWA3} \cdot \frac{L_{\mathrm{EN}} \cdot W_{\mathrm{EN}}}{L_{\mathrm{E}} \cdot W_{\mathrm{E}}}$$
(3.167)

$$\mathbf{A4} = \mathbf{POA4} + \mathbf{PLA4} \cdot \frac{L_{\mathrm{EN}}}{L_{\mathrm{E}}} + \mathbf{PWA4} \cdot \frac{W_{\mathrm{EN}}}{W_{\mathrm{E}}} + \mathbf{PLWA4} \cdot \frac{L_{\mathrm{EN}} \cdot W_{\mathrm{EN}}}{L_{\mathrm{E}} \cdot W_{\mathrm{E}}}$$
(3.168)

Gate Current Parameters

$$GCO = POGCO (3.169)$$

$$\mathbf{IGINV} = \mathbf{POIGINV} + \mathbf{PLIGINV} \cdot \frac{L_{\mathrm{E}}}{L_{\mathrm{EN}}}$$

+ PWIGINV
$$\cdot \frac{W_{\rm E}}{W_{\rm EN}}$$
 + PLWIGINV $\cdot \frac{L_{\rm E} \cdot W_{\rm E}}{L_{\rm EN} \cdot W_{\rm EN}}$ (3.170)

$$\mathbf{IGOV} = \mathbf{POIGOV} + \mathbf{PLIGOV} \cdot \frac{L_{\mathrm{EN}}}{L_{\mathrm{E}}} + \mathbf{PWIGOV} \cdot \frac{W_{\mathrm{E}}}{W_{\mathrm{EN}}} + \mathbf{PLWIGOV} \cdot \frac{W_{\mathrm{E}} \cdot L_{\mathrm{EN}}}{W_{\mathrm{EN}} \cdot L_{\mathrm{E}}}$$
(3.171)

$$\mathbf{IGOVD} = \mathbf{POIGOVD} + \mathbf{PLIGOVD} \cdot \frac{L_{\mathrm{EN}}}{L_{\mathrm{E}}}$$

$$+ \mathbf{PWIGOVD} \cdot \frac{W_{\mathrm{E}}}{W_{\mathrm{EN}}} + \mathbf{PLWIGOVD} \cdot \frac{W_{\mathrm{E}} \cdot L_{\mathrm{EN}}}{W_{\mathrm{EN}} \cdot L_{\mathrm{E}}} \quad (3.172)$$

$$STIG = POSTIG (3.173)$$

$$GC2 = POGC2 (3.174)$$

$$GC3 = POGC3 \tag{3.175}$$

$$\mathbf{CHIB} = \mathbf{POCHIB} \tag{3.176}$$

Gate-Induced Drain Leakage (GIDL) Parameters

$$\mathbf{AGIDL} = \mathbf{POAGIDL} + \mathbf{PLAGIDL} \cdot \frac{L_{\mathrm{EN}}}{L_{\mathrm{E}}}$$

+ PWAGIDL
$$\cdot \frac{W_{\rm E}}{W_{\rm EN}}$$
 + PLWAGIDL $\cdot \frac{W_{\rm E} \cdot L_{\rm EN}}{W_{\rm EN} \cdot L_{\rm E}}$ (3.177)

$$\mathbf{AGIDLD} = \mathbf{POAGIDLD} + \mathbf{PLAGIDLD} \cdot \frac{L_{\mathrm{EN}}}{I_{L_{\mathrm{EN}}}}$$

$$+ \mathbf{PWAGIDLD} \cdot \frac{W_{\mathrm{E}}}{W_{\mathrm{EN}}} + \mathbf{PLWAGIDLD} \cdot \frac{W_{\mathrm{E}} \cdot L_{\mathrm{EN}}}{W_{\mathrm{EN}} \cdot L_{\mathrm{E}}} \quad (3.178)$$

$$BGIDL = POBGIDL (3.179)$$

$$BGIDLD = POBGIDLD (3.180)$$

$$STBGIDL = POSTBGIDL (3.181)$$

$$STBGIDLD = POSTBGIDLD (3.182)$$

$$CGIDL = POCGIDL (3.183)$$

$$CGIDLD = POCGIDLD (3.184)$$

Charge Model Parameters

$$\mathbf{COX} = \mathbf{POCOX} + \mathbf{PLCOX} \cdot \frac{L_{\mathrm{E,CV}}}{L_{\mathrm{EN}}} + \mathbf{PWCOX} \cdot \frac{W_{\mathrm{E,CV}}}{W_{\mathrm{EN}}} + \mathbf{PLWCOX} \cdot \frac{L_{\mathrm{E,CV}} \cdot W_{\mathrm{E,CV}}}{L_{\mathrm{EN}} \cdot W_{\mathrm{EN}}}$$
(3.185)

$$\mathbf{CGOV} = \mathbf{POCGOV} + \mathbf{PLCGOV} \cdot \frac{L_{\mathrm{EN}}}{L_{\mathrm{E,CV}}}$$

+ **PWCGOV** ·
$$\frac{W_{\text{E,CV}}}{W_{\text{EN}}}$$
 + **PLWCGOV** · $\frac{W_{\text{E,CV}} \cdot L_{\text{EN}}}{W_{\text{EN}} \cdot L_{\text{E,CV}}}$ (3.186)

$$\mathbf{CGOVD} = \mathbf{POCGOVD} + \mathbf{PLCGOVD} \cdot \frac{L_{\mathrm{EN}}}{L_{\mathrm{E,CV}}}$$

$$+ \mathbf{PWCGOVD} \cdot \frac{W_{\mathrm{E,CV}}}{W_{\mathrm{EN}}} + \mathbf{PLWCGOVD} \cdot \frac{W_{\mathrm{E,CV}} \cdot L_{\mathrm{EN}}}{W_{\mathrm{EN}} \cdot L_{\mathrm{E,CV}}} \quad (3.187)$$

$$\mathbf{CGBOV} = \mathbf{POCGBOV} + \mathbf{PLCGBOV} \cdot \frac{L_{\mathrm{G,CV}}}{L_{\mathrm{EN}}}$$

+ **PWCGBOV** ·
$$\frac{W_{G,CV}}{W_{EN}}$$
 + **PLWCGBOV** · $\frac{L_{G,CV} \cdot W_{G,CV}}{L_{EN} \cdot W_{EN}}$ (3.188)

$$\mathbf{CFR} = \mathbf{POCFR} + \mathbf{PLCFR} \cdot \frac{L_{\mathrm{EN}}}{L_{\mathrm{G,CV}}} + \mathbf{PWCFR} \cdot \frac{W_{\mathrm{G,CV}}}{W_{\mathrm{EN}}} + \mathbf{PLWCFR} \cdot \frac{W_{\mathrm{G,CV}} \cdot L_{\mathrm{EN}}}{W_{\mathrm{EN}} \cdot L_{\mathrm{G,CV}}}$$
(3.189)

$$\mathbf{CFRD} = \mathbf{POCFRD} + \mathbf{PLCFRD} \cdot \frac{L_{\mathrm{EN}}}{L_{\mathrm{G,CV}}} + \mathbf{PWCFRD} \cdot \frac{W_{\mathrm{G,CV}}}{W_{\mathrm{EN}}} + \mathbf{PLWCFRD} \cdot \frac{W_{\mathrm{G,CV}} \cdot L_{\mathrm{EN}}}{W_{\mathrm{EN}} \cdot L_{\mathrm{G,CV}}} (3.190)$$

Noise Model Parameters

$$\mathbf{FNT} = \mathbf{POFNT} \tag{3.191}$$

$$\mathbf{NFA} = \mathbf{PONFA} + \mathbf{PLNFA} \cdot \frac{L_{\mathrm{EN}}}{L_{\mathrm{E}}} + \mathbf{PWNFA} \cdot \frac{W_{\mathrm{EN}}}{W_{\mathrm{E}}} + \mathbf{PLWNFA} \cdot \frac{L_{\mathrm{EN}} \cdot W_{\mathrm{EN}}}{L_{\mathrm{E}} \cdot W_{\mathrm{E}}}$$
(3.192)

$$\mathbf{NFB} = \mathbf{PONFB} + \mathbf{PLNFB} \cdot \frac{L_{\mathrm{EN}}}{L_{\mathrm{E}}} + \mathbf{PWNFB} \cdot \frac{W_{\mathrm{EN}}}{W_{\mathrm{E}}} + \mathbf{PLWNFB} \cdot \frac{L_{\mathrm{EN}} \cdot W_{\mathrm{EN}}}{L_{\mathrm{E}} \cdot W_{\mathrm{E}}}$$
(3.193)

$$\mathbf{NFC} = \mathbf{PONFC} + \mathbf{PLNFC} \cdot \frac{L_{\mathrm{EN}}}{L_{\mathrm{E}}} + \mathbf{PWNFC} \cdot \frac{W_{\mathrm{EN}}}{W_{\mathrm{E}}} + \mathbf{PLWNFC} \cdot \frac{L_{\mathrm{EN}} \cdot W_{\mathrm{EN}}}{L_{\mathrm{E}} \cdot W_{\mathrm{E}}}$$
(3.194)

$$\mathbf{EF} = \mathbf{POEF} \tag{3.195}$$

WPE parameters

$$K_{\rm vthowe} = \textbf{POKVTHOWE} + \textbf{PLKVTHOWE} \cdot \frac{L_{\rm EN}}{L_{\rm E}} + \textbf{PWKVTHOWE} \cdot \frac{W_{\rm EN}}{W_{\rm E}} \\ + \textbf{PLWKVTHOWE} \cdot \frac{L_{\rm EN} \cdot W_{\rm EN}}{L_{\rm E} \cdot W_{\rm E}} \quad (3.196)$$

$$K_{\text{uowe}} = \textbf{POKUOWE} + \textbf{PLKUOWE} \cdot \frac{L_{\text{EN}}}{L_{\text{E}}} + \textbf{PWKUOWE} \cdot \frac{W_{\text{EN}}}{W_{\text{E}}} \\ + \textbf{PLWKUOWE} \cdot \frac{L_{\text{EN}} \cdot W_{\text{EN}}}{L_{\text{E}} \cdot W_{\text{E}}} \quad (3.197)$$

3.4 Parasitic resistances

PSP model contains a network of parasitic elements: a gate resistance, two diffusion resistances for source and drain, and four bulk resistances. Note that the junction diodes are no longer directly connected to the bulk terminal of the intrinsic MOS-transistor. The complete circuit is shown in Fig. 3.2. At this moment, only the gate resistance is scaled with geometry (facilitating the implementation of multi-finger devices).

Note: The resistance equations are calculated when SWGEO = 1 or 2.

$$L_{\rm f} = L + \Delta L_{\rm PS} \tag{3.198}$$

$$L_{\rm sil,f} = L_{\rm f} + \mathbf{DLSIL} \tag{3.199}$$

$$W_{\rm E,f} = W_{\rm f} + \Delta W_{\rm OD} \tag{3.200}$$

$$X_{\text{GWE}} = \mathbf{XGW} - 0.5 \cdot \Delta W_{\text{OD}} \tag{3.201}$$

$$\mathbf{RG} = \mathbf{RGO} + \frac{1}{\mathbf{NF}} \cdot \left[\frac{\mathbf{RSHG} \cdot \left(\frac{W_{\mathrm{E,f}}}{3 \cdot \mathbf{NGCON}} + X_{\mathrm{GWE}} \right)}{\mathbf{NGCON} \cdot L_{\mathrm{sil,f}}} + \frac{\mathbf{RINT} + \mathbf{RVPOLY}}{W_{\mathrm{E,f}} \cdot L_{\mathrm{f}}} \right]$$
(3.202)

$$RSE = NRS \cdot RSH \tag{3.203}$$

$$RDE = NRD \cdot RSHD \tag{3.204}$$

$$\mathbf{RBULK} = \mathbf{RBULKO} \tag{3.205}$$

$$\mathbf{RWELL} = \mathbf{RWELLO} \tag{3.206}$$

$$RJUNS = RJUNSO (3.207)$$

$$RJUND = RJUNDO (3.208)$$

Note: The values of $L_{\rm f}$, $L_{\rm sil,f}$, $W_{\rm E,f}$ and $X_{\rm GWE}$ are clipped to a minimum value of 1 nm. The calculated local parameters are subject to the boundaries specified in Section 2.5.6.

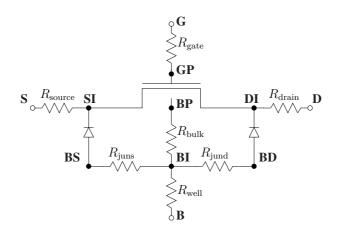


Figure 3.2: Parasitics circuit

3.5 Stress effects

The stress model of BSIM4.4.0 [3] has been adopted in PSP without any modifications, except for two changes: (1) in the original BSIM parameter names all zeros have been replaced by "O"s, in order to comply with PSP conventions and (2) the BSIM parameters *STK2* and *LODK2* are not available in PSP. Some trivial conversion of parameters BSIM→PSP is still necessary, see [2].

The local PSP parameters affected by the stress equations are BETN, THESAT, VFB, and CF.

Calculation of SA and SB for irregular layouts is given in Section B.1.

Note:

- After modification of the local parameters by the stress equations, clipping is applied according to Section 2.5.2.
- If both **SA** and **SB** are set to 0, the stress-equations are *not* computed.
- The stress equations are calculated when SWGEO = 1 or 2.

3.5.1 Layout effects for multi-finger devices

For multi-finger devices, effective values $SA_{\rm eff}$ and $SB_{\rm eff}$ for the instance parameters are calculated (see Fig. 3.3).

$$\frac{1}{\mathbf{SA}_{\text{eff}} + 0.5 \cdot L} = \frac{1}{\mathbf{NF}} \cdot \sum_{i=0}^{\mathbf{NF}-1} \frac{1}{\mathbf{SA} + 0.5 \cdot L + i \cdot (\mathbf{SD} + L)}$$
(3.209)

$$\frac{1}{\mathbf{SB}_{\text{eff}} + 0.5 \cdot L} = \frac{1}{\mathbf{NF}} \cdot \sum_{i=0}^{\mathbf{NF}-1} \frac{1}{\mathbf{SB} + 0.5 \cdot L + i \cdot (\mathbf{SD} + L)}$$
(3.210)

3.5.2 Layout effects for regular shapes

$$R_{\rm A} = \frac{1}{\mathbf{S}\mathbf{A}_{\rm eff} + 0.5 \cdot L} \tag{3.211}$$

$$R_{\rm B} = \frac{1}{\mathbf{SB}_{\rm eff} + 0.5 \cdot L} \tag{3.212}$$

$$R_{\text{A,ref}} = \frac{1}{\text{SAREF} + 0.5 \cdot L} \tag{3.213}$$

$$R_{\text{B,ref}} = \frac{1}{\text{SBREF} + 0.5 \cdot L} \tag{3.214}$$

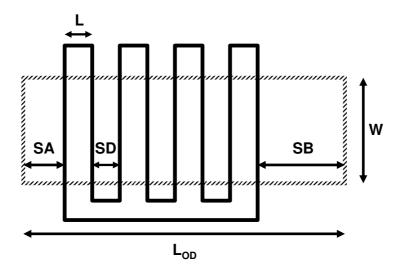


Figure 3.3: A typical layout of multi-finger devices with an additional instance parameters SD.

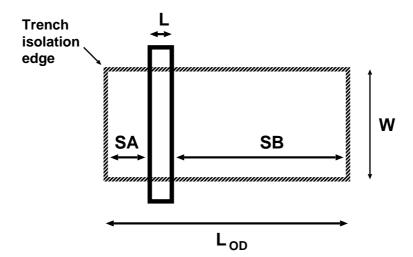


Figure 3.4: Typical layout of a MOSFET. Note that $L_{\rm OD} = {\bf SA} + {\bf SB} + L$, where OD is the active region definition.

3.5.3 Parameter modifications

Mobility-related equations

$$K_{\rm u0} = \left(1 + \frac{\mathbf{LKUO}}{\left(L + \Delta L_{\rm PS}\right)^{\mathbf{LLODKUO}}} + \frac{\mathbf{WKUO}}{\left(W_{\rm f} + \Delta W_{\rm OD} + \mathbf{WLOD}\right)^{\mathbf{WLODKUO}}} + \frac{\mathbf{PKUO}}{\left(L + \Delta L_{\rm PS}\right)^{\mathbf{LLODKUO}} \cdot \left(W_{\rm f} + \Delta W_{\rm OD} + \mathbf{WLOD}\right)^{\mathbf{WLODKUO}}}\right) \cdot \left[1 + \mathbf{TKUO} \cdot \left(\frac{T_{\rm KD}}{T_{\rm KR}} - 1\right)\right] \quad (3.215)$$

$$\rho_{\beta} = \frac{\mathbf{KUO}}{K_{\text{no}}} \cdot (R_{\text{A}} + R_{\text{B}}) \tag{3.216}$$

$$\rho_{\beta,\text{ref}} = \frac{\text{KUO}}{K_{\text{n0}}} \cdot (R_{\text{A,ref}} + R_{\text{B,ref}})$$
(3.217)

$$\mathbf{BETN} = \frac{1 + \rho_{\beta}}{1 + \rho_{\beta \text{ ref}}} \cdot \mathbf{BETN}_{\text{ref}}$$
(3.218)

$$\mathbf{THESAT} = \frac{1 + \rho_{\beta}}{1 + \rho_{\beta, ref}} \cdot \frac{1 + \mathbf{KVSAT} \cdot \rho_{\beta, ref}}{1 + \mathbf{KVSAT} \cdot \rho_{\beta}} \cdot \mathbf{THESAT}_{ref}$$
(3.219)

Threshold-voltage-related equations

$$K_{\rm vth0} = 1 + \frac{\textbf{LKVTHO}}{\left(L + \Delta L_{\rm PS}\right)^{\textbf{LLODVTH}}} + \frac{\textbf{WKVTHO}}{\left(W_{\rm f} + \Delta W_{\rm OD} + \textbf{WLOD}\right)^{\textbf{WLODVTH}}} \\ + \frac{\textbf{PKVTHO}}{\left(L + \Delta L_{\rm PS}\right)^{\textbf{LLODVTH}} \cdot \left(W_{\rm f} + \Delta W_{\rm OD} + \textbf{WLOD}\right)^{\textbf{WLODVTH}}} \quad (3.220)$$

$$\Delta R = R_{\rm A} + R_{\rm B} - R_{\rm A,ref} - R_{\rm B,ref} \tag{3.221}$$

$$\mathbf{VFB} = \mathbf{VFB}_{\text{ref}} + \mathbf{KVTHO} \cdot \frac{\Delta R}{K_{\text{vth0}}}$$
(3.222)

$$\mathbf{CF} = \mathbf{CF}_{ref} + \mathbf{STETAO} \cdot \frac{\Delta R}{K_{\text{vtb0}}^{\text{LODETAO}}}$$
(3.223)

3.6 Well proximity effects

The well proximity effect (WPE) model from BSIM4.5.0 [4, 5, 6] has been adopted in PSP with two changes relative to BSIM4.5.0: (1) in the original BSIM parameter names all zeros have been replaced by 'O's in order to comply with PSP naming convention and (2) the BSIM parameter K2WE is not available in PSP. Except for some trivial conversion of parameters BSIM \rightarrow PSP [2], WPE parameters from BSIM can be used directly in PSP.

The local PSP parameters affected by the WPE equations are VFB and BETN.

How to calculate SCA, SCB, and SCC is shown in Section B.2.

Note:

- After modification of the local parameters by the WPE equations, clipping is applied according to Section 2.5.2.
- If SCA, SCB, SCC and SC are all set to 0, the WPE equations are *not* computed.
- The WPE equations are calculated when SWGEO = 1 or 2.

3.6.1 Parameters for pre-layout simulation

If SCA = SCB = SCC = 0 and SC > 0, SCA, SCB, and SCC will be computed from SC according to Eqs. (B.9)–(B.11), as shown below. Here, SC should be taken as the distance to the nearest well edge (see Fig. 3.5). If any of the parameters SCA, SCB, or SCC is positive, all three values as supplied will be used and SC will be ignored.

If SCA = SCB = SCC = 0 and SC > 0

$$\mathbf{SCA} = \frac{\mathbf{SCREF}^2}{W_{\mathrm{f}}} \cdot \left(\frac{1}{\mathbf{SC}} - \frac{1}{\mathbf{SC} + W_{\mathrm{f}}}\right)$$
(3.224)

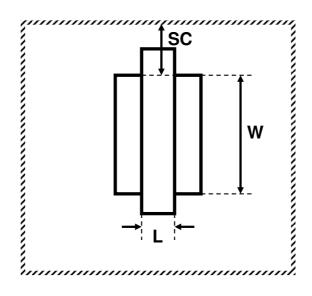


Figure 3.5: A layout of MOS devices for pre-layout simulation using estimated value for SC.

$$\begin{aligned} \mathbf{SCB} &= \frac{1}{W_{\mathrm{f}} \cdot \mathbf{SCREF}} \cdot \left[\frac{\mathbf{SCREF}}{10} \cdot \mathbf{SC} \cdot \exp\left(-10 \cdot \frac{\mathbf{SC}}{\mathbf{SCREF}} \right) + \frac{\mathbf{SCREF}^2}{100} \cdot \exp\left(-10 \cdot \frac{\mathbf{SC}}{\mathbf{SCREF}} \right) \right. \\ &\left. - \frac{\mathbf{SCREF}}{10} \cdot (\mathbf{SC} + W_{\mathrm{f}}) \cdot \exp\left(-10 \cdot \frac{\mathbf{SC} + W_{\mathrm{f}}}{\mathbf{SCREF}} \right) \right. \\ &\left. - \frac{\mathbf{SCREF}^2}{100} \cdot \exp\left(-10 \cdot \frac{\mathbf{SC} + W_{\mathrm{f}}}{\mathbf{SCREF}} \right) \right] \quad (3.225) \\ \mathbf{SCC} &= \frac{1}{W_{\mathrm{f}} \cdot \mathbf{SCREF}} \cdot \left[\frac{\mathbf{SCREF}}{20} \cdot \mathbf{SC} \cdot \exp\left(-20 \cdot \frac{\mathbf{SC}}{\mathbf{SCREF}} \right) + \frac{\mathbf{SCREF}^2}{400} \cdot \exp\left(-20 \cdot \frac{\mathbf{SC}}{\mathbf{SCREF}} \right) \right. \\ &\left. - \frac{\mathbf{SCREF}}{20} \cdot (\mathbf{SC} + W_{\mathrm{f}}) \cdot \exp\left(-20 \cdot \frac{\mathbf{SC} + W_{\mathrm{f}}}{\mathbf{SCREF}} \right) \right. \end{aligned}$$

$$-\frac{\mathbf{SCREF}^2}{400} \cdot \exp\left(-20 \cdot \frac{\mathbf{SC} + W_{\mathrm{f}}}{\mathbf{SCREF}}\right) \right] \quad (3.226)$$

3.6.2 Calculation of parameter modifications

The calculation of K_{vthowe} and K_{uowe} is given in Section 3.2 (global model) or 3.3 (binning model).

$$VFB = VFB_{ref} + K_{vthowe} \cdot (SCA + WEB \cdot SCB + WEC \cdot SCC)$$
(3.227)

$$BETN = BETN_{ref} \cdot [1 + K_{uowe} \cdot (SCA + WEB \cdot SCB + WEC \cdot SCC)]$$
(3.228)

3.7 Asymmetric junctions

From PSP 102.3 onwards, asymmetric junction can be modeled in PSP. This includes asymmetric source-bulk and drain-bulk junctions, GIDL/GISL, overlap gate currents, overlap capacitances and outer fringe capacitances. The asymmetric junction model can be switched on by means of the parameter SWJUNASYM. Note that if SWJUNASYM = 1, the new parameters for the drain side are used all together. Those whose values are not explicitly specified in the model card are set to their default value, *not* to their counterparts for the source side. In other words, it is not possible to activate the parameters for the drain side on a one-by-one basis. The physical scaling and binning rules to calculate the related local parameters for the drain side are given in Section 3.2 and 3.3.

If $\mathbf{SWJUNASYM} = 0$, the related parameters for the drain side are ignored. Effectively, the following assignments are applied before evaluation of the calculations described in Section 4.

If SWJUNASYM = 0:

TOXOVD = TOXOV	(3.229)
NOVD = NOV	(3.230)
$\mathbf{AGIDLD} = \mathbf{AGIDL}$	(3.231)
$\mathbf{BGIDLD} = \mathbf{BGIDL}$	(3.232)
$\mathbf{STBGIDLD} = \mathbf{STBGIDL}$	(3.233)
CGIDLD = CGIDL	(3.234)
$\mathbf{IGOVD} = \mathbf{IGOV}$	(3.235)
CGOVD = CGOV	(3.236)
CFRD = CFR	(3.237)
RSHD = RSH	(3.238)

Section 4

PSP Model Equations

4.1 Internal Parameters (including Temperature Scaling)

In this section, bias-independent internal parameters will be calculated, including temperature scaling. These parameters are computed from local parameters. Local parameters are (as usual) denoted by capital characters in bold font, whereas the internal parameters are denoted by symbols in bold font.

Transistor temperature

$$T_{\rm KR} = T_0 + \mathbf{TR} \tag{4.1}$$

$$T_{\rm KD} = T_0 + T_{\rm A} + \mathbf{DTA} \tag{4.2}$$

$$\Delta T = T_{\rm KD} - T_{\rm KR} \tag{4.3}$$

$$\phi_{\mathbf{T}} = \frac{k_{\mathbf{B}} \cdot T_{\mathbf{KD}}}{q} \tag{4.4}$$

Local process parameters

$$\phi_{\mathbf{T}}^* = \phi_{\mathbf{T}} \cdot \left(1 + \mathbf{C} \mathbf{T} \cdot \frac{T_{KR}}{T_{KD}} \right) \tag{4.5}$$

$$V_{FB} = VFB + STVFB \cdot \Delta T + DELVTO$$
(4.6)

$$E_{\rm g}/q = 1.179 - 9.025 \cdot 10^{-5} \cdot T_{\rm KD} - 3.05 \cdot 10^{-7} \cdot T_{\rm KD}^{2}$$
 (4.7)

$$r_{\rm T} = (1.045 + 4.5 \cdot 10^{-4} \cdot T_{\rm KD}) \cdot (0.523 + 1.4 \cdot 10^{-3} \cdot T_{\rm KD} - 1.48 \cdot 10^{-6} \cdot T_{\rm KD}^{2})$$
(4.8)

$$n_{\rm i} = 2.5 \cdot 10^{25} \cdot r_{\rm T}^{3/4} \cdot (T_{\rm KD}/300)^{3/2} \cdot \exp\left(-\frac{E_{\rm g}/q}{2 \cdot \phi_{\rm T}}\right)$$
 (4.9)

$$\phi_{\mathrm{B,dc}}^{\mathrm{cl}} = \mathrm{MAX} \left(\mathbf{DPHIB} + 2 \cdot \phi_{\mathbf{T}} \cdot \ln \left[\mathbf{NEFF} / n_{i} \right], \ 0.05 \right)$$

$$(4.10)$$

$$N_{\text{eff,ac}} = \text{MIN}[\text{MAX}(\textbf{FACNEFFAC} \cdot \textbf{NEFF}, 10^{20}), 10^{26}]$$
(4.11)

$$\phi_{\mathrm{B,ac}}^{\mathrm{cl}} = \mathrm{MAX} \left(\mathbf{DPHIB} + \mathbf{DELVTAC} + 2 \cdot \phi_{\mathbf{T}} \cdot \ln \left[N_{\mathrm{eff,ac}} / n_{\mathrm{i}} \right], 0.05 \right)$$
(4.12)

$$\epsilon_{\text{ox}} = \mathbf{EPSROX} \cdot \epsilon_0 \tag{4.13}$$

$$C_{\rm ox} = \epsilon_{\rm ox}/{\rm TOX}$$
 (4.14)

$$\epsilon_{\rm Si} = \epsilon_{\rm r,Si} \cdot \epsilon_0 \tag{4.15}$$

$$\gamma_{0,\mathrm{dc}} = \sqrt{2 \cdot q \cdot \epsilon_{\mathrm{Si}} \cdot \mathbf{NEFF}} / C_{\mathrm{ox}}$$
 (4.16)

$$\gamma_{0,\mathrm{ac}} = \sqrt{2 \cdot q \cdot \epsilon_{\mathrm{Si}} \cdot N_{\mathrm{eff,ac}}} / C_{\mathrm{ox}}$$
 (4.17)

$$G_{0,\mathrm{dc}}^{\mathrm{cl}} = \gamma_{0,\mathrm{dc}} / \sqrt{\phi_{\mathrm{T}}} \tag{4.18}$$

$$G_{0,\mathrm{ac}}^{\mathrm{cl}} = \gamma_{0,\mathrm{ac}} / \sqrt{\phi_{\mathrm{T}}} \tag{4.19}$$

Polysilicon depletion parameter

$$\mathbf{k}_{\mathbf{P}} = \begin{cases} \text{if } \mathbf{NP} = 0 & \begin{cases} \mathbf{k}_{\mathbf{P}} = 0 \\ \\ \text{NP}_{1} = \text{MAX}(\mathbf{NP}, 8 \cdot 10^{7} / \mathbf{TOX}^{2}) \end{cases} \\ \text{NP}_{2} = \text{MAX}(\text{NP}_{1}, 5 \cdot 10^{24}) \\ \mathbf{k}_{\mathbf{P}} = 2 \cdot \phi_{\mathbf{T}} \cdot C_{\text{ox}}^{2} / (q \cdot \epsilon_{\text{Si}} \cdot \text{NP}_{2}) \end{cases}$$

$$(4.20)$$

Quantum-mechanical correction parameters

$$q_{\lim} = 10 \cdot \phi_{\mathrm{T}} \tag{4.21}$$

$$\boldsymbol{q}_{\mathbf{q}} = \left\{ \begin{array}{ll} 0.4 \cdot \mathbf{QMC} \cdot Q\boldsymbol{M}_{\mathrm{N}} \cdot \boldsymbol{C}_{\mathrm{ox}}^{2/3} & \text{for NMOS} \\ \\ 0.4 \cdot \mathbf{QMC} \cdot Q\boldsymbol{M}_{\mathrm{P}} \cdot \boldsymbol{C}_{\mathrm{ox}}^{2/3} & \text{for PMOS} \end{array} \right. \tag{4.22}$$

$$q_{\text{b0,dc}} = \gamma_{\text{0,dc}} \cdot \sqrt{\phi_{\text{B,dc}}^{\text{cl}}} \tag{4.23}$$

$$q_{\rm b0,ac} = \gamma_{\rm 0,ac} \cdot \sqrt{\phi_{\rm B,ac}^{\rm cl}} \tag{4.24}$$

$$\phi_{\mathbf{B}, dc} = \phi_{\mathrm{B}, dc}^{\mathrm{cl}} + 0.75 \cdot q_{\mathbf{q}} \cdot q_{\mathrm{b0}, dc}^{2/3}$$
 (4.25)

$$\phi_{\mathbf{B},\mathrm{ac}} = \phi_{\mathbf{B},\mathrm{ac}}^{\mathrm{cl}} + 0.75 \cdot \mathbf{q}_{\mathbf{q}} \cdot q_{\mathrm{b0,ac}}^{2/3} \tag{4.26}$$

$$\boldsymbol{G_{0,\mathrm{dc}}} = G_{0,\mathrm{dc}}^{\mathrm{cl}} \cdot \left(1 + \boldsymbol{q_{q}} \cdot q_{\mathrm{b0,dc}}^{-1/3} \right) \tag{4.27}$$

$$\boldsymbol{G}_{0,\mathrm{ac}} = G_{0,\mathrm{ac}}^{\mathrm{cl}} \cdot \left(1 + \boldsymbol{q}_{\mathbf{q}} \cdot q_{\mathrm{b0,ac}}^{-1/3} \right) \tag{4.28}$$

$V_{\mathrm{SB}} ext{-clipping parameters}$

$$\phi_{\mathbf{X},\mathrm{dc}} = 0.95 \cdot \phi_{\mathbf{B},\mathrm{dc}} \tag{4.29}$$

$$\phi_{\mathbf{X},\mathrm{ac}} = 0.95 \cdot \phi_{\mathbf{B},\mathrm{ac}} \tag{4.30}$$

$$\boldsymbol{a}_{\phi,\mathrm{dc}} = 2.5 \cdot 10^{-3} \cdot \boldsymbol{\phi}_{\mathbf{B},\mathrm{dc}}^2 \tag{4.31}$$

$$\boldsymbol{a}_{\phi,\mathrm{ac}} = 2.5 \cdot 10^{-3} \cdot \boldsymbol{\phi}_{\mathbf{B},\mathrm{ac}}^2 \tag{4.32}$$

$$\boldsymbol{b}_{\phi,\mathrm{dc}} = 2.5 \cdot 10^{-3} \cdot \boldsymbol{\phi}_{\mathbf{B},\mathrm{dc}}^2 \tag{4.33}$$

$$\boldsymbol{b}_{\phi, ac} = 2.5 \cdot 10^{-3} \cdot \phi_{\mathbf{B}, ac}^2$$
 (4.34)

$$\phi_{\mathbf{X}.\mathrm{dc}}^{\star} = 0.5 \cdot \sqrt{b_{\phi.\mathrm{dc}}} \tag{4.35}$$

$$\phi_{\mathbf{X},\mathrm{ac}}^{\star} = 0.5 \cdot \sqrt{b_{\phi,\mathrm{ac}}} \tag{4.36}$$

$$\phi_{\mathbf{X},dc}^* = \text{MINA} \left(\phi_{\mathbf{X},dc} - \phi_{\mathbf{X},dc}^{\star}, 0, \mathbf{a}_{\phi,dc} \right)$$
(4.37)

$$\phi_{\mathbf{X},\mathrm{ac}}^* = \mathrm{MINA} \left(\phi_{\mathbf{X},\mathrm{ac}} - \phi_{\mathbf{X},\mathrm{ac}}^{\star}, 0, \mathbf{a}_{\phi,\mathrm{ac}} \right)$$

$$(4.38)$$

NUD parameters

$$\mathbf{u_{s1}} = \sqrt{\mathbf{VSBNUD} + \phi_{\mathbf{B}}} - \sqrt{\phi_{\mathbf{B}}} \tag{4.39}$$

$$\mathbf{u_{s21}} = \sqrt{\mathbf{DVSBNUD} + \phi_{\mathbf{B}}} - \sqrt{\phi_{\mathbf{B}}} - \mathbf{u_{s1}} \tag{4.40}$$

Local process parameters in gate overlap regions

$$\gamma_{\rm ov} = \sqrt{2 \cdot q \cdot \epsilon_{\rm Si} \cdot \text{NOV}} \cdot \text{TOXOV} / \epsilon_{\rm ox}$$
(4.41)

$$\gamma_{\text{dov}} = \sqrt{2 \cdot q \cdot \epsilon_{\text{Si}} \cdot \text{NOVD}} \cdot \text{TOXOVD} / \epsilon_{\text{ox}}$$
 (4.42)

$$G_{\rm ov} = \gamma_{\rm ov} / \sqrt{\phi_{\rm T}} \tag{4.43}$$

$$G_{
m dov} = \gamma_{
m dov} / \sqrt{\phi_{
m T}}$$
 (4.44)

$$\boldsymbol{\xi_{\text{ov}}} = 1 + \boldsymbol{G_{\text{ov}}} / \sqrt{2} \tag{4.45}$$

$$\boldsymbol{\xi_{\text{dov}}} = 1 + \boldsymbol{G_{\text{dov}}} / \sqrt{2} \tag{4.46}$$

$$\boldsymbol{x}_{\text{mrgov}} = 10^{-5} \cdot \boldsymbol{\xi}_{\text{ov}} \tag{4.47}$$

$$x_{\text{mrgdov}} = 10^{-5} \cdot \xi_{\text{dov}} \tag{4.48}$$

Mobility parameters

$$\beta = \text{FACTUO} \cdot \text{BETN} \cdot C_{\text{ox}} \cdot (T_{\text{KR}}/T_{\text{KD}})^{\text{STBET}}$$
(4.49)

$$\theta_{\mu} = \text{THEMU} \cdot (T_{\text{KR}}/T_{\text{KD}})^{\text{STTHEMU}}$$
 (4.50)

$$\mu_{\rm E} = {\rm MUE} \cdot (T_{\rm KR}/T_{\rm KD})^{\rm STMUE} \tag{4.51}$$

$$X_{\text{cor}} = XCOR \cdot (T_{KR}/T_{KD})^{STXCOR}$$
 (4.52)

$$C_{S} = CS \cdot (T_{KR}/T_{KD})^{STCS}$$
(4.53)

$$\boldsymbol{E}_{\text{eff0}} = 10^{-8} \cdot C_{\text{ox}} / \epsilon_{\text{Si}} \tag{4.54}$$

$$\boldsymbol{\eta_{\mu}} = \begin{cases} 1/2 \cdot \mathbf{FETA} & \text{for NMOS} \\ \\ 1/3 \cdot \mathbf{FETA} & \text{for PMOS} \end{cases}$$
 (4.55)

$$\eta_{\mu,\mathrm{ac}} = \begin{cases}
1/2 & \text{for NMOS} \\
1/3 & \text{for PMOS}
\end{cases}$$
(4.56)

Series resistance parameter

$$R_{\rm s} = \mathbf{RS} \cdot (T_{\rm KR}/T_{\rm KD})^{\rm STRS} \tag{4.57}$$

$$\theta_{\mathbf{R}} = 2 \cdot \boldsymbol{\beta} \cdot R_{s} \tag{4.58}$$

Velocity saturation parameter

$$\theta_{\text{sat}} = \text{THESAT} \cdot (T_{\text{KR}}/T_{\text{KD}})^{\text{STTHESAT}}$$
 (4.59)

Impact-ionization parameter

$$a_2 = \mathbf{A2} \cdot (T_{\mathrm{KD}}/T_{\mathrm{KR}})^{\mathbf{STA2}} \tag{4.60}$$

Gate current parameters

$$I_{\text{GINV}} = \text{IGINV} \cdot (T_{\text{KD}}/T_{\text{KR}})^{\text{STIG}}$$
 (4.61)

$$I_{\text{GOV}} = \text{IGOV} \cdot (T_{\text{KD}}/T_{\text{KR}})^{\text{STIG}}$$
 (4.62)

$$I_{\text{GOVD}} = I\text{GOVD} \cdot (T_{\text{KD}}/T_{\text{KR}})^{\text{STIG}}$$
 (4.63)

$$B = \frac{4}{3} \cdot \frac{\mathbf{TOX}}{\hbar} \cdot \sqrt{2 \cdot q \cdot m_0 \cdot \mathbf{CHIB}} = 6.830909 \cdot 10^9 \cdot \mathbf{TOX} \cdot \sqrt{\mathbf{CHIB}}$$
(4.64)

$$B_{ov} = B \cdot TOXOV/TOX \tag{4.65}$$

$$B_{\text{ovd}} = B \cdot \text{TOXOVD/TOX} \tag{4.66}$$

$$GC_{\mathbf{Q}} = \begin{cases} -0.99 \cdot \frac{\mathbf{GC2}}{2 \cdot \mathbf{GC3}} & \text{for } \mathbf{GC3} < 0 \\ 0 & \text{for } \mathbf{GC3} \ge 0 \end{cases}$$

$$(4.67)$$

$$\alpha_{\mathbf{b}} = \frac{E_{\mathbf{g}}/q + \phi_{\mathbf{B}}}{2} \tag{4.68}$$

$$D_{\rm ch} = {\rm GCO} \cdot \phi_{\rm T}^* \tag{4.69}$$

$$D_{ov} = GCO \cdot \phi_{T} \tag{4.70}$$

Gate-induced drain leakage parameters

$$A_{GIDL} = AGIDL \cdot \left(\frac{2 \cdot 10^{-9}}{TOXOV}\right)^2 \tag{4.71}$$

$$A_{GIDLD} = AGIDLD \cdot \left(\frac{2 \cdot 10^{-9}}{TOXOVD}\right)^{2}$$
(4.72)

$$\boldsymbol{B_{\text{GIDL}}} = \mathbf{BGIDL} \cdot \text{MAX} \left(\left[1 + \mathbf{STBGIDL} \cdot \Delta T \right], 0 \right) \cdot \left(\frac{\mathbf{TOXOV}}{2 \cdot 10^{-9}} \right)$$
(4.73)

$$\boldsymbol{B_{\text{GIDLD}}} = \mathbf{BGIDLD} \cdot \text{MAX} \left(\left[1 + \mathbf{STBGIDLD} \cdot \Delta T \right], 0 \right) \cdot \left(\frac{\mathbf{TOXOVD}}{2 \cdot 10^{-9}} \right)$$
(4.74)

Noise parameter

$$N_{\rm T} = FNT \cdot 4 \cdot k_{\rm B} \cdot T_{\rm KD} \tag{4.75}$$

Additional internal parameters

$$x_1 = 1.25$$
 (4.76)

$$x_{g1} = x_1 + G_{ov} \cdot \sqrt{\exp(-x_1) + x_1 - 1}$$
 (4.77)

$$x_{\text{dg1}} = x_1 + G_{\text{dov}} \cdot \sqrt{\exp(-x_1) + x_1 - 1}$$
 (4.78)

4.2 Current Model

In this section, the current model equations of the PSP-model are given. Use is made of the applied terminal bias values $V_{\rm GS}$, $V_{\rm DS}$ and $V_{\rm SB}$, the local parameters listed in Section 2.5.2 and the internal parameters introduced in Section 4.1. Local parameters are denoted by capital characters in bold font, whereas internal (bias-independent) parameters are denoted by symbols in bold font.

The definitions of the auxiliary functions MINA(.), MAXA(.), $\chi(.)$ and $\sigma_{1,2}(.)$ can be found in Appendix A.

Depending on the value of the parameters **SWNUD** and **SWDELVTAC**, the surface potential (at source- and drain-side of the channel) and associated computations, i.e., Eqs. (4.91)–(4.182), may be evaluated twice: once for the dc-characteristics and a second time for the ac-characteristics of the model. Details are given below.

4.2.1 Conditioning of Terminal Voltages

$$V_{\rm dsx} = \sqrt{V_{\rm DS}^2 + 0.01} - 0.1 \tag{4.79}$$

$$\phi_{V,dc} = MINA (V_{SB}, V_{SB} + V_{DS}, \boldsymbol{b}_{\phi,dc}) + \phi_{\boldsymbol{X}.dc}$$

$$(4.80)$$

$$\phi_{V,ac} = MINA (V_{SB}, V_{SB} + V_{DS}, \boldsymbol{b}_{\boldsymbol{\phi},ac}) + \boldsymbol{\phi}_{\mathbf{X} ac}$$

$$(4.81)$$

$$V_{\mathrm{SB,dc}}^* = V_{\mathrm{SB}} - \mathrm{MINA}\left(\phi_{\mathrm{V}}, 0, \boldsymbol{a}_{\boldsymbol{\phi}, \mathrm{dc}}\right) + \boldsymbol{\phi}_{\mathbf{X}, \mathrm{dc}}^*$$

$$(4.82)$$

$$V_{\text{SB ac}}^* = V_{\text{SB}} - \text{MINA} \left(\phi_{\text{V}}, 0, \boldsymbol{a}_{\boldsymbol{\phi}, \text{ac}}\right) + \boldsymbol{\phi}_{\mathbf{X} \text{ ac}}^*$$

$$(4.83)$$

Nonuniform doping effect. Eqs. (4.84)–(4.90) are only evaluated when **SWNUD** \neq 0 and **GFACNUD** \neq 1:

$$V_{\rm mB} = V_{\rm SB}^* + 0.5 \cdot (V_{\rm DS} - V_{\rm dsx}) \tag{4.84}$$

$$u_{\rm s} = \sqrt{V_{\rm mB} + \phi_{\rm R}} - \sqrt{\phi_{\rm R}} \tag{4.85}$$

$$p = 2 \cdot \frac{u_{\mathrm{s}} - \mathbf{u}_{\mathrm{s}1}}{\mathbf{u}_{\mathrm{s}21}} - 1 \tag{4.86}$$

$$u_{\text{s,nud}} = u_{\text{s}} - 0.25 \cdot (1 - \text{GFACNUD}) \cdot \mathbf{u_{s21}} \cdot \left\{ p + \sqrt{p^2 + [\ln(2)]^2} \right\}$$
 (4.87)

$$V_{\rm mB,nud} = \left(u_{\rm s,nud} + 2 \cdot \sqrt{\phi_{\rm B}}\right) \cdot u_{\rm s,nud} \tag{4.88}$$

$$V_{\rm SB}^{\rm nud} = V_{\rm mB, nud} - 0.5 \cdot (V_{\rm DS} - V_{\rm dsx})$$
 (4.89)

$$V_{\rm SB,dc}^* = V_{\rm SB}^{\rm nud} \tag{4.90}$$

The surface potential (at source- and drain-side of the channel) and associated computations, i.e., Eqs. (4.91)–(4.182), are evaluated using $V_{\rm SB}^* = V_{\rm SB,dc}^*$, $\phi_{\rm B} = \phi_{\rm B,dc}$, and $G_{\rm 0} = G_{\rm 0,dc}$.

If **SWNUD** = 1 or **SWDELVTAC** = 1, Eqs. (4.91)–(4.182) are evaluated a second time using $V_{\rm SB}^* = V_{\rm SB,ac}^*$, $\phi_{\rm B} = \phi_{\rm B,ac}$, and $G_0 = G_{0,ac}$.

$$V_{\rm DB}^* = V_{\rm DS} + V_{\rm SB}^* \tag{4.91}$$

$$V_{\rm sbx} = V_{\rm SB}^* + \frac{V_{\rm DS} - V_{\rm dsx}}{2} \tag{4.92}$$

Drain-induced barrier lowering:

$$\Delta V_{\rm G} = \mathbf{CF} \cdot V_{\rm dsx} \cdot (1 + \mathbf{CFB} \cdot V_{\rm sbx}) \tag{4.93}$$

$$V_{\rm GB}^* = V_{\rm GS} + V_{\rm SB}^* + \Delta V_{\rm G} - V_{\rm FB} \tag{4.94}$$

$$x_{\mathbf{g}} = V_{\mathbf{GB}}^* / \phi_{\mathbf{T}}^* \tag{4.95}$$

4.2.2 Bias-Dependent Body Factor

$$D_{\text{nsub}} = \mathbf{DNSUB} \cdot \text{MAXA}(0, V_{\text{GS}} + V_{\text{SB}} - \mathbf{VNSUB}, \mathbf{NSLP})$$
(4.96)

$$G = G_0 \cdot \sqrt{1 + D_{\text{nsub}}} \tag{4.97}$$

4.2.3 Surface Potential at Source Side and Related Variables

$$\xi = 1 + G/\sqrt{2} \tag{4.98}$$

$$x_{\rm ns} = \frac{\phi_{\rm B} + V_{\rm SB}^*}{\phi_{\rm T}^*} \tag{4.99}$$

$$\Delta_{\rm ns} = \exp\left(-x_{\rm ns}\right) \tag{4.100}$$

$$x_{\rm mrg} = 10^{-5} \cdot \xi \tag{4.101}$$

$$\begin{cases} y_{\rm g} = -x_{\rm g} \\ z = 1.25 \cdot y_{\rm g}/\xi \\ \eta = \left[z + 10 - \sqrt{(z - 6)^2 + 64}\right]/2 \\ a = (y_{\rm g} - \eta)^2 + G^2 \cdot (\eta + 1) \\ c = 2 \cdot (y_{\rm g} - \eta) - G^2 \\ \tau = -\eta + \ln\left(a/G^2\right) \\ y_0 = \sigma_1(a, c, \tau, \eta) \\ \Delta_0 = \exp\left(y_0\right) \\ p = 2 \cdot (y_{\rm g} - y_0) + G^2 \cdot \left[\Delta_0 - 1 + \Delta_{\rm ns} \cdot (1 - \chi'(y_0) - 1/\Delta_0)\right] \\ q = (y_{\rm g} - y_0)^2 + G^2 \cdot \left[y_0 - \Delta_0 + 1 + \Delta_{\rm ns} \cdot (1 + \chi(y_0) - 1/\Delta_0 - 2 \cdot y_0)\right] \\ x_{\rm s} = -y_0 - \frac{2 \cdot q}{p + \sqrt{p^2 - 2 \cdot q \cdot \{2 - G^2 \cdot [\Delta_0 + \Delta_{\rm ns} \cdot (1/\Delta_0 - \chi''(y_0))]\}} \end{cases}$$

if
$$|x_{\rm g}| \le x_{\rm mrg} \left\{ x_{\rm s} = \frac{x_{\rm g}}{\xi} \cdot \left[1 + G \cdot x_{\rm g} \cdot \frac{1 - \Delta_{\rm ns}}{\xi^2 \cdot 6 \cdot \sqrt{2}} \right] \right.$$
 (4.103)

$$\begin{cases} \hat{x}_{\text{g1}} = x_{\text{I}} + G \cdot \sqrt{\exp(-x_{\text{I}}) + x_{\text{I}} - 1} \\ \bar{x} = \frac{x_{\text{g}}}{\xi} \cdot \left[1 + x_{\text{g}} \cdot (\xi \cdot x_{\text{I}} - \hat{x}_{\text{g1}}) / \hat{x}_{\text{g1}}^2 \right] \\ x_0 = x_{\text{g}} + G^2 / 2 - G \cdot \sqrt{x_{\text{g}} + G^2 / 4 - 1 + \exp(-\bar{x})} \\ b_{\text{x}} = x_{\text{ns}} + 3 \\ \eta = \text{MINA}(x_0, b_{\text{x}}, 5) - \left(b_{\text{x}} - \sqrt{b_{\text{x}}^2 + 5} \right) / 2 \\ a = (x_{\text{g}} - \eta)^2 - G^2 \cdot \left[\exp(-\eta) + \eta - 1 - \Delta_{\text{ns}} \cdot (\eta + 1 + \chi(\eta)) \right] \\ b = 1 - G^2 / 2 \cdot \left[\exp(-\eta) - \Delta_{\text{ns}} \cdot \chi''(\eta) \right] \\ c = 2 \cdot (x_{\text{g}} - \eta) + G^2 \cdot \left[1 - \exp(-\eta) - \Delta_{\text{ns}} \cdot (1 + \chi'(\eta)) \right] \\ \tau = x_{\text{ns}} - \eta + \ln\left(a / G^2 \right) \\ y_0 = \sigma_2(a, b, c, \tau, \eta) \\ \Delta_0 = \exp\left(y_0 \right) \\ p = 2 \cdot (x_{\text{g}} - y_0) + G^2 \cdot \left[1 - 1 / \Delta_0 + \Delta_{\text{ns}} \cdot (\Delta_0 - 1 - \chi'(y_0)) \right] \\ q = (x_{\text{g}} - y_0)^2 - G^2 \cdot \left[y_0 + 1 / \Delta_0 - 1 + \Delta_{\text{ns}} \cdot (\Delta_0 - y_0 - 1 - \chi(y_0)) \right] \\ x_{\text{s}} = y_0 + \frac{2 \cdot q}{p + \sqrt{p^2 - 2 \cdot q} \cdot \left\{ 2 - G^2 \cdot \left[1 / \Delta_0 + \Delta_{\text{ns}} \cdot (\Delta_0 - \chi'''(y_0)) \right] \right\}} \\ \text{Eqs. (4.105)-(4.107) are only calculated for } x_{\text{g}} > 0. \end{cases}$$

Eqs. (4.105)-(4.107) are only calculated for $x_{\rm g}>0$

$$E_{\rm s} = \exp\left(-x_{\rm s}\right) \tag{4.105}$$

$$E_{s} = \exp(-x_{s})$$

$$D_{s} = [1/E_{s} - x_{s} - 1 - \chi(x_{s})] \cdot \Delta_{ns}$$

$$(4.105)$$

$$P_{s} = x_{s} - 1 + E_{s}$$

$$(4.107)$$

$$P_{\rm s} = x_{\rm s} - 1 + E_{\rm s}$$
 (4.107)

$$x_{\rm gs} = \begin{cases} x_{\rm g} - x_{\rm s} & \text{for } x_{\rm g} \le 0\\ G \cdot \sqrt{D_{\rm s} + P_{\rm s}} & \text{for } x_{\rm g} > 0 \end{cases}$$

$$(4.108)$$

$$\psi_{\rm ss} = \phi_{\rm T}^* \cdot x_{\rm s} \tag{4.109}$$

4.2.4 Drain Saturation Voltage

Eqs. (4.110)-(4.130) are only calculated for $x_{\rm g}>0$.

$$q_{\rm is} = \frac{G^2 \cdot \phi_{\rm T}^* \cdot D_{\rm s}}{x_{\rm gs} + G \cdot \sqrt{P_{\rm s}}} \tag{4.110}$$

$$\alpha_{\rm s} = 1 + \frac{G \cdot (1 - E_{\rm s})}{2 \cdot \sqrt{P_{\rm s}}} \tag{4.111}$$

$$q_{\rm bs} = \phi_{\rm T}^* \cdot G \cdot \sqrt{P_{\rm s}} \tag{4.112}$$

$$\rho_{\rm b} = \begin{cases} 1 + \mathbf{RSB} \cdot V_{\rm sbx} & \text{for } \mathbf{RSB} \ge 0 \\ \frac{1}{1 - \mathbf{RSB} \cdot V_{\rm sbx}} & \text{for } \mathbf{RSB} < 0 \end{cases}$$

$$(4.113)$$

$$\rho_{\rm g,s} = \begin{cases} \frac{1}{1 + \mathbf{RSG} \cdot q_{\rm is}} & \text{for } \mathbf{RSG} \ge 0\\ 1 - \mathbf{RSG} \cdot q_{\rm is} & \text{for } \mathbf{RSG} < 0 \end{cases}$$

$$(4.114)$$

$$\rho_{\rm s} = \boldsymbol{\theta}_{\mathbf{R}} \cdot \rho_{\rm b} \cdot \rho_{\rm g,s} \cdot q_{\rm is} \tag{4.115}$$

$$\mu_{\mathbf{x}} = \frac{1 + \boldsymbol{X}_{\mathbf{cor}} \cdot \boldsymbol{V}_{\mathbf{sbx}}}{1 + 0.2 \cdot \boldsymbol{X}_{\mathbf{cor}} \cdot \boldsymbol{V}_{\mathbf{sbx}}} \tag{4.116}$$

$$E_{\text{eff,s}} = E_{\text{eff0}} \cdot \left(q_{\text{bs}} + \eta_{\mu} \cdot q_{\text{is}} \right) \tag{4.117}$$

$$G_{\text{mob,s}} = \frac{1 + (\boldsymbol{\mu}_{\mathbf{E}} \cdot E_{\text{eff,s}})^{\boldsymbol{\theta}_{\boldsymbol{\mu}}} + \boldsymbol{C}_{\mathbf{S}} \cdot \left(\frac{q_{\text{bs}}}{q_{\text{is}} + q_{\text{bs}}}\right)^{2} + \rho_{\text{s}}}{\mu_{\text{x}}}$$
(4.118)

$$\xi_{\rm tb} = \begin{cases} 1 + \text{THESATB} \cdot V_{\rm sbx} & \text{for THESATB} \ge 0 \\ \\ \frac{1}{1 - \text{THESATB} \cdot V_{\rm sbx}} & \text{for THESATB} < 0 \end{cases}$$

$$(4.119)$$

$$w_{\text{sat,s}} = \frac{100 \cdot q_{\text{is}} \cdot \xi_{\text{tb}}}{100 + q_{\text{is}} \cdot \xi_{\text{tb}}}$$
(4.120)

$$\theta_{\text{sat,s}}^* = \begin{cases} \frac{\theta_{\text{sat}}}{G_{\text{mob,s}}} \cdot (1 + \text{THESATG} \cdot w_{\text{sat,s}}) & \text{for THESATG} \ge 0 \\ \frac{\theta_{\text{sat}}}{G_{\text{mob,s}}} \cdot \frac{1}{1 - \text{THESATG} \cdot w_{\text{sat,s}}} & \text{for THESATG} < 0 \end{cases}$$

$$(4.121)$$

$$\phi_{\infty} = q_{\rm is}/\alpha_{\rm s} + \phi_{\rm T}^* \tag{4.122}$$

$$y_{\text{sat}} = \begin{cases} \theta_{\text{sat,s}}^* \cdot \phi_{\infty} / \sqrt{2} & \text{for NMOS} \\ \frac{\theta_{\text{sat,s}}^* \cdot \phi_{\infty} / \sqrt{2}}{\sqrt{1 + \theta_{\text{sat,s}}^* \cdot \phi_{\infty} / \sqrt{2}}} & \text{for PMOS} \end{cases}$$

$$(4.123)$$

$$z_{\rm a} = \frac{2}{1 + \sqrt{1 + 4 \cdot y_{\rm sat}}} \tag{4.124}$$

$$\phi_0 = \phi_{\infty} \cdot z_{\text{a}} \cdot \left[1 + 0.86 \cdot z_{\text{a}} \cdot y_{\text{sat}} \cdot \frac{1 - z_{\text{a}}^2 \cdot y_{\text{sat}}}{1 + 4 \cdot z_{\text{a}}^3 \cdot y_{\text{sat}}^2} \right]$$
(4.125)

$$a_{\rm sat} = x_{\rm gs} + G^2/2 \tag{4.126}$$

$$\phi_2 = \frac{\phi_{\mathbf{T}}^* \cdot 0.98 \cdot G^2 \cdot D_{\mathbf{s}}}{a_{\text{sat}} + \sqrt{a_{\text{sat}}^2 - 0.98 \cdot G^2 \cdot D_{\mathbf{s}}}}$$
(4.127)

$$\phi_{\text{sat}} = \frac{2 \cdot \phi_0 \cdot \phi_2}{\phi_0 + \phi_2 + \sqrt{(\phi_0 + \phi_2)^2 - 3.96 \cdot \phi_0 \cdot \phi_2}}$$
(4.128)

$$V_{\text{dsat}} = \phi_{\text{sat}} - \phi_{\mathbf{T}}^* \cdot \ln \left[1 + \frac{\phi_{\text{sat}} \cdot \left(\phi_{\text{sat}} - 2 \cdot a_{\text{sat}} \cdot \phi_{\mathbf{T}}^* \right)}{G^2 \cdot D_{\text{s}} \cdot \phi_{\mathbf{T}}^{*2}} \right]$$
(4.129)

$$V_{\rm dse} = \frac{V_{\rm DS}}{\left[1 + (V_{\rm DS}/V_{\rm dsat})^{\mathbf{AX}}\right]^{1/\mathbf{AX}}} \tag{4.130}$$

4.2.5 Surface Potential at Drain Side and Related Variables

Eqs. (4.131)-(4.140) are only calculated for $x_{\rm g}>0$.

$$x_{\rm nd} = \frac{\phi_{\rm B} + V_{\rm SB}^* + V_{\rm dse}}{\phi_{\rm T}^*}$$
 (4.131)

$$k_{\rm ds} = \exp\left(-V_{\rm dse}/\phi_{\rm T}^*\right) \tag{4.132}$$

$$\Delta_{\rm nd} = \Delta_{\rm ns} \cdot k_{\rm ds} \tag{4.133}$$

if
$$x_{\rm g} \le x_{\rm mrg} \left\{ x_{\rm d} = \frac{x_{\rm g}}{\xi} \cdot \left[1 + G \cdot x_{\rm g} \cdot \frac{1 - \Delta_{\rm nd}}{\xi^2 \cdot 6 \cdot \sqrt{2}} \right] \right\}$$
 (4.134)

$$\begin{cases} b_{x} = x_{\text{nd}} + 3.0 \\ \eta = \text{MINA}(x_{0}, b_{x}, 5) - \left(b_{x} - \sqrt{b_{x}^{2} + 5}\right) / 2 \\ a = (x_{g} - \eta)^{2} - G^{2} \cdot \left[\exp(-\eta) + \eta - 1 - \Delta_{\text{nd}} \cdot (\eta + 1 + \chi(\eta))\right] \\ b = 1 - G^{2} / 2 \cdot \left[\exp(-\eta) - \Delta_{\text{nd}} \cdot \chi''(\eta)\right] \\ c = 2 \cdot (x_{g} - \eta) + G^{2} \cdot \left[1 - \exp(-\eta) - \Delta_{\text{nd}} \cdot (1 + \chi'(\eta))\right] \\ \tau = x_{\text{nd}} - \eta + \ln\left(a/G^{2}\right) \\ y_{0} = \sigma_{2}(a, b, c, \tau, \eta) \\ \Delta_{0} = \exp\left(y_{0}\right) \\ p = 2 \cdot (x_{g} - y_{0}) + G^{2} \cdot \left[1 - 1/\Delta_{0} + \Delta_{\text{nd}} \cdot (\Delta_{0} - 1 - \chi'(y_{0}))\right] \\ q = (x_{g} - y_{0})^{2} - G^{2} \cdot \left[y_{0} + 1/\Delta_{0} - 1 + \Delta_{\text{nd}} \cdot (\Delta_{0} - y_{0} - 1 - \chi(y_{0}))\right] \\ x_{d} = y_{0} + \frac{2 \cdot q}{p + \sqrt{p^{2} - 2 \cdot q} \cdot \left\{2 - G^{2} \cdot \left[1/\Delta_{0} + \Delta_{\text{nd}} \cdot (\Delta_{0} - \chi''(y_{0}))\right]\right\}} \end{cases}$$

$$(4.135)$$

$$\text{if } x_{\rm ds} < 10^{-10} \begin{cases}
p = 2 \cdot x_{\rm gs} + G^2 \cdot [1 - E_{\rm s} + \Delta_{\rm nd} \cdot (1/E_{\rm s} - 1 - \chi'(x_{\rm s}))] \\
q = G^2 \cdot (1 - k_{\rm ds}) \cdot D_{\rm s} \\
\xi = 1 - G^2/2 \cdot [E_{\rm s} + \Delta_{\rm nd} (1/E_{\rm s} - \chi''(x_{\rm s}))] \\
x_{\rm ds} = \frac{2 \cdot q}{p + \sqrt{p^2 - 4 \cdot \xi \cdot q}} \\
x_{\rm d} = x_{\rm s} + x_{\rm ds}
\end{cases} \tag{4.137}$$

$$E_{\rm d} = \exp\left(-x_{\rm d}\right) \tag{4.138}$$

$$D_{\rm d} = (1/E_{\rm d} - x_{\rm d} - 1 - \chi(x_{\rm d})) \cdot \Delta_{\rm nd}$$
(4.139)

$$\Delta \psi = \phi_{\mathbf{T}}^* \cdot x_{\mathrm{ds}} \tag{4.140}$$

$$\psi_{\rm sd} = \phi_{\rm T}^* \cdot x_{\rm d} \tag{4.141}$$

4.2.6 Mid-Point Surface Potential and Related Variables

if
$$x_{\rm g} > 0$$

$$\begin{cases}
x_{\rm m} = (x_{\rm s} + x_{\rm d})/2 \\
E_{\rm m} = \sqrt{E_{\rm s} \cdot E_{\rm d}} \\
\bar{D} = (D_{\rm s} + D_{\rm d})/2 \\
D_{\rm m} = \bar{D} + x_{\rm ds}^2/8 \cdot (E_{\rm m} - 2/G^2) \\
P_{\rm m} = x_{\rm m} - 1 + E_{\rm m} \\
x_{\rm gm} = G \cdot \sqrt{D_{\rm m} + P_{\rm m}}
\end{cases}$$
(4.142)

if
$$x_{\rm g} \le 0$$

$$\begin{cases} x_{\rm m} = x_{\rm s} \\ x_{\rm gm} = x_{\rm g} - x_{\rm s} \end{cases}$$
 (4.143)

4.2.7 Polysilicon Depletion

Eqs. (4.144)-(4.158) are only calculated for $k_{\rm P}>0$ and $x_{\rm g}>0$ (otherwise $\eta_{\rm p}=1$):

$$x_{\rm m}^{(0)} = x_{\rm m}, \qquad x_{\rm ds}^{(0)} = x_{\rm ds}, \qquad D_{\rm m}^{(0)} = D_{\rm m}, \qquad E_{\rm m}^{(0)} = E_{\rm m},$$
 (4.144)

$$d_0 = 1 - E_{\rm m}^{(0)} + 2 \cdot x_{\rm gm} / G^2 \tag{4.145}$$

$$\eta_{\rm p} = 1/\sqrt{1 + \mathbf{k_P} \cdot x_{\rm gm}} \tag{4.146}$$

$$x_{\rm pm} = \mathbf{k}_{\mathbf{P}} \cdot \left[\frac{\eta_{\rm p} \cdot x_{\rm gm}}{1 + \eta_{\rm p}} \right]^2 \cdot \frac{D_{\rm m}^{(0)}}{D_{\rm m}^{(0)} + P_{\rm m}}$$
(4.147)

$$p = 2 \cdot (x_{\rm gm} - x_{\rm pm}) + G^2 \cdot \left(1 - E_{\rm m}^{(0)} + D_{\rm m}^{(0)}\right)$$
(4.148)

$$q = x_{\text{pm}} \cdot (x_{\text{pm}} - 2 \cdot x_{\text{gm}}) \tag{4.149}$$

$$\xi_{\rm p} = 1 - G^2/2 \cdot \left(E_{\rm m}^{(0)} + D_{\rm m}^{(0)}\right) \tag{4.150}$$

$$u_{\mathbf{p}} = \frac{p \cdot q}{p^2 - \xi_{\mathbf{p}} \cdot q} \tag{4.151}$$

$$x_{\rm m} = x_{\rm m}^{(0)} + u_{\rm p} \tag{4.152}$$

$$E_{\rm m} = E_{\rm m}^{(0)} \cdot \exp\left(-u_{\rm p}\right) \tag{4.153}$$

$$D_{\rm m} = D_{\rm m}^{(0)} \cdot \exp\left(u_{\rm p}\right)$$
 (4.154)

$$P_{\rm m} = x_{\rm m} - 1 + E_{\rm m} \tag{4.155}$$

$$x_{\rm gm} = G \cdot \sqrt{D_{\rm m} + P_{\rm m}} \tag{4.156}$$

$$x_{\rm ds} = x_{\rm ds}^{(0)} \cdot \frac{\exp(u_{\rm p}) \cdot \left[\bar{D} + d_{0}\right]}{1 - E_{\rm m} + 2 \cdot x_{\rm gm} \cdot \eta_{\rm p} / G^{2} + \exp(u_{\rm p}) \cdot \bar{D}}$$
(4.157)

$$\Delta \psi = \phi_{\mathbf{T}}^* \cdot x_{\mathrm{ds}} \tag{4.158}$$

4.2.8 Potential Mid-Point Inversion Charge and Related Variables

Eqs. (4.159)-(4.167) are only calculated for $x_{\rm g}>0.\,$

$$q_{\rm im} = \frac{G^2 \cdot \phi_{\rm T}^* \cdot D_{\rm m}}{x_{\rm gm} + G \cdot \sqrt{P_{\rm m}}}$$

$$\tag{4.159}$$

$$\alpha_{\rm m} = \eta_{\rm p} + \frac{G \cdot (1 - E_{\rm m})}{2 \cdot \sqrt{P_{\rm m}}} \tag{4.160}$$

$$q_{\rm im}^* = q_{\rm im} + \phi_{\rm T}^* \cdot \alpha_{\rm m} \tag{4.161}$$

$$q_{\rm bm} = \phi_{\rm T}^* \cdot G \cdot \sqrt{P_{\rm m}} \tag{4.162}$$

Series resistance:

$$\rho_{\rm g} = \begin{cases}
\frac{1}{1 + \mathbf{RSG} \cdot q_{\rm im}} & \text{for } \mathbf{RSG} \ge 0 \\
1 - \mathbf{RSG} \cdot q_{\rm im} & \text{for } \mathbf{RSG} < 0
\end{cases}$$
(4.163)

$$\rho_{\rm s} = \boldsymbol{\theta}_{\mathbf{R}} \cdot \rho_{\rm b} \cdot \rho_{\rm g} \cdot q_{\rm im} \tag{4.164}$$

Mobility reduction:

$$E_{\text{eff}} = \boldsymbol{E}_{\text{eff0}} \cdot (q_{\text{bm}} + \boldsymbol{\eta}_{\boldsymbol{\mu}} \cdot q_{\text{im}}) \tag{4.165}$$

$$q_{\text{eff1}} = q_{\text{bm}} + \eta_{\mu,ac} \cdot q_{\text{im}} \tag{4.166}$$

$$G_{\text{mob}} = \frac{1 + (\boldsymbol{\mu}_{\mathbf{E}} \cdot E_{\text{eff}})^{\boldsymbol{\theta}_{\boldsymbol{\mu}}} + \boldsymbol{C}_{\mathbf{S}} \cdot \left(\frac{q_{\text{bm}}}{q_{\text{im}} + q_{\text{bm}}}\right)^{2} + \rho}{\mu_{\text{x}}}$$
(4.167)

4.2.9 Drain-Source Channel Current

Eqs. (4.168)-(4.179) are only calculated for $x_{\rm g}>0$:

Channel length modulation:

$$R_1 = q_{\rm im}/q_{\rm im}^*$$
 (4.168)

$$R_2 = \phi_{\mathbf{T}}^* \cdot \alpha_{\mathbf{m}} / q_{\mathbf{im}}^* \tag{4.169}$$

$$T_{1} = \ln \left(\frac{1 + \frac{V_{DS} - \Delta \psi}{\mathbf{VP}}}{1 + \frac{V_{dse} - \Delta \psi}{\mathbf{VP}}} \right)$$
(4.170)

$$T_2 = \ln\left(1 + \frac{V_{\rm dsx}}{\mathbf{VP}}\right) \tag{4.171}$$

$$\Delta L/L = \mathbf{ALP} \cdot T_1 \tag{4.172}$$

$$G_{\Delta L} = \frac{1}{1 + \Delta L/L + (\Delta L/L)^2} \tag{4.173}$$

$$\Delta L_1/L = \left[\mathbf{ALP} + \frac{\mathbf{ALP1}}{q_{\text{im}}^*} \cdot R_1 \right] \cdot T_1 + \mathbf{ALP2} \cdot q_{\text{bm}} \cdot R_2^2 \cdot T_2$$
(4.174)

$$F_{\Delta L} = \left[1 + \Delta L_1 / L + (\Delta L_1 / L)^2\right] \cdot G_{\Delta L} \tag{4.175}$$

Velocity saturation:

$$w_{\text{sat}} = \frac{100 \cdot q_{\text{im}} \cdot \xi_{\text{tb}}}{100 + q_{\text{im}} \cdot \xi_{\text{tb}}} \tag{4.176}$$

$$\theta_{\text{sat}}^* = \begin{cases} \frac{\theta_{\text{sat}}}{G_{\text{mob,s}} \cdot G_{\Delta L}} \cdot (1 + \text{THESATG} \cdot w_{\text{sat}}) & \text{for THESATG} \ge 0 \\ \frac{\theta_{\text{sat}}}{G_{\text{mob,s}} \cdot G_{\Delta L}} \cdot \frac{1}{1 - \text{THESATG} \cdot w_{\text{sat}}} & \text{for THESATG} < 0 \end{cases}$$

$$(4.177)$$

$$z_{\text{sat}} = \begin{cases} (\theta_{\text{sat}}^* \cdot \Delta \psi)^2 & \text{for NMOS} \\ \\ \frac{(\theta_{\text{sat}}^* \cdot \Delta \psi)^2}{1 + \theta_{\text{sat}}^* \cdot \Delta \psi} & \text{for PMOS} \end{cases}$$
(4.178)

$$G_{\text{vsat}} = \frac{G_{\text{mob}} \cdot G_{\Delta L}}{2} \cdot \left(1 + \sqrt{1 + 2 \cdot z_{\text{sat}}}\right) \tag{4.179}$$

Auxiliary Variables for Calculation of Intrinsic Charges and Gate Current. Eqs. (4.180)-(4.182) are only calculated for $x_{\rm g}>0$.

$$V_{\text{oxm}} = \phi_{\mathbf{T}}^* \cdot x_{\text{gm}} \tag{4.180}$$

$$\alpha_{\rm m}' = \alpha_{\rm m} \cdot \left[1 + \frac{z_{\rm sat}}{2} \cdot \left(\frac{G_{\rm mob} \cdot G_{\Delta L}}{G_{\rm vsat}} \right)^2 \right]$$
 (4.181)

$$H = \frac{G_{\text{mob}} \cdot G_{\Delta L}}{G_{\text{vsat}}} \cdot \frac{q_{\text{im}}^*}{\alpha_{\text{m}}'}$$
(4.182)

In the remainder of this document, some variables (e.g., x_g) are labeled 'dc' or 'ac' (e.g., $x_{g,dc}$ or $x_{g,ac}$). Variables labeled 'dc' result from the *first* evaluation of Eqs. (4.91)–(4.182). For variables labeled 'ac', there are two possibilities. If **SWNUD** = 1 or **SWDELVTAC** = 1, their values result from the *second* evaluation of Eqs. (4.91)–(4.182). In any other case, their value is equal to their 'dc'-counterpart.

This applies to the following variables: $x_{\rm g}$, $q_{\rm eff1}$, $V_{\rm oxm}$, $q_{\rm im}$, $q_{\rm im}^*$, $\alpha_{\rm m}$, $\Delta \psi$, $G_{\Delta L}$, $F_{\Delta L}$, H, $\eta_{\rm p}$, $G_{\rm vsat}$, $V_{\rm dse}$, $G_{\rm mob}$, $x_{\rm m}$, G, $x_{\rm gm}$, $\theta_{\rm sat}^*$.

Drain-Source channel current:

$$I_{\rm DS} = \begin{cases} 0 & \text{for } x_{\rm g,dc} \le 0 \\ \beta \cdot F_{\Delta L,\rm dc} \cdot \frac{q_{\rm im,dc}^*}{G_{\rm vsat,dc}} \cdot \Delta \psi_{\rm dc} & \text{for } x_{\rm g,dc} > 0 \end{cases}$$

$$(4.183)$$

4.2.10 Impact Ionization or Weak-Avalanche

The equations in this Section are only calculated when SWIMPACT = 1 and $x_{\rm g}>0$.

$$a_2^* = \mathbf{a_2} \cdot \left[1 + \mathbf{A4} \cdot \left(\sqrt{V_{\mathrm{SB,dc}}^* + \phi_{\mathbf{B}}} - \sqrt{\phi_{\mathbf{B}}} \right) \right]$$
(4.184)

$$\Delta V_{\rm sat} = V_{\rm DS} - \mathbf{A3} \cdot \Delta \psi_{\rm dc} \tag{4.185}$$

$$M_{\rm avl} = \begin{cases} 0 & \text{for } \Delta V_{\rm sat} \le 0 \\ \mathbf{A1} \cdot \Delta V_{\rm sat} \cdot \exp\left(-\frac{a_2^*}{\Delta V_{\rm sat}}\right) & \text{for } \Delta V_{\rm sat} > 0 \end{cases}$$

$$(4.186)$$

$$I_{\text{avl}} = M_{\text{avl}} \cdot I_{\text{DS}} \tag{4.187}$$

4.2.11 Surface Potential in Gate Overlap Regions

$$x_{\text{sov}}\left(x_{\text{g}}\right) = \begin{cases} y_{\text{g}} = -x_{\text{g}} \\ z = x_{1} \cdot y_{\text{g}} / \xi_{\text{ov}} \\ \eta = \left[z + 10 - \sqrt{(z - 6)^{2} + 64}\right] / 2 \\ a = (y_{\text{g}} - \eta)^{2} + G_{\text{ov}}^{2} \cdot (\eta + 1) \\ c = 2 \cdot (y_{\text{g}} - \eta) - G_{\text{ov}}^{2} \\ \tau = -\eta + \ln\left(a / G_{\text{ov}}^{2}\right) \\ y_{0} = \sigma_{1}(a, c, \tau, \eta) \\ \Delta_{0} = \exp\left(y_{0}\right) \\ p = 2 \cdot (y_{\text{g}} - y_{0}) + G_{\text{ov}}^{2} \cdot (y_{0} - \Delta_{0} + 1) \\ x_{\text{sov}} = -y_{0} - \frac{2 \cdot q}{p + \sqrt{p^{2} - 2 \cdot q \cdot (2 - G_{\text{ov}}^{2} \cdot \Delta_{0})}} \end{cases}$$

$$\text{if } |x_{\text{g}}| < x_{\text{mrgov}} \begin{cases} x_{\text{sov}} = x_{\text{g}} / \xi_{\text{ov}} \\ x_{\text{sov}} = x_{\text{g}} / \xi_{\text{ov}} \cdot \left[1 + x_{\text{g}} \cdot (\xi_{\text{ov}} \cdot x_{1} - x_{\text{g1}}) / x_{\text{g1}}^{2}\right] \\ \omega = 1 - \exp\left(-\bar{x}\right) \\ x_{0} = x_{\text{g}} + G_{\text{ov}}^{2} / 2 - G_{\text{ov}} \cdot \sqrt{x_{\text{g}} + G_{\text{ov}}^{2} / 4 - \omega} \\ \Delta_{0} = \exp\left(-x_{0}\right) \\ q = (x_{\text{g}} - x_{0})^{2} - G_{\text{ov}}^{2} \cdot (x_{0} + \Delta_{0} - 1) \\ x_{\text{sov}} = x_{0} + \frac{2 \cdot q}{p + \sqrt{p^{2} - 2 \cdot q \cdot (2 - G_{\text{ov}}^{2} \cdot \Delta_{0})}} \end{cases}$$

$$\begin{aligned} & \begin{cases} y_{\rm g} = -x_{\rm g} \\ z = x_1 \cdot y_{\rm g}/\xi_{\rm dov} \\ \eta = \left[z + 10 - \sqrt{(z - 6)^2 + 64}\right]/2 \\ a = (y_{\rm g} - \eta)^2 + G_{\rm dov}^2 \cdot (\eta + 1) \\ c = 2 \cdot (y_{\rm g} - \eta) - G_{\rm dov}^2 \\ \tau = -\eta + \ln\left(a/G_{\rm dov}^2\right) \\ y_0 = \sigma_1(a, c, \tau, \eta) \\ \Delta_0 = \exp\left(y_0\right) \\ p = 2 \cdot (y_{\rm g} - y_0) + G_{\rm dov}^2 \cdot (\chi_0 - \Delta_0 + 1) \\ x_{\rm dov} = -y_0 - \frac{2 \cdot q}{p + \sqrt{p^2 - 2 \cdot q \cdot (2 - G_{\rm dov}^2 \cdot \Delta_0)}} \end{aligned}$$
 (4.189)
$$\begin{aligned} & \text{if } |x_{\rm g}| < x_{\rm mrgdov} & \left\{ \begin{array}{c} \bar{x} = x_{\rm g}/\xi_{\rm dov} \cdot \left[1 + x_{\rm g} \cdot (\xi_{\rm dov} \cdot x_1 - x_{\rm dg1})/x_{\rm dg1}^2\right] \\ \omega = 1 - \exp\left(-\bar{x}\right) \\ x_0 = x_{\rm g} + G_{\rm dov}^2/2 - G_{\rm dov} \cdot \sqrt{x_{\rm g} + G_{\rm dov}^2/4 - \omega} \\ \Delta_0 = \exp\left(-x_0\right) \\ p = 2 \cdot (x_{\rm g} - x_0) + G_{\rm dov}^2 \cdot (x_0 + \Delta_0 - 1) \\ x_{\rm dov} = x_0 + \frac{2 \cdot q}{p + \sqrt{p^2 - 2 \cdot q \cdot (2 - G_{\rm dov}^2 \cdot \Delta_0)}} \end{aligned}$$

$$\psi_{\text{sov}} = -\phi_{\mathbf{T}} \cdot x_{\text{sov}} \left(-\frac{V_{\text{GS}}}{\phi_{\mathbf{T}}} \right) \tag{4.190}$$

$$\psi_{\text{dov}} = -\phi_{\mathbf{T}} \cdot x_{\text{dov}} \left(-\frac{V_{\text{GS}} - V_{\text{DS}}}{\phi_{\mathbf{T}}} \right) \tag{4.191}$$

$$V_{\text{ov}_0} = V_{\text{GS}} - \psi_{\text{sov}} \tag{4.192}$$

$$V_{\text{ov}_{\text{L}}} = V_{\text{GS}} - V_{\text{DS}} - \psi_{\text{dov}} \tag{4.193}$$

4.2.12 Gate Current

The equations in this Section are only calculated when SWIGATE = 1.

Source/Drain gate overlap current:

Source/Drain gate overlap current:
$$I_{GSow}(V_{GX}, \psi_{ov}, V_{ov}) = \begin{cases} V_{ov}^* = \sqrt{V_{ov}^2 + 10^{-6}} \\ \psi_{tov} = \text{MINA}\left(0, V_{ov} + D_{ov}, 0.01\right) \\ z_g = \begin{cases} \text{MINA}\left(\frac{V_{ov}^*}{\text{CHIB}}, GC_{\mathbf{Q}}, 10^{-6}\right) & \text{for } \mathbf{GC3} < 0 \\ \frac{V_{ov}^*}{\mathbf{CHIB}} & \text{for } \mathbf{GC3} \ge 0 \end{cases} \\ \Delta_{Siov} = \exp\left(\frac{3.0 \cdot \phi_{\mathbf{T}} + \psi_{ov} + \psi_{tov}}{\phi_{\mathbf{T}}}\right) \\ I_{Gov} = I_{\mathbf{GOV}} \cdot F_{Sov} \cdot \exp\left(\frac{1 + \Delta_{Siov}}{1 + \Delta_{Siov} \cdot \exp\left(-V_{\mathbf{GX}}/\phi_{\mathbf{T}}\right)}\right) \\ I_{Gov} = I_{\mathbf{GOV}} \cdot F_{Sov} \cdot \exp\left(\frac{1 - \frac{3}{2} + z_g \cdot (\mathbf{GC2} + \mathbf{GC3} \cdot z_g)}{1 + 2 - \frac{3}{2} + \frac{3}{2}$$

$$I_{\text{GSov}} = I_{\text{GSov}} \left(V_{\text{GS}}, \psi_{\text{sov}}, V_{\text{ov_0}} \right) \tag{4.196}$$

$$I_{\text{GDov}} = I_{\text{GDov}} \left(V_{\text{GS}} - V_{\text{DS}}, \psi_{\text{dov}}, V_{\text{ov}_{\text{L}}} \right) \tag{4.197}$$

Gate-channel current:

$$V_{\rm m} = V_{\rm SB,dc}^* + \phi_{\rm T}^* \cdot \left[\frac{x_{\rm ds,dc}}{2} - \ln\left(\frac{1 + \exp(x_{\rm ds,dc} - V_{\rm dse,dc}/\phi_{\rm T}^*)}{2}\right) \right]$$
(4.198)

$$\psi_{\rm t} = {\rm MINA} \left(0, \, V_{\rm oxm, dc} + D_{\rm ch}, \, 0.01 \right)$$
(4.199)

$$V_{\text{oxm}}^* = \sqrt{V_{\text{oxm,dc}}^2 + 10^{-6}}$$
 (4.200)

$$z_{g} = \begin{cases} \text{MINA}\left(\frac{V_{\text{oxm}}^{*}}{\text{CHIB}}, GC_{\mathbf{Q}}, 10^{-6}\right) & \text{for GC3} < 0\\ \frac{V_{\text{oxm}}^{*}}{\text{CHIB}} & \text{for GC3} \ge 0 \end{cases}$$

$$(4.201)$$

$$\Delta_{\rm Si} = \exp\left(x_{\rm m,dc} - \frac{\alpha_{\rm b} + V_{\rm m} - \psi_{\rm t}}{\phi_{\rm T}^*}\right) \tag{4.202}$$

$$F_{\rm S} = \ln \left[\frac{1 + \Delta_{\rm Si}}{1 + \Delta_{\rm Si} \cdot \exp\left(-\frac{V_{\rm GS} + V_{\rm SB,dc}^* - V_{\rm m}}{\phi_{\rm T}^*}\right)} \right]$$
(4.203)

$$I_{\text{GCO}} = I_{\text{GINV}} \cdot F_{\text{S}} \cdot \exp\left(\boldsymbol{B} \cdot \left[-3/2 + z_{\text{g}} \cdot (\mathbf{GC2} + \mathbf{GC3} \cdot z_{\text{g}})\right]\right)$$
(4.204)

$$\operatorname{if} x_{\mathrm{g,dc}} > 0 \begin{cases} u_0 = \operatorname{CHiB} / \left[B \cdot (\operatorname{GC2} + 2 \cdot \operatorname{GC3} \cdot z_{\mathrm{g}}) \right] \\ x = \Delta \psi_{\mathrm{dc}} / \left(2 \cdot u_0 \right) \\ b = u_0 / H_{\mathrm{dc}} \\ B_{\mathrm{g}} = b \cdot \left(1 - b \right) / 2 \\ A_{\mathrm{g}} = 1 / 2 - 3 \cdot B_{\mathrm{g}} \\ p_{\mathrm{gc}} = \left(1 - b \right) \cdot \frac{\sinh(x)}{x} + b \cdot \cosh(x) \\ p_{\mathrm{gd}} = \frac{p_{\mathrm{gc}}}{2} - B_{\mathrm{g}} \cdot \sinh(x) - A_{\mathrm{g}} \cdot \frac{\sinh(x)}{x} \cdot \left[\coth(x) - \frac{1}{x} \right] \end{cases}$$

$$(4.205)$$

if
$$x_{g,dc} \le 0$$

$$\begin{cases} p_{gc} = 1 \\ p_{gd} = 1/2 \end{cases}$$
 (4.206)

$$S_{\rm g} = \frac{1}{2} \cdot \left(1 + \frac{x_{\rm g,dc}}{\sqrt{x_{\rm g,dc}^2 + 10^{-6}}} \right) \tag{4.207}$$

$$I_{\rm GC} = I_{\rm GCO} \cdot p_{\rm gc} \cdot S_{\rm g} \tag{4.208}$$

$$I_{\text{GCD}} = I_{\text{GCO}} \cdot p_{\text{gd}} \cdot S_{\text{g}} \tag{4.209}$$

$$I_{GCS} = I_{GC} - I_{GCD} \tag{4.210}$$

$$I_{\rm GB} = I_{\rm GCO} \cdot p_{\rm gc} \cdot (1 - S_{\rm g}) \tag{4.211}$$

4.2.13 **Gate-Induced Drain/Source Leakage Current**

The equations in this section are only calculated when SWGIDL = 1.

$$I_{\text{gisl}}(V_{\text{ov}}, V) = \begin{cases} V_{\text{tov}} = \sqrt{V_{\text{ov}}^2 + \text{CGIDL}^2 \cdot V^2 + 10^{-6}} \\ t = V \cdot V_{\text{tov}} \cdot V_{\text{ov}} \\ I_{\text{gisl}} = \begin{cases} -A_{\text{GIDL}} \cdot t \cdot \exp\left(-\frac{B_{\text{GIDL}}}{V_{\text{tov}}}\right) & \text{for } V_{\text{ov}} < 0 \\ 0 & \text{for } V_{\text{ov}} \ge 0 \end{cases}$$

$$I_{\text{gidl}}(V_{\text{ov}}, V) = \begin{cases} V_{\text{tov}} = \sqrt{V_{\text{ov}}^2 + \text{CGIDLD}^2 \cdot V^2 + 10^{-6}} \\ t = V \cdot V_{\text{tov}} \cdot V_{\text{ov}} \\ I_{\text{gidl}} = \begin{cases} -A_{\text{GIDLD}} \cdot t \cdot \exp\left(-\frac{B_{\text{GIDLD}}}{V_{\text{tov}}}\right) & \text{for } V_{\text{ov}} < 0 \\ 0 & \text{for } V_{\text{ov}} \ge 0 \end{cases}$$

$$I_{\text{gidl}} = \begin{cases} -A_{\text{GIDLD}} \cdot t \cdot \exp\left(-\frac{B_{\text{GIDLD}}}{V_{\text{tov}}}\right) & \text{for } V_{\text{ov}} < 0 \\ 0 & \text{for } V_{\text{ov}} \ge 0 \end{cases}$$

$$I_{\text{gidl}} = \begin{cases} -A_{\text{GIDLD}} \cdot t \cdot \exp\left(-\frac{B_{\text{GIDLD}}}{V_{\text{tov}}}\right) & \text{for } V_{\text{ov}} < 0 \\ 0 & \text{for } V_{\text{ov}} \ge 0 \end{cases}$$

$$I_{\text{gidl}} = \begin{cases} -A_{\text{GIDLD}} \cdot t \cdot \exp\left(-\frac{B_{\text{GIDLD}}}{V_{\text{tov}}}\right) & \text{for } V_{\text{ov}} < 0 \\ 0 & \text{for } V_{\text{ov}} \ge 0 \end{cases}$$

$$I_{\text{gidl}}(V_{\text{ov}}, V) = \begin{cases} V_{\text{tov}} = \sqrt{V_{\text{ov}}^2 + \mathbf{CGIDLD}^2 \cdot V^2 + 10^{-6}} \\ t = V \cdot V_{\text{tov}} \cdot V_{\text{ov}} \\ I_{\text{gidl}} = \begin{cases} -\mathbf{A_{GIDLD}} \cdot t \cdot \exp\left(-\frac{\mathbf{B_{GIDLD}}}{V_{\text{tov}}}\right) & \text{for } V_{\text{ov}} < 0 \\ 0 & \text{for } V_{\text{ov}} \ge 0 \end{cases}$$

$$(4.213)$$

$$I_{\text{gisl}} = I_{\text{gisl}}(V_{\text{ov}_0}, V_{\text{SB}}) \tag{4.214}$$

$$I_{\text{gidl}} = I_{\text{gidl}}(V_{\text{ov}_{\text{L}}}, V_{\text{DS}} + V_{\text{SB}}) \tag{4.215}$$

4.2.14 Total Terminal Currents

$$I_{\rm D} = I_{\rm DS} + I_{\rm avl} - I_{\rm GDov} - I_{\rm GCD} + I_{\rm gidl} \tag{4.216}$$

$$I_{\rm S} = -I_{\rm DS} - I_{\rm GSov} - I_{\rm GCS} + I_{\rm gisl} \tag{4.217}$$

$$I_{\rm G} = I_{\rm GC} + I_{\rm GB} + I_{\rm GDov} + I_{\rm GSov} \tag{4.218}$$

$$I_{\rm B} = -I_{\rm avl} - I_{\rm GB} - I_{\rm gidl} - I_{\rm gisl}$$
 (4.219)

4.3 Charge Model

In this section, the charge model equations of the PSP-model are given. Use is made of the applied terminal bias values $V_{\rm GS}$, $V_{\rm DS}$ and $V_{\rm SB}$, the local parameters listed in Section 2.5.2 and the internal parameters introduced in Section 4.1. Local parameters are denoted by capital characters in bold font, whereas internal (bias-independent) parameters are denoted by symbols in bold font.

The definitions of the auxiliary functions MINA(.), MAXA(.), $\chi(.)$ and $\sigma_{1,2}(.)$ can be found in Appendix A.

Quantum-Mechanical Corrections

$$q_{\rm eff,ac} = \begin{cases} V_{\rm oxm,ac} & \text{for } x_{\rm g,ac} \le 0 \\ q_{\rm eff1,ac} & \text{for } x_{\rm g,ac} > 0 \end{cases} \tag{4.220}$$

$$C_{\rm OX}^{\rm qm} = \begin{cases} \mathbf{COX} & \text{for } \boldsymbol{q_q} = 0 \\ \\ \frac{\mathbf{COX}}{1 + \boldsymbol{q_q}/(q_{\rm eff,ac}^2 + \boldsymbol{q_{\rm lim}}^2)^{1/6}} & \text{for } \boldsymbol{q_q} > 0 \end{cases} \tag{4.221}$$

4.3.2 Intrinsic Charge Model

$$\begin{aligned} & \begin{cases} F_{\rm j} = \Delta \psi_{\rm ac} / \left(2 \cdot H_{\rm ac}\right) \\ q_{\Delta L} = \left(1 - G_{\Delta L, \rm ac}\right) \cdot \left(q_{\rm im, ac} - \alpha_{\rm m, ac} \cdot \Delta \psi_{\rm ac} / 2\right) \\ q_{\Delta L}^* = q_{\Delta L, \rm ac} \cdot \left(1 + G_{\Delta L, \rm ac}\right) \\ Q_{\rm G}^{(i)} = C_{\rm OX}^{\rm qm} \cdot \left[V_{\rm oxm, ac} + \frac{\eta_{\rm p, ac} \cdot \Delta \psi_{\rm ac}}{2} \cdot \left(\frac{G_{\Delta L, \rm ac}}{3} \cdot F_{\rm j} + G_{\Delta L, \rm ac} - 1\right)\right] \\ Q_{\rm I}^{(i)} = -C_{\rm OX}^{\rm qm} \cdot \left[G_{\Delta L, \rm ac} \cdot \left(q_{\rm im, ac} + \frac{\alpha_{\rm m, ac} \cdot \Delta \psi_{\rm ac}}{6} \cdot F_{\rm j}\right) + q_{\Delta L, \rm ac}\right] \\ Q_{\rm D}^{(i)} = -\frac{C_{\rm OX}^{\rm qm}}{2} \cdot \left[G_{\Delta L, \rm ac}^2 \cdot \left(q_{\rm im, ac} + \frac{\alpha_{\rm m, ac} \cdot \Delta \psi_{\rm ac}}{6} \cdot \left[\frac{F_{\rm j}^2}{5} + F_{\rm j} - 1\right]\right) + q_{\Delta L}^* \right] \end{aligned}$$

if
$$x_{\rm g} \le 0$$

$$\begin{cases}
Q_{\rm G}^{(i)} = C_{\rm OX}^{\rm qm} \cdot V_{\rm oxm,ac} \\
Q_{\rm I}^{(i)} = 0 \\
Q_{\rm D}^{(i)} = 0
\end{cases}$$
(4.223)

$$Q_{\rm S}^{(i)} = Q_{\rm I}^{(i)} - Q_{\rm D}^{(i)} \tag{4.224}$$

$$Q_{\rm B}^{(i)} = -Q_{\rm I}^{(i)} - Q_{\rm G}^{(i)} \tag{4.225}$$

4.3.3 Extrinsic Charge Model

The charges of the source and drain overlap regions:

$$Q_{\text{sov}} = \mathbf{CGOV} \cdot (V_{\text{GS}} - \psi_{\text{sov}}) \tag{4.226}$$

$$Q_{\text{dov}} = \mathbf{CGOVD} \cdot (V_{\text{GS}} - V_{\text{DS}} - \psi_{\text{dov}}) \tag{4.227}$$

The charge of the bulk overlap region

$$Q_{\text{bov}} = \mathbf{CGBOV} \cdot (V_{\text{GS}} + V_{\text{SB}}) \tag{4.228}$$

Outer fringe charge:

$$Q_{\text{ofs}} = \mathbf{CFR} \cdot V_{\text{GS}} \tag{4.229}$$

$$Q_{\text{ofd}} = \mathbf{CFRD} \cdot (V_{\text{GS}} - V_{\text{DS}}) \tag{4.230}$$

4.3.4 Total Terminal Charges

$$Q_{\rm G} = Q_{\rm G}^{(i)} + Q_{\rm sov} + Q_{\rm dov} + Q_{\rm ofs} + Q_{\rm ofd} + Q_{\rm bov}$$
(4.231)

$$Q_{\rm S} = Q_{\rm S}^{(i)} - Q_{\rm sov} - Q_{\rm ofs} \tag{4.232}$$

$$Q_{\rm D} = Q_{\rm D}^{(i)} - Q_{\rm dov} - Q_{\rm ofd} \tag{4.233}$$

$$Q_{\rm B} = Q_{\rm B}^{(i)} - Q_{\rm bov} \tag{4.234}$$

4.4 Noise Model

Eqs. (4.235)-(4.251) are only calculated for $x_g > 0$. In these equations f_{op} represents the operation frequency of the transistor and $j = \sqrt{-1}$.

$$N^* = \frac{C_{\text{ox}}}{q} \cdot \alpha_{\text{m,dc}} \cdot \phi_{\mathbf{T}}$$
 (4.235)

$$N_{\rm m}^* = \frac{C_{\rm ox}}{q} \cdot q_{\rm im,dc}^* \tag{4.236}$$

$$\Delta N = \frac{C_{\text{ox}}}{q} \cdot \alpha_{\text{m,dc}} \cdot \Delta \psi_{\text{dc}}$$
 (4.237)

$$S_{\mathrm{fl}} = \frac{q \cdot \phi_{\mathrm{T}}^{2} \cdot \beta \cdot I_{\mathrm{DS}}}{\left(f_{\mathrm{op}}\right)^{\mathrm{EF}} \cdot C_{\mathrm{ox}} \cdot G_{\mathrm{vsat,dc}} \cdot N^{*}} \cdot \left[\left(\mathbf{NFA} - \mathbf{NFB} \cdot N^{*} + \mathbf{NFC} \cdot N^{*\,2}\right) \cdot \ln \left(\frac{N_{\mathrm{m}}^{*} + \Delta N/2}{N_{\mathrm{m}}^{*} - \Delta N/2} \right) \right]$$

+
$$\left(\mathbf{NFB} + \mathbf{NFC} \cdot [N_{\mathrm{m}}^* - 2 \cdot N^*]\right) \cdot \Delta N$$
 (4.238)

$$H_0 = \frac{q_{\text{im,dc}}^*}{\alpha_{\text{m,dc}}} \tag{4.239}$$

$$t_1 = \frac{q_{\text{im,dc}}}{q_{\text{im,dc}}^*} \tag{4.240}$$

$$t_2 = \left(\frac{\Delta\psi_{\rm dc}}{12 \cdot H_0}\right)^2 \tag{4.241}$$

$$R = \frac{H_0}{H} - 1 \tag{4.242}$$

$$l_c = 1 - 12 \cdot t_2 \cdot R \tag{4.243}$$

$$g_{\text{ideal}} = \frac{\beta \cdot q_{\text{im,dc}}^*}{G_{\text{vsat,dc}}} \cdot F_{\Delta L,\text{dc}}$$
(4.244)

$$C_{\text{Geff}} = \left(\frac{G_{\text{vsat,ac}}}{G_{\text{mob,ac}} \cdot G_{\Delta L,\text{ac}}}\right)^2 \cdot C_{\text{OX}}^{\text{qm}} \cdot \eta_{\text{p,ac}}$$
(4.245)

$$m_{\rm id} = \frac{g_{\rm ideal}}{l_{\rm c}^2} \cdot [t_1 + 12 \cdot t_2 - 24 \cdot (1 + t_1) \cdot t_2 \cdot R]$$
(4.246)

$$S_{\rm id} = N_{\rm T} \cdot m_{\rm id} \tag{4.247}$$

$$m_{\text{ig}} = \frac{1}{l_{\text{c}}^2 \cdot g_{\text{ideal}}} \cdot \left[\frac{t_1}{12} - t_2 \cdot \left(t_1 + \frac{1}{5} - 12 \cdot t_2 \right) - \frac{8}{5} \cdot t_2 \cdot (t_1 + 1 - 12 \cdot t_2) \cdot R \right]$$
(4.248)

$$S_{ig} = N_{T} \cdot \frac{(2 \cdot \pi \cdot f_{op} \cdot C_{Geff})^{2} \cdot m_{ig}}{1 + (2 \cdot \pi \cdot f_{op} \cdot C_{Geff} \cdot m_{ig})^{2}}$$

$$(4.249)$$

$$m_{\text{igid}} = \frac{\sqrt{t_2}}{l_c^2} \cdot \left[1 - 12 \cdot t_2 - \left(t_1 + \frac{96}{5} \cdot t_2 - 12 \cdot t_1 \cdot t_2 \right) \cdot R \right]$$
 (4.250)

$$S_{\text{igid}} = N_{\text{T}} \cdot \frac{2 \cdot \pi \cdot j \cdot f_{\text{op}} \cdot C_{\text{Geff}} \cdot m_{\text{igid}}}{1 + 2 \cdot \pi \cdot j \cdot f_{\text{op}} \cdot C_{\text{Geff}} \cdot m_{\text{ig}}}$$

$$(4.251)$$

Gate current shot noise:

$$S_{igs} = 2 \cdot q \cdot (I_{GCS} + I_{GSov}) \tag{4.252}$$

$$S_{\text{igd}} = 2 \cdot q \cdot (I_{\text{GCD}} + I_{\text{GDov}}) \tag{4.253}$$

Avalanche current shot noise:

$$S_{\text{avl}} = 2 \cdot q \cdot (1 + M_{\text{avl}}) \cdot I_{\text{avl}} \tag{4.254}$$

Thermal noise for parasitic resistances (see Fig. 3.2):

$$S_{\rm R_G} = 4 \cdot k_{\rm B} \cdot T_{\rm KD} / R_{\rm gate} \tag{4.255}$$

$$S_{R_{\text{BULK}}} = 4 \cdot k_{\text{B}} \cdot T_{\text{KD}} / R_{\text{bulk}} \tag{4.256}$$

$$S_{\text{R}_{\text{WELL}}} = 4 \cdot k_{\text{B}} \cdot T_{\text{KD}} / R_{\text{well}}$$
 (4.257)

$$S_{\rm R_{\rm JUNS}} = 4 \cdot k_{\rm B} \cdot T_{\rm KD} / R_{\rm juns} \tag{4.258}$$

$$S_{\rm R_{\rm JUND}} = 4 \cdot k_{\rm B} \cdot T_{\rm KD} / R_{\rm jund} \tag{4.259}$$

Section 5

Non-quasi-static RF model

5.1 Introduction

For high-frequency modeling and fast transient simulations, a special version of the PSP model is available, which enables the simulation of non-quasi-static (NQS) effects, and includes several parasitic resistances.

5.2 NQS-effects

In the PSP-NQS model, NQS-effects are introduced by applying the one-dimensional current continuity equation ($\partial I/\partial y \propto -\partial \rho/\partial t$) to the channel. A full numerical solution of this equation is too inefficient for compact modeling, therefore an approximate technique is used. The channel is partitioned into N+1 sections of equal length by assigning N equidistant *collocation points*. The charge density (per unit channel area) along the channel is then approximated by a cubic spline through these collocation points, assuring that both the charge and its first and second spatial derivatives are continuous along the channel. Within this approximation, the current continuity equation reduces to a system of N coupled first order ordinary differential equations, from which the channel charge at each collocation point can be found:

$$\begin{cases}
\frac{dQ_1}{dt} = f_1(Q_1, \dots, Q_N) \\
\vdots & \vdots \\
\frac{dQ_N}{dt} = f_N(Q_1, \dots, Q_N)
\end{cases}$$
(5.1)

Here, Q_i is the charge density at the *i*-th collocation point and f_i are functions, which contain the *complete* PSP-charge model. These equations are implemented by the definition of appropriate subcircuits (see left part of Fig. 5.1) and solved by the circuit simulator. Finally, the four terminal charges are calculated from the channel charges, using the Ward-Dutton partitioning scheme for the source and drain charges.

A full description of the PSP-NQS model is given in Section 5.3. More background information can be found in literature [7, 8].

5.3 NQS Model Equations

In this section, several symbols and notations are used which were defined in Section 4. Moreover, y denotes the (normalized) position along the channel (y=0 is source side, y=1 is drain side), while x denotes the surface potential (normalized to ϕ_T^*) at a certain position.

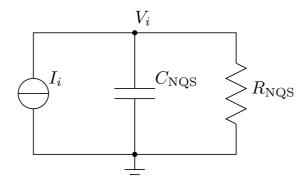


Figure 5.1: The subcircuit used to solve one of the differential equations of Eq. (5.1). The current is set to $I_i = C_{\text{NQS}} \cdot f(V_1, \dots, V_N)$, where the voltage V_i represents the charge density Q_i at the *i*-th collocation point and is solved by the circuit simulator. N of these circuits are defined and they are coupled through the dependence of I_i on the voltages of the other circuits. The resistance R_{NQS} has a very large value and is present only for convergence purposes. Right: The full network of parasitic elements in the PSP-NQS model. The large full dots indicate the five additional internal nodes.

5.3.1 Internal constants

Eqs. (5.2)–(5.7) are independent of bias conditions and time. Consequently, they have to be computed only once.

Note: In PSP only **SWNQS** = 0, 1, 2, 3, 5, 9 are allowed!

$$n = SWNQS + 1 \tag{5.2}$$

$$h = 1/n \tag{5.3}$$

The matrix A is a square $(n+1) \times (n+1)$ -matrix with elements $A_{i,j}$ $(0 \le i, j \le n)$, which are used in Eq. 5.25. They are computed using the following algorithm (adapted from [9]):

1. Initial values:

$$A_{i,j} = 0 \qquad \text{for } 0 \le i, j \le n \tag{5.4}$$

$$v_i = 0 \qquad \text{for } 0 \le i \le n \tag{5.5}$$

2. First loop:

$$p = 2 + v_{i-1}/2$$

$$v_{i} = -1/(2 \cdot p)$$

$$A_{i,i-1} = 1/h$$

$$A_{i,i} = -2/h$$

$$A_{i,i+1} = 1/h$$

$$A_{i,j} = \frac{1}{p} \cdot (3 \cdot A_{i,j}/h - A_{i-1,j}/2)$$
 for $j = 0 \dots n$
$$(5.6)$$

3. Second loop (back substitution):

$$A_{i,j} = v_i \cdot A_{i+1,j} + A_{i,j}$$
 for $j = 0 \dots n$
$$\begin{cases} for \ i = (n-1) \dots 0 \end{cases}$$
 (5.7)

5.3.2 Position independent quantities

The following quantities depend on the bias conditions, but are constant along the channel:

$$if x_{g,ac} > 0 \begin{cases} y_{m} = \frac{1}{2} \cdot \left(1 + \frac{\Delta \psi_{ac}}{4 \cdot H_{ac}}\right) \\ p_{d} = \frac{x_{gm,ac}}{x_{g,ac} - x_{m,ac}} \\ G_{p} = G_{ac}/p_{d} \end{cases}$$
 (5.8)

if
$$x_{\rm g,ac} \le 0$$

$$\begin{cases} y_{\rm m} = 1/2 \\ p_{\rm d} = 1 \\ G_{\rm p} = G_{\rm ac} \end{cases}$$
(5.9)

$$a_{\rm p} = 1 + G_{\rm p}/\sqrt{2}$$
 (5.10)

$$p_{\rm mrg} = 10^{-5} \cdot a_{\rm p}$$
 (5.11)

5.3.3 Position dependent surface potential and charge

Interpolated (quasi-static) surface potential along the channel:

$$\Psi(y) = x_{\text{m,ac}} + \frac{H_{\text{ac}}}{\phi_{\mathbf{T}}^*} \cdot \left(1 - \sqrt{1 - \frac{2 \cdot \Delta \psi_{\text{ac}}}{H_{\text{ac}}} \cdot (y - y_{\text{m}})}}\right)$$
(5.12)

Normalized bulk-charge and its first two derivatives as functions of surface potential:

$$q_{\rm b}(x) = -\operatorname{sgn}(x) \cdot G_{\rm p} \cdot \sqrt{\exp(-x) + x - 1}$$
(5.13)

$$q_{\rm b}'(x) = \frac{G_{\rm p}^2 \cdot [1 - \exp(-x)]}{2 \cdot q_{\rm b}(x)}$$
(5.14)

$$q_{\rm b}''(x) = -q_{\rm b}'(x) - \frac{q_{\rm b}'(x)^2 - G_{\rm p}^2/2}{q_{\rm b}(x)}$$
(5.15)

Surface potential as a function of normalized inversion charge (note that these equations are identical to

$$X(x_{\rm g}, q_{\rm inv}) = \Pi(x_{\rm g} + q_{\rm inv}/p_{\rm d}) \tag{5.17}$$

$$q(x) = -p_{\mathbf{d}} \cdot (x_{\mathbf{g}} - x) - q_{\mathbf{b}}(x) \tag{5.18}$$

$$\psi(q, q_{x1}) = \frac{q}{q_{x1}} - 1 \tag{5.19}$$

$$\phi(q, q_{x1}, q_{x2}) = \left(1 - \frac{q \cdot q_{x2}}{q_{x1}^2}\right) / q_{x1} \tag{5.20}$$

Normalized right-hand-side of continuity equation:

$$f(x_{\rm g},q) = \frac{\partial q}{\partial x}(x_{\rm g}) = p_{\rm d} - q_{\rm b}'(x_{\rm g})$$

$$q_{x1} = \frac{\partial q}{\partial x}(x_{\rm g}) = p_{\rm d} - q_{\rm b}'(x_{\rm g})$$

$$q_{x2} = \frac{\partial^2 q}{\partial x^2}(x_{\rm g}) = q_{\rm b}''(x_{\rm g})$$

$$f_0 = \psi(q,q_{x1}) \cdot q'' + \phi(q,q_{x1},q_{x2}) \cdot q'^2$$

$$x_{y1} = \frac{\partial x_{\rm g}}{\partial y} = q'/q_{x1}$$

$$z_{\rm sat} = \begin{cases} \left(\theta_{\rm sat,ac}^* \cdot \phi_{\rm T}^* \cdot x_{y1}\right)^2 & \text{for NMOS} \end{cases}$$

$$z_{\rm sat} = \begin{cases} \left(\theta_{\rm sat,ac}^* \cdot \phi_{\rm T}^* \cdot x_{y1}\right)^2 & \text{for PMOS} \end{cases}$$

$$\zeta = \sqrt{1 + 2 \cdot z_{\rm sat}}$$

$$F_{\rm vsat} = 2/(1 + \zeta)$$

$$f = F_{\rm vsat} \cdot \left[f_0 - F_{\rm vsat} \cdot \frac{z_{\rm sat}}{\zeta} \cdot \psi(q,q_{x1}) \cdot (q'' + x_{y1}^2 \cdot q_{\rm b}''(x_{\rm g}))\right]$$
Tradization constant:

Normalization constant:

$$T_{\text{norm}} = \frac{\text{MUNQS} \cdot \phi_{\mathbf{T}}^* \cdot \beta}{C_{\text{OX}}^{\text{qm}}} \cdot G_{\text{mob,ac}} \cdot G_{\Delta L, \text{ac}}$$
(5.22)

5.3.4 Cubic spline interpolation

Using cubic spline interpolation, the spatial derivatives $\frac{\partial q_i}{\partial y}(t)$ and $\frac{\partial^2 q_i}{\partial y^2}(t)$ can be expressed as functions of the $q_i(t)$.

$$q_0'' = 0 (5.23)$$

$$q_n'' = 0 ag{5.24}$$

$$q_i'' = \sum_{j=0}^{n} A_{i,j} \cdot q_i$$
 for $1 \le i \le n-1$ (5.25)

$$q_i' = \frac{q_{i+1} - q_i}{h} - \frac{h}{6} \cdot (2 \cdot q_i'' + q_{i+1}'') \qquad \text{for } 1 \le i \le n - 1$$
(5.26)

5.3.5 Continuity equation

Initial value for the q_i ($0 \le i \le n$). These values are used for the DC operating point.

$$x_{i,0} = \Psi(i \cdot h) \tag{5.27}$$

$$q_{i,0} = q(x_{i,0}) (5.28)$$

Note: $x_{0,0} = x_s$ and $x_{n,0} = x_d$. Moreover, these values coincide with those in the quasi-static part of PSP.

The core of the NQS-model is the solution of q(y,t) from the charge continuity equation along the channel. By approximating the y-dependence by a cubic spline through a number of collocation points, the problem is reduced to solving the $q_i(t)$ from the following set of coupled differential equations.

$$\begin{cases}
\frac{\partial q_i}{\partial t}(t) + T_{\text{norm}} \cdot f\left(x_{\text{g,ac}}, q_i(t), \frac{\partial q_i}{\partial y}(t), \frac{\partial^2 q_i}{\partial y^2}(t)\right) = 0 \\
q_i(0) = q_{i,0}
\end{cases}$$
for $1 \le i \le n - 1$

Note that the boundary points $q_0(t) = q(x_s) = q_{is}$ and $q_n(t) = q(x_d) = q_{id}$ remain fixed to their quasi-static values; they are not solved from the equation above.

The set of differential equations defined above is solved by the circuit simulator via the subcircuits shown in the left part of Fig. 5.1.

5.3.6 Non-quasi-static terminal charges

Once the q_i are known, the NQS terminal charges can be computed:

$$S_0 = \sum_{i=1}^{n-1} q_i \tag{5.30}$$

$$S_2 = \sum_{i=1}^{n-1} q_i'' \tag{5.31}$$

$$q_{\rm I}^{\rm NQS} = \int_0^1 q(y) \, \mathrm{d}y = h \cdot S_0 + \frac{h}{2} \cdot (u_0 + u_n) - \frac{h^3}{12} \cdot S_2$$
 (5.32)

$$U_0 = \sum_{i=1}^{n-1} i \cdot q_i \tag{5.33}$$

$$U_2 = \sum_{i=1}^{n-1} i \cdot q_i'' \tag{5.34}$$

$$q_{\rm D}^{\rm NQS} = \int_0^1 y \cdot q(y) \, \mathrm{d}y = h^2 \cdot U_0 + \frac{h^2}{6} \cdot [q_0 + (3n - 1)u_n] - \frac{h^4}{12} \cdot U_2$$
 (5.35)

$$q_{\rm S}^{\rm NQS} = q_{\rm I}^{\rm NQS} - q_{\rm D}^{\rm NQS} \tag{5.36}$$

Currently, only **SWNQS** = 0, 1, 2, 3, 5, 9 are allowed. For odd values of **SWNQS** the gate charge is integrated along the channel using "Simpson's rule". If **SWNQS** = 2, "Simpson's 3/8-rule" is used.

• If **SWNQS** is odd (that is, n is even):

$$q_{\mathbf{G}}^{\text{NQS}} = p_{\mathbf{d}} \cdot \left[x_{\text{g,ac}} - \frac{h}{3} \cdot \left(X(x_{\text{g,ac}}, q_0) + 4 \cdot \sum_{i=1}^{n/2} X(x_{\text{g,ac}}, q_{2i-1}) + \frac{1}{2} \cdot \sum_{i=1}^{n/2-1} X(x_{\text{g,ac}}, q_{2i}) + X(x_{\text{g,ac}}, q_n) \right) \right]$$
(5.37)

• If SWNQS = 2 (that is, n = 3):

$$q_{\rm G}^{\rm NQS} = p_{\rm d} \cdot \left[x_{\rm g,ac} - \frac{3 \cdot h}{8} \cdot \left(X(x_{\rm g,ac}, q_0) + 3 \cdot X(x_{\rm g,ac}, q_1) + 3 \cdot X(x_{\rm g,ac}, q_2) + X(x_{\rm g,ac}, q_3) \right) \right] (5.38)$$

Convert back to conventional units:

$$Q_{\rm S}^{\rm NQS} = C_{\rm OX}^{\rm qm} \cdot \phi_{\rm T}^* \cdot q_{\rm S}^{\rm NQS} \tag{5.39}$$

$$Q_{\mathrm{D}}^{\mathrm{NQS}} = C_{\mathrm{OX}}^{\mathrm{qm}} \cdot \phi_{\mathbf{T}}^{*} \cdot q_{\mathrm{D}}^{\mathrm{NQS}}$$
(5.40)

$$Q_{\rm G}^{\rm NQS} = C_{\rm OX}^{\rm qm} \cdot \phi_{\rm T}^* \cdot q_{\rm G}^{\rm NQS} \tag{5.41}$$

$$Q_{\rm B}^{\rm NQS} = -(Q_{\rm S}^{\rm NQS} + Q_{\rm D}^{\rm NQS} + Q_{\rm G}^{\rm NQS})$$
 (5.42)

Section 6

Embedding

6.1 Model selection

Circuit simulators have different ways for the user to determine which model must be used for simulation. Typically, model selection is either done by *name* or by assigning a value to the parameter **LEVEL**. The method to be used is prescribed by the circuit simulator vendor. If selection is done by name, the value of the parameter **LEVEL** is generally ignored. When Verilog-A code is used, model selection is always done by name.

For the SiMKit and the Verilog-A code provided by the PSP model developers, the method and values to be used are given in the table below. For other implementations, the method/value provided by the circuit simulator vendor is to be used.

From PSP 103.0 onwards, the global, local and binning models are unified. All three models are called by the same *name* or **LEVEL**. Model flavor selection is done by setting parameter **SWGEO**.

Simulator	Model selection by	Global (geom.)	Global (binning)	Local
Spectre	psp103			
Pstar	$\mathbf{LEVEL} = 103$	SWGEO = 1	SWCFO = 2	SWGEO = 0
ADS	psp103	SWGEO = 1	SWGEO = 2	SWGEO = 0
Verilog-A	PSP103VA			

6.2 Case of parameters

Throughout this document, all parameter names are printed in uppercase characters. Similarly, in the Verilog-A code provided by the PSP model developers, the parameters are in upper case characters. However, in other PSP implementations a different choice can be made. For example, the parameter names may be in lowercase characters (possibly first character capitalized) if this is conform the conventions of the circuit simulator.

6.3 Embedding PSP in a Circuit Simulator

In CMOS technologies both n- and p-channel MOS transistors are supported. It is convenient to use the same set of equations for both types of transistor instead of two separate models. This is accomplished by mapping a p-channel device with its bias conditions and parameter set onto an equivalent n-channel device with appropriately changed bias conditions (i.e. currents, voltages and charges) and parameters. In this way both types of transistor can be treated internally as an n-channel transistor. Nevertheless, the electrical behavior

of electrons and holes is not exactly the same (e.g., the mobility and tunneling behavior), and consequently slightly different equations have to be used in case of n- or p-type transistors.

Designers are used to the standard terminology of source, drain, gate and bulk. Therefore, in the context of a circuit simulator it is traditionally possible to address, say, the drain of MOST number 17, even if in reality the corresponding source is at a higher potential (n-channel case). More strongly, most circuit simulators provide for model evaluation values for $V_{\rm DS}$, $V_{\rm GS}$, and $V_{\rm SB}$ based on an a priori assignment of source, drain, and bulk, independent of the actual bias conditions. Since PSP assumes that saturation occurs at the drain side of the MOSFET, the basic model cannot cope with bias conditions that correspond to $V_{\rm DS} < 0$. Again a transformation of the bias conditions is necessary. In this case, the transformation corresponds to internally reassigning source and drain, applying the standard electrical model, and then reassigning the currents and charges to the original terminals. In PSP care has been taken to preserve symmetry with respect to drain and source at $V_{\rm DS} = 0$. In other words, no singularities will occur in the higher-order derivatives at $V_{\rm DS} = 0$.

In detail, for correct embedding of PSP into a circuit simulator, the following procedure—illustrated in Fig. 6.1—is followed. It is assumed that the simulator provides the nodal potentials $V_{\rm D}^e$, $V_{\rm G}^e$, $V_{\rm S}^e$ and $V_{\rm B}^e$ based on an a priori assignment of drain, gate, source and bulk.

- Step 1 The voltages $V'_{\rm DS}$, $V'_{\rm GS}$, and $V'_{\rm SB}$ are calculated from the nodal potentials provided by the circuit simulator. In the same step, the value of the parameter **TYPE** is used to deal with the polarity of the device. From here onwards, all transistors can be treated as n-channel devices.
- **Step 2** Depending on the sign of V'_{DS} , 'source-drain interchange' is performed. At this level, the voltages comply to all the requirements for input quantities of PSP.
- **Step 3** All the internal output quantities (i.e. channel current, weak-avalanche current, gate current, nodal charges, and noise-power spectral densities) are evaluated using the standard PSP equations (Section 4) and the internal voltages.
- Step 4 The internal output quantities are corrected for a possible source-drain interchange.
- **Step 5** External output are corrected for a possible *p*-channel transformation and **MULT** is applied. The quantities of the intrinsic MOSFET and the junctions are combined.

In general, separate parameter sets are used for n- and p-channel transistors, which are distinguished by the value of **TYPE**. As a consequence, the changes in the parameter values necessary for a p-channel type transistor are normally already included in the parameter sets on file. The changes should therefore not be included in the simulator.

6.3.1 Selection of device type

In the SiMKit-based and built-in version of PSP in certain circuit simulators, the selection of device type (nmos or pmos) is done using a different parameter, or using different parameter values. The correct values for some circuit simulators are given in the table below.

Simulator	Parameter	Value NMOS	value PMOS
Spectre	type	n	р
Pstar	type	1	-1
ADS	gender	1	0
Verilog-A	type	1	-1

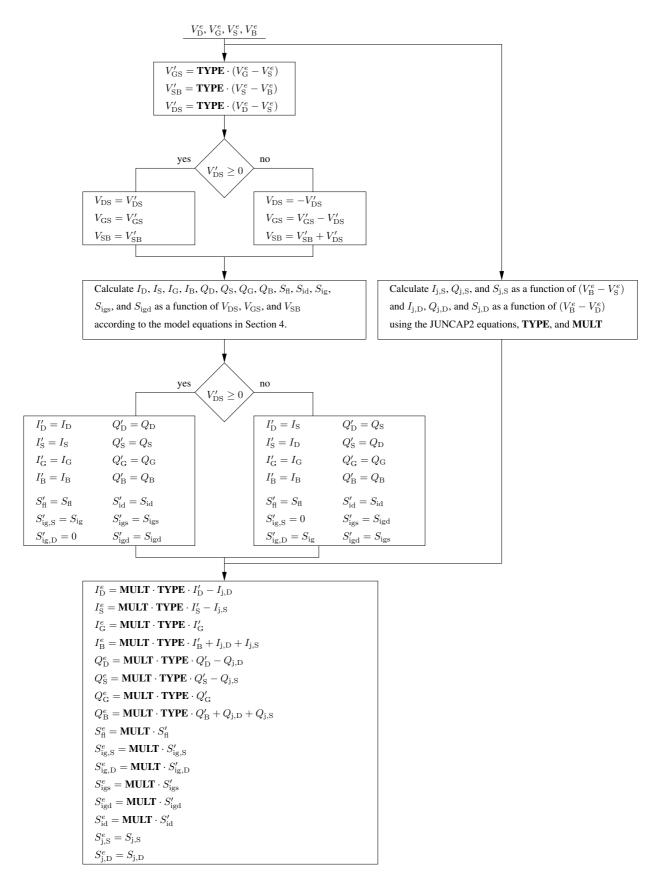


Figure 6.1: Schematic overview of source-drain interchange and handling of **TYPE** and **MULT**. Note that **TYPE** and **MULT** are included in the JUNCAP2 model equations.

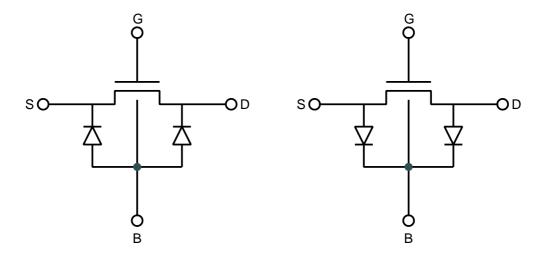


Figure 6.2: Topology of the PSP model. *Left: n*-channel MOSFET; *Right: p*-channel MOSFET. In PSP, the correct diode polarity is automatically chosen via the **TYPE**-parameter.

6.4 Integration of JUNCAP2 in PSP

Introduction

The JUNCAP2 model 200.3 is an integral part of PSP 102.2. In addition, it is available as a stand-alone model. A complete description of the JUNCAP2-model (including all model equations) can be found in the documentation of JUNCAP2's stand alone version [10]. In this section, only the integration of JUNCAP2 in PSP is described.

Topology

In a MOS transistor, there are two junctions: one between source and bulk, and one between drain and bulk. In case of an n-channel MOSFET, the junction anode corresponds to the MOSFET bulk terminal, and the junction cathodes correspond to the source and the drain. In case of a p-channel MOSFET, it is the other way around: now the junction cathode corresponds to the MOSFET bulk terminal, and the junction anodes correspond to the source and the drain. The connections are schematically given in Fig. 6.2. In PSP, this change of junction terminal connections in case of a p-MOSFET is handled automatically via the **TYPE** parameter.

In most cases, the MOSFET is operated in such a way that the junctions are either biased in the reverse mode of operation or not biased at all. In some applications, however, the source-bulk junction has a small forward bias. This is also the case in partially depleted SOI (PDSOI).

As indicated in Fig. 6.1, the interchange of source and drain for $V_{\rm DS} < 0$ (as explained above for the intrinsic MOS model) does *not* apply to the junctions. For example, **ABDRAIN** always refers to junction between the bulk and the terminal known as 'drain' to the simulator, independent of the sign of $V_{\rm DS}$.

Global and local model level

As explained in the introduction, the PSP model has a local and a global level. The JUNCAP2 model is a geometrically scaled model, i.e. it is valid for a range of junction geometries (as described by the geometrical parameters **AB**, **LS**, and **LG**). It has turned out that it is very unnatural to create a local parameter set for JUNCAP2, valid for one particular junction geometry: such a parameter set would have as many parameters as the global parameter set, and would be of no use. (Note that, in contrast, the local model for the intrinsic MOSFET is very useful in, e.g., parameter extraction; this is not the case for JUNCAP2.)

Therefore, the JUNCAP2 model is connected in exactly the same way to both the local and global model levels of PSP. That means that the resulting PSP local model is valid for a MOSFET with one particular channel width

and length, but with arbitrary junction geometry.

Parameters

Both junctions in the MOSFET are modeled with the same set of JUNCAP2 parameters. In the PSP model, the geometrical parameters **AB**, **LS**, and **LG** need to be specified for both source and drain. They will be denoted as **ABSOURCE**, **LSSOURCE**, and **LGSOURCE** for the source junction, and **ABDRAIN**, **LSDRAIN**, and **LGDRAIN** for the drain junction. For compatibility with BSIM instance parameters, there is also an option to use **AS**, **AD**, **PS**, and **PD**. The complete list of instance parameters (PSP and JUNCAP2) can be found in Sections 2.5.1.

The parameter **MULT** is merged with the parameter **MULT** of the intrinsic MOSFET model. In other words, both intrinsic currents, charges, and noise as well as junction currents, charges and noise are multiplied by one single parameter **MULT**. Beside **MULT**, also the parameters **DTA** and **TYPE** are shared by the intrinsic MOSFET model and the junction model. For clarity, we mention here that the reference temperatures of the intrinsic MOSFET model and junction model are *not* merged; they each have their own value and name (**TR** and **TRJ**, respectively). The currents, charges and spectral noise densities of the source and drain junctions are labeled $I_{\rm j,S}$, $Q_{\rm j,S}$, $S_{\rm j,S}$, $I_{\rm j,D}$, $Q_{\rm j,D}$, and $S_{\rm j,D}$ in Fig. 6.1.

6.5 Verilog-A versus C

As mentioned in Section 1.3, two implementations of the PSP-model are distributed: in Verilog-A language and in C-language (as part of the SiMKit). The C-version is automatically generated from the Verilog-A version by a software package called ADMS [1]. This procedure guarantees that the two implementations contain identical model equations.

Nevertheless, there are a few minor differences between the two, which are due to certain limitations of either the Verilog-A language or the circuit simulators supported in the SiMKit-framework. These differences are described below.

6.5.1 Implementation of GMIN

In both implementations, there is an additional term in Eqs. (4.216) and (4.217), resulting in

$$I_{\rm D} = I_{\rm DS} + I_{\rm avl} - I_{\rm GDov} - I_{\rm GCD} + I_{\rm gidl} + G_{\rm min} \cdot V_{\rm DS}$$

$$(6.1)$$

and

$$I_{\rm S} = -I_{\rm DS} - I_{\rm GSov} - I_{\rm GCS} + I_{\rm gisl} - G_{\rm min} \cdot V_{\rm DS}. \tag{6.2}$$

In the SiMKit, G_{\min} is a variable which is accessible by the circuit simulator. This allows the circuit simulator to improve the convergence properties of a circuit by making use of so-called ' G_{\min} -stepping'.

In the Verilog-A version of PSP, G_{\min} is set to a fixed value $G_{\min} = 1 \cdot 10^{-15} \; \mathrm{S.}^1$

6.5.2 Implementation of parasitic resistances

From PSP 102.2 onwards, a network of parasitic resistors has been inserted around the intrinsic MOSFET. If the user sets one or more of these resistance values to zero, the associated internal node(s) could be shorted to one of its neighbors, reducing the size of the matrix in the circuit simulator. This phenomenon is called 'node collapse' and is supported by most major circuit simulators.

 $^{^{1}}$ If supported by the circuit simulator, Verilog-A version 2.2 allows the value of G_{\min} to be accessed by the circuit simulator. Once this feature is generally available in Verilog-A compilers, it will be included in PSP as well.

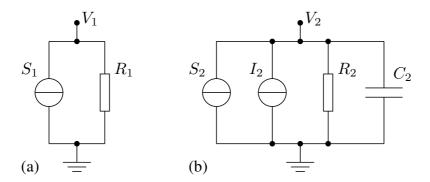


Figure 6.3: The two subcircuits used in PSP's Verilog-A implementation to model the correct frequency dependence of induced gate noise and its correlation with the channel thermal noise.

From SiMKit 3.0 onwards, the SiMKit architecture allows for flexible topologies and therefore supports node collapse in PSP. This functionality is therefore available in circuit simulations with PSP using Spectre, Pstar, and ADS.

Flexible topology (and thus node collapse) is currently not (yet) fully supported by all Verilog-A compilers. This is not a limitation of the Verilog-A language, but rather due to immaturity of present-day Verilog-A compilers. As a result, the official PSP 102.2 Verilog-A code may not be (fully) functional in some Verilog-A compilers.

Please refer to the release notes for more details.

Implementation of the noise-equations 6.5.3

First, the Verilog-A implementation of the noise equations is described in this section. Then, the C-implementation is derived from this by a sequence of approximations.

Verilog-A

In Verilog-A, the possibilities to directly model the frequency-dependence of noise spectral density are limited. Moreover, the only way to include correlation between noise sources is by using (extra) internal nodes. Consequently, the calculation for the description of thermal noise in the channel, induced gate noise, and their correlation is implemented using the subcircuits depicted in Fig. 6.3. The first subcircuit (a) contains a parallel connection of a white noise current source S_1 and a resistor R_1 . The voltage over the elements is denoted by V_1 . The second subcircuit (b) contains a parallel connection of a voltage-controlled current source I_2 , a white-noise current source S_2 , a resistor R_2 , and a capacitor C_2 . The nodal voltage is V_2 . The parameters of these components are given in the table below.

Name	Component	Quantity	Value
R_1	Resistor	Resistance	$1~\Omega$
R_2	Resistor	Resistance	$1~\Omega$
S_1	White noise source	Noise current spectral density	$C_{ m igid}$
S_2	White noise source	Noise current spectral density	$S_{\mathrm{ig}}^{0} \cdot (1 - C_{\mathrm{igid}})$
C_2	Capacitor	Capacitance	$m_{\mathrm{ig}} \cdot C_{\mathrm{Geff}}$
I_2	Voltage-controlled current source	Current	$-\sqrt{S_{ m ig}^0}\cdot V_1$

The values of $m_{\rm ig}$ and $C_{\rm Geff}$ are given by Eqs. (4.245) and (4.248), respectively. Furthermore,

$$S_{\rm ig}^0 = \frac{N_{\rm T}}{m_{\rm ig}} \tag{6.3}$$

and

$$C_{\text{igid}} = \frac{m_{\text{igid}}}{\sqrt{m_{\text{ig}} \cdot m_{\text{id}}}},\tag{6.4}$$

where $m_{\rm id}$ and $m_{\rm igid}$ are given by Eqs. (4.246) and (4.250).

Subcircuit (a) contains a single white noise source, from which the correlated parts of the channel noise and induced gate noise are derived. Now, the thermal noise in the channel is modeled by two contributions:

- 1. An uncorrelated white noise source with current spectral density $S_{id} \cdot (1 C_{igid})$.
- 2. A white noise source with spectral power density $S_{id} \cdot C_{igid}$ which is fully correlated with S_1 .

Subcircuit (b) contains a current noise source S_2 and a voltage controlled current source I_2 , the current of which is controlled by V_1 . The result is that I_2 acts as white noise source which is fully correlated with S_1 (and thus with the second component of the channel noise above). Summarizing, the induced gate noise is modeled by two contributions:

- 1. An uncorrelated white noise source with current spectral density $S_{ig}^0 \cdot (1 C_{igid})$.
- 2. A white noise source with current spectral density $S_{ig}^0 \cdot C_{igid}$, which is fully correlated with S_1 .

These two noise sources in subcircuit (b) are in series with a parallel combination of a resistor and a capacitor. The noise in the current through C_2 has the correct frequency dependence and is used to describe the induced gate noise in the MOSFET.

The total noise current spectral density of the two noise sources S_2 and I_2 is equal to $S_{\rm ig}^0 \cdot (1 - C_{\rm igid}) + S_{\rm ig}^0 \cdot C_{\rm igid} = S_{\rm ig}^0$. Therefore, the total noise spectral density of the current through the capacitor C_2 is given by

$$S_{ig} = \left| \frac{j \cdot \omega \cdot C_2 \cdot R_2}{1 + j \cdot \omega \cdot C_2 \cdot R_2} \right|^2 \cdot S_{ig}^0, \tag{6.5}$$

(where $\omega=2\cdot\pi\cdot f_{\mathrm{op}}$ and $j=\sqrt{-1}$) which is indeed exactly equivalent to Eq. (4.249).

Similarly, the cross-correlation noise spectrum of (i) the current through C_2 induced by noise source I_2 and (ii) the correlated part of the channel noise is given by

$$S_{\text{igid}} = \left(\frac{j \cdot \omega \cdot C_2 \cdot R_2}{1 + j \cdot \omega \cdot C_2 \cdot R_2} \cdot \sqrt{S_{\text{ig}}^0} \cdot C_{\text{igid}}\right) \cdot \left(\sqrt{S_{\text{id}}} \cdot C_{\text{igid}}\right), \tag{6.6}$$

which is, in turn, equivalent to Eq. (4.251).

This shows that the implementation of PSP's noise model in Verilog-A naturally yields the desired correlations and frequency dependence. However, it is at the cost of two additional internal nodes.

Note once more that the equations in Section 4.4 exactly reflect the results of the Verilog-A implementation described above.

SiMKit C-code

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Contrary to the limitation of Verilog-A language, most circuit simulators are able to directly deal with correlated and frequency dependent noise—without the use of additional internal nodes. In order to minimize the simulation time of the model, C-implementations should therefore avoid the use of such internal nodes whenever possible.

In the frequency dependence of S_{ig} and S_{igid} one can roughly distinguish two regions: a frequency dependent part at low frequencies and a constant part at high frequencies. The transition between the two regions occurs at

$$f_{\text{cross}} = \frac{1}{2 \cdot \pi \cdot C_{\text{Geff}} \cdot m_{\text{ig}}}.$$
(6.7)

Eqs. (4.249) and (4.251) ensure a smooth transition between the two regions.

As mentioned before, circuit simulators are typically able to deal with correlated noise without using additional internal nodes. However, to achieve this, two approximations are made:

- 1. The frequency dependence is split in a frequency dependent (power law; $\propto f_{\rm op}^2$ for $S_{\rm ig}$ and $\propto f_{\rm op}$ for $S_{\rm igid}$) and a frequency independent part.
- 2. Only the imaginary part of S_{igid} is considered.

Applying these approximations, it is found from Eq. (4.249) that

$$S_{ig} = \begin{cases} \frac{N_{T}}{m_{ig}} \cdot \left(\frac{f_{op}}{f_{cross}}\right)^{2} & \text{for } f_{op} \leq f_{cross} \\ \frac{N_{T}}{m_{ig}} & \text{for } f_{op} > f_{cross} \end{cases}$$

$$(6.8)$$

Similarly, the imaginary part of Eq. (4.251) is approximated as

$$\operatorname{Im}(S_{\text{igid}}) = \begin{cases} \frac{N_{\text{T}}}{m_{\text{ig}}} \cdot m_{\text{igid}} \cdot \frac{f_{\text{op}}}{f_{\text{cross}}} & \text{for } f_{\text{op}} \leq f_{\text{cross}} \\ \frac{N_{\text{T}}}{m_{\text{ig}}} \cdot m_{\text{igid}} & \text{for } f_{\text{op}} > f_{\text{cross}} \end{cases}$$

$$(6.9)$$

while $Re(S_{igid})$ is set to zero for all frequencies.

In the SiMKit-implementation of PSP, the values above are passed to the circuit simulator to be used in noise calculations.

Section 7

Parameter extraction

The parameter extraction strategy for PSP consists of four main steps:

- 1. Measurements
- 2. Extraction of local parameters at room temperature
- 3. Extraction of temperature scaling parameters
- 4. Extraction of geometry scaling (global) parameters

The above steps will be briefly described in the following sections. Note that the description of the extraction procedure is not 'complete' in the sense that only the most important parameters are discussed and in cases at hand it may be advantageous (or even necessary) to use an adapted procedure.

Throughout this section, bias and current conditions are given for an n-channel transistor only; for a p-channel transistor, all voltages and currents should be multiplied by -1.

As explained in the introduction, the hierarchical setup of PSP (local and global level) allows for the two-step parameter extraction procedure described in this section; this is the recommended method of operation. Nevertheless, it is possible to skip the first steps and start extracting global parameters directly. This procedure is not described here, but the directions below may still be useful.

7.1 Measurements

The parameter extraction routine consists of six different DC-measurements (two of which are optional) and two capacitance measurements.¹ Measurement V and VI are only used for extraction of gate-current, avalanche, and GIDL/GISL parameters.

```
• Measurement I ("idvg"): I_{\rm D} vs. V_{\rm GS} V_{\rm GS}=0\ldots V_{\rm sup} (with steps of maximum 50 mV). V_{\rm DS}=25 or 50 mV V_{\rm BS}=0\ldots -V_{\rm sup} (3 or more values)
```

• Measurement II ("idvgh"): $I_{\rm D}$ vs. $V_{\rm GS}$ $V_{\rm GS}=0\ldots V_{\rm sup}$ (with steps of maximum 50 mV). $V_{\rm DS}=V_{\rm sup}$ $V_{\rm BS}=0\ldots -V_{\rm sup}$ (3 or more values)

 $^{^1}$ The bias conditions to be used for the measurements are dependent on the supply voltage of the process. Of course it is advisable to restrict the range of voltages to this supply voltage $V_{\rm sup}$. Otherwise physical effects atypical for normal transistor operation—and therefore less well described by PSP—may dominate the characteristics.

```
• Measurement III ("idvd"): I_{\rm D} vs. V_{\rm DS} V_{\rm GS}=0\ldots V_{\rm sup} (3 or more values) V_{\rm DS}=0\ldots V_{\rm sup} (with steps of maximum 50 mV). V_{\rm BS}=0 V
```

• Measurement IV ("idvdh", optional): $I_{\rm D}$ vs. $V_{\rm DS}$ $V_{\rm GS}=0\ldots V_{\rm sup}$ (3 or more values) $V_{\rm DS}=0\ldots V_{\rm sup}$ (with steps of maximum 50 mV). $V_{\rm BS}=-V_{\rm sup}$

• Measurement V ("igvg"): $I_{\rm G}$ and $I_{\rm B}$ vs. $V_{\rm GS}$ $V_{\rm GS} = -V_{\rm sup} \dots V_{\rm sup}$ (with steps of maximum 50 mV). $V_{\rm DS} = 0 \dots V_{\rm sup}$ (3 or more values) $V_{\rm BS} = 0$ V

• Measurement VI ("igvgh", optional): $I_{\rm G}$ and $I_{\rm B}$ vs. $V_{\rm GS}$ $V_{\rm GS} = -V_{\rm sup} \dots V_{\rm sup}$ (with steps of maximum 50 mV). $V_{\rm DS} = 0 \dots V_{\rm sup}$ (3 or more values) $V_{\rm BS} = -V_{\rm sup}$

• Measurement VII ("cggvg"): $C_{\rm GG}$ vs. $V_{\rm GS}$ $V_{\rm GS}=-V_{\rm sup}\dots V_{\rm sup}$ (with steps of maximum 50 mV). $V_{\rm DS}=0$ V $V_{\rm BS}=0$ V

• Measurement VIII ("ccgvg"): $C_{\rm CG}$ vs. $V_{\rm GS}$ $V_{\rm GS}=-V_{\rm sup}\dots V_{\rm sup}$ (with steps of maximum 50 mV). $V_{\rm DS}=0$ V $V_{\rm BS}=0$ V

For the extraction procedure, the transconductance $g_{\rm m}$ (for Measurement I and II) and the output conductance $g_{\rm DS}$ (for Measurement III and IV) are obtained by numerical differentiation of the measured I-V-curves. Furthermore, $I_{\rm min}$ is the smallest current which can reliably measured by the system (noise limit) and $I_{\rm T}$ is defined as 10% of the largest measured value of $|I_{\rm D}|$ in Measurement I. The latter will be used to make a rough distinction between the subthreshold and superthreshold region.

The channel-to-gate capacitance $C_{\rm CG}$ in Measurement VIII is the summation of the drain-to-gate capacitance $C_{\rm DG}$ and the source-to-gate capacitance $C_{\rm SG}$ (i.e., source and drain are short-circuited); it is needed to extract overlap capacitance parameters.

The local parameter extraction measurements I through VI have to be performed at room temperature for every device. In addition, capacitance measurements VII and VIII need to be performed for at least a long/wide and a short/wide (i.e., $L=L_{\rm min}$) transistor (at room temperature). Furthermore, for the extraction of temperature scaling parameters measurements I, III, and V have to be performed at different temperatures (at least two extra, typically $-40\,^{\circ}{\rm C}$ and $125\,^{\circ}{\rm C}$) for at least a long wide and a short wide transistor.

7.2 Extraction of local parameters at room temperature

General remarks

The simultaneous determination of *all* local parameters for a specific device is not advisable, because the value of some parameters can be wrong due to correlation and suboptimization. Therefore it is more practical to

split the parameters into several small groups, where each parameter group can be determined using specific measurements. In this section, such a procedure will be outlined.

The extraction of local parameters is performed for every device. In order to ensure that the temperature scaling relations do not affect the behavior at room temperature, the reference temperature **TR** should be set equal to room temperature.

Before starting the parameter extraction procedure, one should make sure that **SWIGATE**, **SWIMPACT**, **SWGIDL**, **SWJUNCAP**, and **TYPE** are set to the desired value. Moreover, **QMC** should be set to 1, in order to include quantum mechanical corrections in the simulations.

It is not the case that all local parameters are extracted for every device. Several parameters are only extracted for one or a few devices, while they are kept fixed for all other devices. Moreover, a number of parameters can generally be kept fixed at their default values and need only occasionally be used for fine-tuning in the optimization procedure. Details are given later in this section.

As a special case, it is generally not necessary to extract values for \mathbf{AX} . In stead, they can be calculated from Eq. (3.63), using $\mathbf{AXO} \sim 18$ and $\mathbf{AXL} \sim 0.25$. It may be necessary to tune the latter value such that the value of \mathbf{AX} is between 2 and 3 for the shortest channel in the technology under study.

It is recommended to start the extraction procedure with the long(est) wide(st) device, then the shortest device with the same width, followed by all remaining devices of the same width in order of decreasing length. Then the next widest-channel devices are extracted, where the various lengths are handled in the same order. In this way, one works ones way down to the narrowest channel devices.

AC-parameters

Some parameters (such as **TOX** and **NP**) that do affect the DC-behavior of a MOSFET can only be extracted accurately from C-V-measurements.² This should be done before the actual parameter extraction from DC-measurements is started. In Tables 7.1 and 7.2 the extraction procedure for the AC-parameters is given.

Table 7.1: AC-parameter extraction procedure for a long channel MOSFET.

Step	Optimized parameters	Fitted on	Abs./Rel.	Conditions
1	VFB,NEFF, DPHIB, NP, COX	VII: C_{GG}	Relative	_
2	Repeat Step 1			

Table 7.2: AC-parameter extraction procedure for a short channel MOSFET. The values of **VFB** and **NP** are taken from the long-channel case.

Step	Optimized parameters	Fitted on	Abs./Rel.	Conditions
1	NEFF, DPHIB, COX	VII: C_{GG}	Relative	_
2	CGOV, NOV	VIII: $C_{\rm CG}$	Relative	$V_{\rm GS} < 0$
3	Repeat Steps 1 and 2			

Starting from the default parameter set and setting **TOX** to a reasonable value (as known from technology), **VFB**, **NEFF**, **DPHIB**, **COX**, and **NP** can be extracted from C_{GG} in Measurement VII for a long, wide device.

Next, **NOV** and **CGOV** can be extracted from C_{CG} in Measurement VIII for a short, wide device (see also Table 7.1), where **VFB** and **NP** are taken from the long channel case. In general, one can assume **TOXOV** = **TOX**.

The value of **TOX** can be determined from **COX** = $\epsilon_{ox} \cdot L \cdot W/\text{TOX}$. If the device is sufficiently long and wide, drawn length and width can be used in this formula. Even better, if Measurement VII is available for a

²Although parameter **NOV** can be determined from overlap gate current, it is nonetheless more accurately determined from Measurement VIII.

few short/wide devices of different lengths, one can extract **TOX** and ΔL from a series of extracted values of **COX** vs. $L_{\rm draw}$.

Some remarks:

- If C-V-measurements are not available, one could revert to values known from the fabrication process. Note that **TOX** and **TOXOV** are *physical* oxide thicknesses; poly-depletion and quantum-mechanical effects are taken care of by the model. If the gate dielectric is not pure SiO₂, one should manually compensate for the deviating dielectric constant.
- In general, **VFB** and **NP** can be assumed independent of channel length and width (so, the long/wide-channel values can be used for all other devices as well). Only if no satisfactory fits are obtained, one could allow for a length dependence (for **NP**) or length *and* width dependence (for **VFB**). Then, one should proceed by extracting **VFB** and/or **NP** from capacitance measurements for various channel geometries, fit Eq. (3.12) / Eq. (3.32) to the result and use interpolated values in the DC parameter extraction procedure.
- The value of parameter **TOX** profoundly influences both the DC- and AC-behavior of the PSP-model and thus the values of many other parameters. It is therefore very important that this parameter is determined (as described above) and *fixed* before the rest of the extraction procedure is started.

If desired (e.g., for RF-characterization), parameters for several parasitic capacitances (gate-bulk overlap, fringe capacitance, etc.) can be extracted as well (**CGBOV** and **CFR**). However, this requires additional capacitance measurements

The obtained values of **VFB**, **TOX**, **TOXOV**, **NP**, and **NOV** can now be used in the DC-parameter extraction procedure. The above values of **NEFF** and **DPHIB** can be disregarded; they will be determined more accurately from the DC-measurements.

In devices with strong lateral non-uniform doping, the threshold voltage in AC-measurements may deviate significantly from that in DC-measurements. If that is the case, values for **NEFF** and **DPHIB** obtained from DC-measurements may not be satisfactory to describe AC-measurements. Then, one has the option to set $\mathbf{SWDELVTAC} = 1$, $\mathbf{DELVTAC} = \mathbf{DPHIB}_{ac} - \mathbf{DPHIB}_{dc}$, and $\mathbf{FACNEFFAC} = \mathbf{NEFF}_{ac}/\mathbf{NEFF}_{dc}$ to get a good description of both the DC and the AC measurements.

DC-parameters

Before the optimization is started a reasonably good starting value has to be determined, both for the parameters to be extracted and for the parameters which remain constant. For most parameters to be extracted for a *long* channel device, the default values from local parameters in Section 2.5.2 can be taken as initial values. Exceptions are given in Table 7.3. Starting from these values, the optimization procedure following the scheme below is performed. This method yields a proper set of parameters after the repetition indicated as the final step in the scheme. Experiments with transistors of several processes show that repeating those steps more than once is generally not necessary.

For an accurate extraction of parameter values, the parameter set for a long-channel transistor has to be determined first. In the long-channel case most of the mobility related parameters (i.e. MUE and THEMU) and the gate tunneling parameters (GCO, GC2, and GC3) are determined and subsequently fixed for the shorter-channel devices.

In Table 7.4 the complete DC extraction procedure for long-channel transistors is given. The magnitude of the simulated $I_{\rm D}$ and the overall shape of the simulated $I_{\rm D}$ - $V_{\rm GS}$ -curve is roughly set in Step 1. Next the parameters **NEFF**, **DPHIB**, and **CT**—which are important for the subthreshold behavior—are optimized in Step 2, neglecting short-channel effects such as drain-induced barrier-lowering (DIBL). After that, the mobility parameters are optimized in Step 3, neglecting the influence of series-resistance. In Step 4 a preliminary value of the velocity saturation parameter is obtained, and subsequently the conductance parameters **ALP**, **ALP1**, **ALP2**, and **VP** are determined in Step 5. A more accurate value of **THESAT** can now be obtained using Step 6. The gate current parameters are determined in Steps 7 and 8, where it should be noted that **GCO** should only be extracted if the influence of gate-to-bulk tunneling is visible in the measurements. This is usually the

Table 7.3: Initial values for local parameter extraction for a *long*-channel device. For parameters which are not listed in this table, the default value (as given in Section 2.5.2) can be used as initial value.

Parameter	Initial value
BETN	$0.03 \cdot W/L$
RS	0
THESAT	0.1
AX	12
A1	0

Table 7.4: DC-parameter extraction procedure for a long-channel MOSFET. The parameters VFB, TOX, TOXOV, NP, and NOV must be taken from *C-V*-measurements. The optimization is either performed on the absolute or relative deviation between model and measurements, as shown in the table.

Step	Optimized parameters	Fitted on	Abs./Rel.	Conditions
1	NEFF, BETN, MUE, THEMU ^a	I: $I_{ m D}$	Absolute	_
2	NEFF, DPHIB, CT, GFACNUD	I: $I_{ m D}$	Relative	$I_{ m min} < I_{ m D} < I_{ m T}$
3	MUE, THEMU a , CS, XCOR, BETN	I: $I_{\rm D}, g_{\rm m}$	Absolute	-
4	THESAT	III: $I_{ m D}$	Absolute	_
5	ALP , $ALP1$, $ALP2$, VP^a , (AX)	III: g_{DS}	Relative	_
6	THESAT	II: I_{D}	Absolute	_
7	$IGINV, GC2^a, GC3^a$	$V:I_{\mathrm{G}}$	Relative	$I_{ m G} > I_{ m min}$
8	$IGOV, (GCO^a)$	$V:I_{\mathrm{G}}$	Relative	$V_{ m GS} < 0$ V, $I_{ m G} < -I_{ m min}$
9	$A1, A2^a, A3$	$V:I_{\mathrm{B}}$	Relative	$V_{\mathrm{GS}} > 0$ V, $I_{\mathrm{B}} < -I_{\mathrm{min}}$
10	A4	$ ext{VI:}\ I_{ ext{B}}$	Relative	$V_{\mathrm{GS}} > 0$ V, $I_{\mathrm{B}} < -I_{\mathrm{min}}$
11	$\mathbf{AGIDL}, \mathbf{BGIDL}^a$	$V:I_{\mathrm{B}}$	Relative	$V_{\mathrm{GS}} < 0$ V, $I_{\mathrm{B}} < -I_{\mathrm{min}}$
12	\mathbf{CGIDL}^a	$ ext{VI:}\ I_{ ext{B}}$	Relative	$V_{\mathrm{GS}} < 0$ V, $I_{\mathrm{B}} < -I_{\mathrm{min}}$
13	Repeat Steps 2 – 12			

 $[^]a$ Only extracted for the widest long channel device and fixed for all other geometries.

case if $V_{\text{sup}} \gtrsim |\mathbf{VFB}|$. This is followed by the weak-avalanche parameters in Step 9 and (optionally) 10, and finally, the gate-induced leakage current parameters are optimized in Step 11 and (optionally) 12.

After completion of the extraction for the long-channel device, it is recommended to first extract parameters for the shortest-channel device (of the same width). The mobility-reduction parameters (**MUE**, **THEMU**) and the gate tunneling probability factors (**GCO**, **GC2**, **GC3**) found from the corresponding long-channel device should be used. The extraction procedure as given in Table 7.5 should be used.

Once the value for **RS** has been found from the shortest device, it should be copied into the long-channel parameter set and steps 2–3 (Table 7.4) should be repeated, possibly leading to some readjustment of **MUE** and **THEMU**. If necessary, this procedure must be repeated. Similarly—once the value of **THESATG** and **THESATB** have been determined from the shortest widest channel device—steps 4, 5, and 6 of the long-channel extraction procedure (Table 7.4) must be repeated to obtain updated values for **THESAT**, **ALP**, **ALP1**, and **ALP2**

If consistent parametersets have been found for the longest and shortest channel device, the extraction procedure

Table 7.5: DC-parameter extraction procedure for a short-channel MOSFET. Parameters MUE, THEMU, VP, GCO, GC2, GC3, A2, A4, BGIDL, and CGIDL are taken from the corresponding long-channel case. The optimization is either performed on the absolute or relative deviation between model and measurements, as indicated in the table.

Step	Optimized parameters	Fitted on	Abs./Rel.	Conditions
1	NEFF, DPHIB, BETN, RS ^a	I: I_{D}	Absolute	_
2	NEFF, DPHIB, CT, GFACNUD, VSB-NUD b , DVSBNUD b	I: I_{D}	Relative	$I_{ m min} < I_{ m D} < I_{ m T}$
3	BETN, RS^a , XCOR	I: $I_{\rm D}, g_{\rm m}$	Absolute	_
4	THESAT	III: $I_{ m D}$	Absolute	_
5	ALP, ALP1, ALP2, CF, (AX)	III: $g_{\rm DS}$	Relative	_
6	\mathbf{CFB}^b	IV: g_{DS}	Relative	_
7	THESAT, THESATG b , THESATB b	II: $I_{\rm D}, g_{\rm m}$	Absolute	_
8	IGINV, IGOV	$V:I_{\mathrm{G}}$	Relative	$ I_{ m G} >I_{ m min}$
9	A1, A3	$V:I_{\mathrm{B}}$	Relative	$V_{\mathrm{GS}} > 0$ V, $I_{\mathrm{B}} < -I_{\mathrm{min}}$
10	AGIDL	$V:I_{\mathrm{B}}$	Relative	$V_{\mathrm{GS}} < 0$ V, $I_{\mathrm{B}} < -I_{\mathrm{min}}$
11	Repeat Steps 2 – 10			

^aOnly extracted for the *shortest* channel of each width and fixed for all other geometries.

as given in Table 7.5 can be executed for all intermediate channel lengths. The extracted parameter values of the next-longer device can be used as initial values.

Finally, the parameters **GFACNUD**, **VSBNUD**, and **DVSBNUD** should only be used if the description of the body effect is not satisfactory otherwise. For this, the NUD-model must be invoked by setting **SWNUD** = 1.

7.3 Extraction of Temperature Scaling Parameters

For a specific device, the temperature scaling parameters can be extracted after determination of the local parameters at room temperature. In order to do so, measurements I, II and IV need to be performed at various temperature values (at least two values different from room temperature, typically $-40\,^{\circ}\text{C}$ and $125\,^{\circ}\text{C}$), at least for a long wide device and a short wide device. If the reference temperature TR has been chosen equal to room temperature (as recommended in Section 7.2), the modeled behavior at room temperature is insensitive to the value of the temperature scaling parameters. As a first-order estimate of the temperature scaling parameter values, the default values as given by local parameters in Section 2.5.2 can be used. Again the parameter extraction scheme is slightly different for the long-channel and for the short-channel case.

For an accurate extraction, the temperature scaling parameters for a long-wide-channel device have to be determined first. In the long-wide-channel case the carrier mobility parameters can be determined, and they are subsequently fixed for all other devices. In Table 7.6 the appropriate extraction procedure is given. In Step 1 the subthreshold temperature dependence is optimized, followed by the optimization of mobility reduction parameters in Step 2. Next the temperature dependence of velocity saturation is optimized in Step 3. In the subsequent steps, parameters for the temperature dependence of the gate current, the impact ionization current and gate-induced drain leakage are determined. The determined values of the mobility reduction temperature scaling parameters (i.e., STMUE, STTHEMU, STCS, and STXCOR) are copied to all other devices and kept fixed during the remainder of the temperature-scaling parameter extraction procedure. Step 1 and 2 could then be performed on one or more long narrow devices as well (for STVFB, STBETN, and STTHESAT only).

Next the extraction procedure as given in Table 7.7 is carried out for several short devices of different widths. Preferably, the extraction is done first for a short narrow device, such that the determined value of **STRS** can

^bOnly extracted for the *shortest widest* device and fixed for all other geometries.

Table 7.6: Temperature scaling parameter extraction procedure for a long wide channel MOSFET. This scheme only makes sense if measurements have been performed at one or (preferably) more temperatures which differ from room temperature.

Step	Optimized parameters	Fitted on	Abs./Rel.	Conditions
1	$STVFB^a$	I: $I_{ m D}$	Relative	$I_{ m D} < I_{ m T}$
2	STBETN ^a , STMUE, STTHEMU,	I: I_{D}	Absolute	-
	STCS, STXCOR			
3	$STTHESAT^a$	II: I_{D}	Absolute	
4	STIG	$V:I_{\mathrm{G}}$	Relative	$ I_{ m G} >I_{ m min}$
5	STA2	$V:I_{\mathrm{B}}$	Relative	$V_{\mathrm{GS}} > 0$ V, $I_{\mathrm{B}} < -I_{\mathrm{min}}$
6	STBGIDL	$ ext{V:}\ I_{ ext{B}}$	Relative	$V_{\mathrm{GS}} < 0 \mathrm{\ V}, I_{\mathrm{B}} < -I_{\mathrm{min}}$

^aAlso extracted for one or more long narrow devices.

Table 7.7: Temperature scaling parameter extraction procedure for short-channel MOSFETs (both wide and narrow). This scheme only makes sense if measurements have been performed at one or (preferably) more temperatures which differ from room temperature.

Step	Optimized parameters	Fitted on	Abs./Rel.	Conditions
1	STVFB	I: I_{D}	Relative	$V_{\rm GS} < V_{ m T}$
2	STBETN, STRS a	I: I_{D}	Absolute	$V_{\rm GS} > V_{\rm T}$
3	STTHESAT	II: $I_{ m D}$	Absolute	_

^aOnly extracted for a short *narrow* device and fixed for all other geometries.

be used during the extraction of the wider devices.

7.4 Extraction of Geometry Scaling Parameters

The aim of the complete extraction procedure is the determination of the geometry scaling parameters (global parameters), i.e., a single set of parameters (see Section 2.5.2) which gives a good description of the MOSFET-behavior over the full geometry range of a CMOS technology.

Determination of ΔL and ΔW

An extremely important part of the geometry scaling extraction scheme is an accurate determination of ΔL and ΔW , see Eqs. (3.6) and (3.7).³ Since it affects the DC-, the AC- as well as the noise model and, moreover, it can heavily influence the quality of the resulting global parameter set, it is very important that this step is carried out with care.

Traditionally, ΔW can be determined from the extrapolated zero-crossing in **BETN** versus mask width W. In a similar way ΔL can be determined from 1/BETN versus mask length L. For modern MOS devices with pocket implants, however, it has been found that the above ΔL extraction method is no longer valid [11, 12]. Another, more accurate method is to measure the gate-to-bulk capacitance C_{GB} in accumulation for different channel lengths [12, 13]. In this case the extrapolated zero-crossing in the C_{GB} versus mask length L curve will

 $^{^3}$ Note that $\Delta L_{\rm PS}$ and $\Delta W_{\rm OD}$ are expected to be known from the fabrication process. So, in fact, only **LAP** and **WOT** are extracted from the electrical measurements.

give ΔL . Similarly, the extracted values for **COX** (from the procedure in Table 7.1 and 7.2) vs. mask length L may be used for this purpose. Unfortunately for CMOS technologies in which gate current is non-negligible, capacitance measurements may be hampered by gate current [14]. In this case gate current parameter **IGINV** plotted as a function of channel length L may be used to extract ΔL [14]. If possible, ΔL extraction from C-V-measurements is the preferred method.

Finally, LOV can be obtained from (a series of) extracted values of CGOV from one or more short devices.

From local to global

First of all, the global parameters **TYPE**, **QMC**, and the 'switch'-parameters should be set to the appropriate value. Next, parameters for which no geometrical scaling rules exist must be taken directly from the local set (this applies to **TR**, **TOXO**, **VNSUBO**, **NSLPO**, **DNSUBO**, **TOXOVO**, **NOVO**, **CFBO**, **STMUEO**, **THE-MUO**, **STTHEMUO**, **STCSO**, **STXCORO**, **FETAO**, **STRSO**, **RSBO**, **RSGO**, **THESATBO**, **THESATGO**, **VPO**, **A2O**, **STA2O**, **GCOO**, **STIGO**, **GC2O**, **GC3O**, **CHIBO**, **BGIDLO**, **STBGIDLO**, **CGIDLO**, and **DTA**). Generally, these parameters have been left at their default values or they have been extracted for one device only and subsequently fixed for all other devices. The parameters **LVARO**, **LVARL**, **LVARW**, **WVARO**, **WVARL**, and **WVARW** should be known from technology.

Once the values of ΔL and ΔW are firmly established (as described above), **LAP** and **WOT** can be set and the actual extraction procedure of the geometry scaling parameters can be started. It consists of several *independent* sub-steps (which can be carried out in random order), one for each geometry dependent local parameter.

To illustrate such a sub-step, the local parameter \mathbf{CT} is taken as an example. The relevant geometry scaling equation from Section 3.2 is Eq. (3.33), from which it can be seen that \mathbf{CTO} , \mathbf{CTL} , \mathbf{CTLEXP} , and \mathbf{CTW} are the global parameters which determine the value of \mathbf{CT} as a function of L and W. First, the extracted \mathbf{CT} of each device in a length-series of measured (preferably wide) devices are considered as a function of L. In this context \mathbf{CTO} , \mathbf{CTL} , and \mathbf{CTLEXP} are optimized such that the fit of Eq. (3.33) to the extracted \mathbf{CT} -values is as good as possible, while keeping \mathbf{CTW} fixed at 0. Then \mathbf{CTW} is determined by considering the extracted \mathbf{CT} -values from a length-series of measured narrow devices. Finally, the four global parameters may be fine-tuned by optimizing all four parameters to all extracted \mathbf{CT} -values simultaneously. The default values given in Section 2.5.2 are good initial values for the optimization procedure.

All other parameters can be extracted in a similar manner. The local parameters **BETN** and **NEFF** have quite complicated scaling rules, particularly due to the non-uniform doping profiles employed in modern CMOS technologies. Therefore, a few additional guidelines are in place.

- The optimization procedure for **BETN** is facilitated if not **BETN**, but **BETN**_{sq} $\stackrel{\text{def}}{=}$ **BETN** · $L_{\text{E}}/W_{\text{E}}$ is considered.
- Starting from the default values, first **UO**, **FBET1**, **LP1**, **FBET2**, and **LP2** should be determined from a length-series of wide devices. Then **BETW1**, **BETW2**, and **WBET** should be determined from a width-series of long devices. Finally, **FBET1W** and **LP1W** can be found by considering some short narrow devices.
- Starting from the default values, first extract FOL1, FOL2, NSUBO, NPCK, and LPCK from a length-series of wide devices. Here, NSUBO determines the long-channel value of NEFF. Moreover, NPCK and LPCK determine the increase of NEFF for shorter channels (reverse short channel effect), while FOL1 and FOL2 are used to describe the decrease of NEFF for very short channels (short channel effect).
- Then **NSUBW** and **WSEG** can be determined form a width-series of long devices. Finally, **NPCKW**, **LPCKW** and **WEGP** are determined from a width-series of short devices.
- Especially for **BETN** and **NEFF** it is advisable—after completing the procedure described above—to fine tune the global parameters found by considering all extracted values of **BETN** (or **NEFF**) simultaneously.

Note that in many cases it may not be necessary to use the full flexibility of PSP's parameter scaling, e.g., for many technologies **NP** and **VFB** may be considered as independent of geometry. If such a geometry-

independence is anticipated, the corresponding local parameter should be fixed during local parameter extraction. Only if the resulting global parameter set is not satisfactory, the parameter should be allowed to vary during a subsequent optimization round.

Fine tuning

Once the complete set of global parameters is found, the global model should give an accurate description of the measured I-V-curves and capacitance measurements. Either for fine tuning or to facilitate the extraction of global parameters for which the geometry scaling of the corresponding extracted local parameters is not well-behaved, there are two more things that can be done.

- Local parameters for which the fitting of global parameters was completed satisfactorily could be replaced by the values calculated from the geometrical scaling rules and fixed. Then one could redo (parts
 of) the local parameter extraction procedure for the remaining local parameters, making them less sensitive for cross-correlations.
- Small groups of global parameters may be fitted directly to the measurements of a well-chosen series of devices, using the global model.

7.5 Summary – Geometrical scaling

Summarizing, for the determination of a full parameter set, the following procedure is recommended.

- 1. Determine local parameter sets (VFB, NEFF, ...) for all measured devices, as explained in Section 7.2 and 7.3.
- 2. Find ΔL and ΔW .
- 3. Determine the global parameters by fitting the appropriate geometry scaling rules to the extracted local parameters.
- 4. Finally, the resulting global can be fine-tuned, by fitting the result of the scaling rules and current equations to the measured currents of all devices simultaneously.

7.6 Extraction of Binning Parameters

In this section, expressions will be given for the parameters in the binning scaling rules, **POYYY**, **PLYYY**, **PWYYY**, and **PLWYYY**, as given in Section 3.3. These coefficients will be expressed in terms of parameter values at the corners of bin (see Fig. 7.1). These expressions can be easily found by substituting the parameter values at the bin corners into the binning scaling rules and inverting the resulting four equations. Note once more that this results in a *separate parameter set for each bin*.

In the expression below, the value of parameter **YYY** at bin corner (L_i, W_j) is denoted by Y_{ij} (i = 1, 2, j = 1, 2). Moreover, $\Delta L = L_2 - L_1$, $\Delta W = W_2 - W_1$, $A = 1/(\Delta L \cdot \Delta W)$.

1. Coefficients for type I scaling

$$\mathbf{POYYY} = A \cdot (L_1 \cdot W_1 \cdot Y_{11} - L_1 \cdot W_2 \cdot Y_{12} - L_2 \cdot W_1 \cdot Y_{21} + L_2 \cdot W_2 \cdot Y_{22})$$
(7.1)

$$\mathbf{PLYYY} = A \cdot \frac{L_1 \cdot L_2}{L_{\text{EN}}} \cdot \left(-W_1 \cdot Y_{11} + W_2 \cdot Y_{12} + W_1 \cdot Y_{21} - W_2 \cdot Y_{22} \right)$$
(7.2)

$$\mathbf{PWYYY} = A \cdot \frac{W_1 \cdot W_2}{W_{\text{EN}}} \cdot \left(-L_1 \cdot Y_{11} + L_1 \cdot Y_{12} + L_2 \cdot Y_{21} - L_2 \cdot Y_{22} \right)$$
(7.3)

$$\mathbf{PLWYYY} = A \cdot \frac{L_1 \cdot L_2 \cdot W_1 \cdot W_2}{L_{\text{EN}} \cdot W_{\text{EN}}} \cdot (Y_{11} - Y_{12} - Y_{21} + Y_{22})$$
 (7.4)

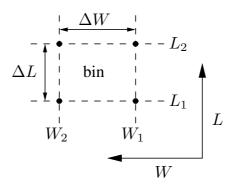


Figure 7.1: Schematic view of a bin, showing the coordinates of the four corners. Note that L_1 , L_2 , W_1 , and W_2 denote the *effective* length and width (L_E and W_E) at the bin corners.

2. Coefficients for type II scaling

$$\mathbf{POYYY} = A \cdot (L_2 \cdot W_2 \cdot Y_{11} - L_2 \cdot W_1 \cdot Y_{12} - L_1 \cdot W_2 \cdot Y_{21} + L_1 \cdot W_1 \cdot Y_{22}) \tag{7.5}$$

$$\mathbf{PLYYY} = A \cdot L_{\text{EN}} \cdot (-W_2 \cdot Y_{11} + W_1 \cdot Y_{12} + W_2 \cdot Y_{21} - W_1 \cdot Y_{22})$$
(7.6)

$$\mathbf{PWYYY} = A \cdot W_{\text{EN}} \cdot (-L_2 \cdot Y_{11} + L_2 \cdot Y_{12} + L_1 \cdot Y_{21} - L_1 \cdot Y_{22}) \tag{7.7}$$

$$PLWYYY = A \cdot L_{EN} \cdot W_{EN} \cdot (Y_{11} - Y_{12} - Y_{21} + Y_{22})$$
(7.8)

3. Coefficients for type III scaling

$$\mathbf{POYYY} = A \cdot (-L_1 \cdot W_2 \cdot Y_{11} + L_1 \cdot W_1 \cdot Y_{12} + L_2 \cdot W_2 \cdot Y_{21} - L_2 \cdot W_1 \cdot Y_{22}) \tag{7.9}$$

$$\mathbf{PLYYY} = A \cdot \frac{L_1 \cdot L_2}{L_{\text{EN}}} \cdot (W_2 \cdot Y_{11} - W_1 \cdot Y_{12} - W_2 \cdot Y_{21} + W_1 \cdot Y_{22})$$
 (7.10)

$$\mathbf{PWYYY} = A \cdot W_{\text{EN}} \cdot (L_1 \cdot Y_{11} - L_1 \cdot Y_{12} - L_2 \cdot Y_{21} + L_2 \cdot Y_{22})$$
 (7.11)

$$\mathbf{PLWYYY} = A \cdot \frac{L_1 \cdot L_2 \cdot W_{\text{EN}}}{L_{\text{EN}}} \cdot (-Y_{11} + Y_{12} + Y_{21} - Y_{22})$$
 (7.12)

Note: For L_1 , L_2 , W_1 , and W_2 in the formulas above one must take the *effective* length and width (L_E and W_E) as defined in Section 3.2.

7.6.1 Binning of BETN

From PSP 103.0 onwards, the binning rule of **BETN** is changed to better match its typical scaling behavior.

• Extract the parameters **POBETN**, **PLBETN**, **PWBETN**, and **PLWBETN** for type I binning by applying Eq. (7.1)-(7.4) to $(L_{\rm E}/W_{\rm E})$ • **BETN** (i.e., not to **BETN** itself).

Section 8

DC Operating Point Output

The DC operating point output facility gives information on the state of a device at its operation point. Beside terminal currents and voltages, the magnitudes of linearized internal elements are given. In some cases meaningful quantities can be derived which are then also given (e.g., $f_{\rm T}$). The objective of the DC operating point facility is twofold:

- Calculate small-signal equivalent circuit element values
- Open a window on the internal bias conditions of the device and its basic capabilities.

All accessible quantities are described in the table below. The symbols in the 'value' column are defined in Section 4. Besides, the following notation is used: $P_D = 1 + k_p \cdot G/4$, where k_p is defined in Eq. (4.20).

Important note: For *all* operating point output the signs are such as if the device is an NMOS. Moreover, whenever there is a reference to the 'drain', this is always the terminal which is acting as drain for the actual bias conditions. This is even true for variables such as **vds** (which is therefore always nonnegative) and the junction-related variables. The output variable **sdint** shows whether or not this 'drain' is the same as the terminal which was named 'drain' in the simulator.

No.	Name	Unit	Value	Description	
0	ctype	_	1 for NMOS, −1 for PMOS	Flag for channel-type	
1	sdint	_	1 if $V'_{\rm DS} \ge 0$, -1 otherwise	Flag for source-drain interchange	
			Current components		
2	ise	A	$I_{ m S}-I_{ m JS}$	Total source current	
3	ige	A	$I_{ m G}$	Total gate current	
4	ide	A	$I_{ m D}-I_{ m JD}$	Total drain current	
5	ibe	A	$I_{ m B}+I_{ m JS}+I_{ m JD}$	Total bulk current	
6	ids	A	$I_{ m DS}$	Drain current, excl. avalanche and tunnel currents	
7	idb	A	$I_{ m avl} + I_{ m gidl} - I_{ m JD}$	Drain-to-bulk current	
8	isb	A	$I_{ m gisl} - I_{ m JS}$	Source-to-bulk current	
9	igs	A	$I_{ m GCS} + I_{ m GSov}$	Gate-source tunneling current	
10	igd	A	$I_{ m GCD} + I_{ m GDov}$	Gate-drain tunneling current	
11	igb	A	$I_{ m GB}$	Gate-bulk tunneling current	
12	igcs	A	$I_{ m GCS}$	Gate-channel tunneling current (source component)	

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No.	Name	Unit	Value	Description
13	igcd	A	$I_{ m GCD}$	Gate-channel tunneling current (drain component)
14	iavl	A	$I_{ m avl}$	Substrate current due to weak-avalanche
15	igisl	A	$I_{ m gisl}$	Gate-induced source leakage current
16	igidl	A	$I_{ m gidl}$	Gate-induced drain leakage current
			Junction currents	
17	ijs	A	$I_{ m JS}$	Total source junction current
18	ijsbot	A	$I_{ m JS, bot}$	Source junction current, bottom component
19	ijsgat	A	$I_{ m JS,gat}$	Source junction current, gate-edge component
20	ijssti	A	$I_{ m JS,sti}$	Source junction current, STI-edge component
21	ijd	A	$I_{ m JD}$	Total drain junction current
22	ijdbot	A	$I_{ m JD,bot}$	Drain junction current, bottom component
23	ijdgat	A	$I_{ m JD,gat}$	Drain junction current, gate-edge component
24	ijdsti	A	$I_{ m JD,sti}$	Drain junction current, STI-edge component
			Voltages	
25	vds	V	$V_{ m DS}$	Drain-source voltage
26	vgs	V	$V_{ m GS}$	Gate-source voltage
27	vsb	V	$V_{ m SB}$	Source-bulk voltage
28	vto	V	$ \begin{array}{cccccccccccccccccccccccccccccccccccc$	Zero-bias threshold voltage
29	vts	V	$ \begin{aligned} \mathbf{VFB} + P_{\mathrm{D}} \cdot (V_{\mathrm{SB}}^{\mathrm{nud}} + \boldsymbol{\phi_{\mathbf{B}}} + 2 \cdot \boldsymbol{\phi_{\mathbf{T}}^{*}}) - V_{\mathrm{SB}}^{\mathrm{nud}} + \\ G \cdot \sqrt{\boldsymbol{\phi_{\mathbf{T}}^{*}} \cdot (V_{\mathrm{SB}}^{\mathrm{nud}} + \boldsymbol{\phi_{\mathbf{B}}} + 2 \cdot \boldsymbol{\phi_{\mathbf{T}}^{*}})} \end{aligned} $	Threshold voltage including back- bias effects
30	vth	V	${f vts} - \Delta V_{ m G}$	Threshold voltage including backbias and drain-bias effects
31	vgt	V	vgs - vth	Effective gate drive voltage including drain- and back-bias effects
32	vdss	V	$V_{ m dsat}$	Drain saturation voltage at actual bias
33	vsat	V	$V_{ m DS}-V_{ m dsat}$	Saturation limit
			(Trans-)conductances	
34	gm	A/V	$\partial {f ide}/\partial V_{ m GS}$	Transconductance
35	gmb	A/V	$-\partial {f ide}/\partial V_{ m SB}$	Substrate-transconductance
36	gds	A/V	$\partial {f ide}/\partial V_{ m DS}$	Output conductance
37	gjs	A/V	$-\partial {f ijs}/\partial V_{ m SB}$	Source junction conductance

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No.	Name	Unit	Value	Description	
38	gjd	A/V	$-(\partial \mathbf{ijd}/\partial V_{\mathrm{DS}} + \partial \mathbf{ijd}/\partial V_{\mathrm{SB}})$	Drain junction conductance	
			Capacitances		
39	cdd	F	$\partial Q_{ m D}^{(i)}/\partial V_{ m DS}$	Drain capacitance	
40	cdg	F	$-\partial Q_{ m D}^{(i)}/\partial V_{ m GS}$	Drain-gate capacitance	
41	cds	F	cdd - cdg - cdb	Drain-source capacitance	
42	cdb	F	$\partial Q_{ m D}^{(i)}/\partial V_{ m SB}$	Drain-bulk capacitance	
43	cgd	F	$-\partial Q_{ m G}^{(i)}/\partial V_{ m DS}$	Gate-drain capacitance	
44	cgg	F	$\partial Q_{ m G}^{(i)}/\partial V_{ m GS}$	Gate capacitance	
45	cgs	F	cgg - cgd - cgb	Gate-source capacitance	
46	cgb	F	$\partial Q_{ m G}^{(i)}/\partial V_{ m SB}$	Gate-bulk capacitance	
47	csd	F	$-\partial Q_{ m S}^{(i)}/\partial V_{ m DS}$	Source-drain capacitance	
48	csg	F	$-\partial Q_{ m S}^{(i)}/\partial V_{ m GS}$	Source-gate capacitance	
49	css	F	csg + csd + csb	Source capacitance	
50	csb	F	$\partial Q_{ m S}^{(i)}/\partial V_{ m SB}$	Source-bulk capacitance	
51	cbd	F	$-\partial Q_{ m B}^{(i)}/\partial V_{ m DS}$	Bulk-drain capacitance	
52	cbg	F	$-\partial Q_{ m B}^{(i)}/\partial V_{ m GS}$	Bulk-gate capacitance	
53	cbs	F	cbb - cbd - cbg	Bulk-source capacitance	
54	cbb	F	$-\partial Q_{ m B}^{(i)}/\partial V_{ m SB}$	Bulk capacitance	
55	cgsol	F	$\partial (Q_{\rm sov} + Q_{\rm ofs})/\partial V_{\rm GS}$	Total gate-source overlap capaci	
56	cgdol	F	$\partial (Q_{ m dov} + Q_{ m ofd})/\partial V_{ m DS}$	Total gate-drain overlap capaci tance	
			Junction capacitance	s	
57	cjs	F	$C_{ m JS}$	Total source junction capacitance	
58	cjsbot	F	$C_{ m JS,bot}$	Source junction capacitance, bot tom component	
59	cjsgat	F	$C_{ m JS,gat}$	Source junction capacitance, gate- edge component	
60	cjssti	F	$C_{ m JS,sti}$	Source junction capacitance, STI- edge component	
61	cjd	F	$C_{ m JD}$	Total drain junction capacitance	
62	cjdbot	F	$C_{ m JD, bot}$	Drain junction capacitance, botton component	
63	cjdgat	F	$C_{ m JD,gat}$	Drain junction capacitance, gate edge component	
64	cjdsti	F	$C_{ m JD,sti}$	Drain junction capacitance, STI edge component	
			Miscellaneous		
65	weff	m	$W_{ m E}$ Effective channel width for georical models		
66	leff	m	$L_{ m E}$	Effective channel length for geo-	
00				metrical models	

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No.	Name	Unit	Value	Description
68	rout	Ω	1/gds	Small-signal output resistance
69	vearly	V	ide /gds	Equivalent Early voltage
70	beff	A/V^2	$2 \cdot {f ide} /{f vgt}^2$	Gain factor
71	fug	Hz	$\mathbf{gm}/[2\cdot\pi\cdot(\mathbf{cgg}+\mathbf{cgsol}+\mathbf{cgdol})]$	Unity gain frequency at actual bias
			Noise	
72	sqrtsff	V/√Hz	$\sqrt{S_{ m fl}(1~{ m kHz})}/{ m gm}$	Input-referred RMS white noise voltage density at 1 kHz
73	sqrtsfw	V/√Hz	$\sqrt{S_{ m id}}/{ m f gm}$	Input-referred RMS white noise voltage density
74	sid	A^2/Hz	$S_{ m id}$	Channel thermal noise current density
75	sig	${ m A}^2/{ m Hz}$	$S_{ m ig}(1~{ m kHz})$	Induced gate noise current density at 1 kHz
76	cigid	_	$rac{m_{ m igid}}{\sqrt{m_{ m ig}\cdot m_{ m id}}}$	Imaginary part of correlation coefficient between $S_{\rm ig}$ and $S_{\rm id}$
77	fknee	Hz	$1{\rm Hz}\cdot S_{\rm fl}(1{\rm Hz})/S_{\rm id}$	Cross-over frequency above which white noise is dominant
78	sigs	${ m A}^2/{ m Hz}$	$S_{ m igs}$	Gate-source current noise spectral density
79	sigd	A^2/Hz	$S_{ m igd}$	Gate-drain current noise spectral density
80	siavl	${ m A}^2/{ m Hz}$	$S_{ m avl}$	Impact ionization current noise spectral density
81	ssi	${ m A}^2/{ m Hz}$	•	
82	sdi	${ m A}^2/{ m Hz}$	$S_{ m D,I}$	Total drain junction current noise spectral density

From PSP 103.0 onwards, the values of local parameters are provided in the operating point output. They are listed in the table below.

No.	Name	Unit	Description
			Process Parameters
0	lp_vfb	V	Local parameter VFB after T-scaling and clipping
1	lp_stvfb	V/K	Local parameter STVFB after clipping
2	lp_tox	m	Local parameter TOX after clipping
3	lp_epsrox	_	Local parameter EPSROX after clipping
4	lp_neff	m^{-3}	Local parameter NEFF after clipping
5	lp_facneffac	_	Local parameter FACNEFFAC after clipping
6	lp_gfacnud	_	Local parameter GFACNUD after clipping
7	lp_vsbnud	V	Local parameter VSBNUD after clipping
8	lp_dvsbnud	V	Local parameter DVSBNUD after clipping
9	lp_vnsub	V	Local parameter VNSUB after clipping
10	lp_nslp	V	Local parameter NSLP after clipping
11	lp_dnsub	V^{-1}	Local parameter DNSUB after clipping
12	lp_dphib	V	Local parameter DPHIB after clipping
13	lp_delvtac	V	Local parameter DELVTAC after clipping
14	lp_np	m^{-3}	Local parameter NP after clipping
15	lp_ct	_	Local parameter CT after clipping
16	lp_toxov	m	Local parameter TOXOV after clipping
17	lp_toxovd	m	Local parameter TOXOVD after clipping
18	lp_nov	m^{-3}	Local parameter NOV after clipping
19	lp_novd	m^{-3}	Local parameter NOVD after clipping
			DIBL Parameters
20	lp_cf	_	Local parameter CF after clipping
21	lp_cfb	V^{-1}	Local parameter CFB after clipping
			Mobility Parameters
22	lp_betn	$m^2/V/s$	Local parameter BETN after T-scaling and clipping
23	lp_stbet	_	Local parameter STBET after clipping
24	lp_mue	m/V	Local parameter MUE after T-scaling and clipping
25	lp_stmue	_	Local parameter STMUE after clipping
26	lp_themu	_	Local parameter THEMU after T-scaling and clipping
27	lp_stthemu	_	Local parameter STTHEMU after clipping
28	lp_cs	_	Local parameter CS after T-scaling and clipping
29	lp_stcs	_	Local parameter STCS after clipping
30	lp_xcor	V^{-1}	Local parameter XCOR after T-scaling and clipping
31	lp_stxcor	-	Local parameter STXCOR after clipping
32	lp_feta		Local parameter FETA after clipping
		Seri	ies Resistance Parameters
33	lp_rs	Ω	Local parameter RS after T-scaling and clipping
34	lp_strs	_	Local parameter STRS after clipping
			continued on next page

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No.	Name	Unit	Description
35	lp_rsb	V^{-1}	Local parameter RSB after clipping
36	lp_rsg	\mathbf{V}^{-1}	Local parameter RSG after clipping
		Velo	city Saturation Parameters
37	lp_thesat	V^{-1}	Local parameter THESAT after T-scaling and clipping
38	lp_stthesat	_	Local parameter STTHESAT after clipping
39	lp_thesatb	V^{-1}	Local parameter THESATB after clipping
40	lp_thesatg	V^{-1}	Local parameter THESATG after clipping
		Satu	ıration Voltage Parameters
41	lp_ax	_	Local parameter AX after clipping
		Channel Len	ogth Modulation (CLM) Parameters
42	lp_alp	-	Local parameter ALP after clipping
43	lp_alp1	V	Local parameter ALP1 after clipping
44	lp_alp2	\mathbf{V}^{-1}	Local parameter ALP2 after clipping
45	lp_vp	V	Local parameter VP after clipping
		Impa	ct Ionization (II) Parameters
46	lp_a1	_	Local parameter A1 after clipping
47	lp_a2	V	Local parameter A2 after T-scaling and clipping
48	lp_sta2	_	Local parameter STA2 after clipping
49	lp_a3	_	Local parameter A3 after clipping
50	lp_a4	$1/\sqrt{V}$	Local parameter A4 after clipping
		G	ate Current Parameters
51	lp_gco	_	Local parameter GCO after clipping
52	lp_iginv	A	Local parameter IGINV after T-scaling and clipping
53	lp_igov	A	Local parameter IGOV after T-scaling and clipping
54	lp_igovd	A	Local parameter IGOVD after T-scaling and clipping
55	lp_stig	_	Local parameter STIG after clipping
56	lp_gc2	_	Local parameter GC2 after clipping
57	lp_gc3	_	Local parameter GC3 after clipping
58	lp_chib	V	Local parameter CHIB after clipping
		Gate-Ind	uced Drain Leakage Parameters
59	lp_agidl	A/V^3	Local parameter AGIDL after clipping
60	lp_agidld	A/V^3	Local parameter AGIDLD after clipping
61	lp_bgidl	V	Local parameter BGIDL after T-scaling and clipping
62	lp_bgidld	V	Local parameter BGIDLD after T-scaling and clipping
63	lp_stbgidl	V/K	Local parameter STBGIDL after clipping
64	lp_stbgidld	V/K	Local parameter STBGIDLD after clipping
65	lp_cgidl	-	Local parameter CGIDL after clipping
66	lp_cgidld	_	Local parameter CGIDLD after clipping

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No.	Name	Unit	Description
		Cł	narge Model Parameters
67	lp_cox	F	Local parameter COX after clipping
68	lp_cgov	F	Local parameter CGOV after clipping
69	lp_cgovd	F	Local parameter CGOVD after clipping
70	lp_cgbov	F	Local parameter CGBOV after clipping
71	lp_cfr	F	Local parameter CFR after clipping
72	lp_cfrd	F	Local parameter CFRD after clipping
		N	oise Model Parameters
73	lp_fnt	_	Local parameter FNT after clipping
74	lp_nfa	$1/V/m^4$	Local parameter NFA after clipping
75	lp_nfb	$1/V/m^2$	Local parameter NFB after clipping
76	lp_nfc	V^{-1}	Local parameter NFC after clipping
77	lp_ef	-	Local parameter EF after clipping
		Paras	sitic Resistance Parameters
78	lp_rg	Ω	Local parameter RG after clipping
79	lp_rse	Ω	Local parameter RSE after clipping
80	lp_rde	Ω	Local parameter RDE after clipping
81	lp_rbulk	Ω	Local parameter RBULK after clipping
82	lp_rwell	Ω	Local parameter RWELL after clipping
83	lp_rjuns	Ω	Local parameter RJUNS after clipping
84	lp_rjund	Ω	Local parameter RJUND after clipping
			NQS Parameters
85	lp_munqs		Local parameter MUNQS after clipping

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Appendix A

Auxiliary Equations

In this Appendix, some auxiliary functions which are used in the model equations are defined.

The MINA-smoothing function:

MINA
$$(x, y, a) = \frac{1}{2} \cdot \left[x + y - \sqrt{(x - y)^2 + a} \right]$$
 (A.1)

The MAXA-smoothing function:

MAXA
$$(x, y, a) = \frac{1}{2} \cdot \left[x + y + \sqrt{(x - y)^2 + a} \right]$$
 (A.2)

The functions $\chi(y)$, its derivatives, σ_1 , and σ_2 , which are used in the explicit approximation of surface potential:

$$\chi(y) = \frac{y^2}{2 + y^2} \tag{A.3}$$

$$\chi'(y) = \frac{4y}{(2+y^2)^2} \tag{A.4}$$

$$\chi''(y) = \frac{8 - 12y^2}{(2 + y^2)^3} \tag{A.5}$$

$$\nu = a + c \tag{A.6}$$

$$\mu_1 = \frac{v^2}{\tau} + \frac{c^2}{2} - a \tag{A.7}$$

$$\sigma_1(a, c, \tau, \eta) = \frac{a \cdot \nu}{\mu_1 + (c^2/3 - a) \cdot c \cdot \nu/\mu_1} + \eta$$
(A.8)

$$\mu_2 = \frac{v^2}{\tau} + \frac{c^2}{2} - a \cdot b \tag{A.9}$$

$$\sigma_2(a, b, c, \tau, \eta) = \frac{a \cdot \nu}{\mu_2 + (c^2/3 - a \cdot b) \cdot c \cdot \nu/\mu_2} + \eta$$
(A.10)

Appendix B

Layout parameter calculation

In post-layout simulations, various PSP instance parameters should be supplied either manually or by a layout extraction tool. In this appendix, it is shown how these parameters should be calculated.

Note: These equations are *not* part of the PSP model.

B.1 Stress parameters

B.1.1 Layout effects for irregular shapes

For irregular shapes the following effective values for **SA** and **SB** are to be used (see Fig B.1).

$$\frac{1}{\mathbf{S}\mathbf{A}_{\text{eff}} + 0.5 \cdot L} = \sum_{i=1}^{n} \frac{\mathbf{S}\mathbf{W}_{i}}{W} \cdot \frac{1}{\mathbf{S}\mathbf{A}_{i} + 0.5 \cdot L}$$
(B.1)

$$\frac{1}{\mathbf{S}\mathbf{B}_{\text{eff}} + 0.5 \cdot L} = \sum_{i=1}^{n} \frac{\mathbf{S}\mathbf{W}_{i}}{W} \cdot \frac{1}{\mathbf{S}\mathbf{B}_{i} + 0.5 \cdot L}$$
(B.2)

B.2 Well proximity effect parameters

The values of the instance parameters **SCA**, **SCB** and **SCC** can be calculated from layout parameters using the equations below.

$$f_{\mathcal{A}}(u) = \frac{\mathbf{SCREF}^2}{u^2} \tag{B.3}$$

$$f_{\rm B}(u) = \frac{u}{\text{SCREF}} \cdot \exp\left(-10 \cdot \frac{u}{\text{SCREF}}\right)$$
 (B.4)

$$f_{\rm C}(u) = \frac{u}{\text{SCREF}} \cdot \exp\left(-20 \cdot \frac{u}{\text{SCREF}}\right)$$
 (B.5)

$$A_{\text{corner}} = \sum_{i=m+1}^{m+k} \left(\frac{L}{2} \cdot \int_{\text{SCX}_i + \text{SCY}_i}^{\text{SCX}_i + \text{SCY}_i + W} f_{\text{A}}(u) \, du \right) + \sum_{i=n+1}^{n+k} \left(\frac{W}{2} \cdot \int_{\text{SCX}_i + \text{SCY}_i}^{\text{SCX}_i + \text{SCY}_i + L} f_{\text{A}}(u) \, du \right)$$
(B.6)

$$B_{\text{corner}} = \sum_{i=m+1}^{m+k} \left(\frac{L}{2} \cdot \int_{\text{SCX}_i + \text{SCY}_i}^{\text{SCX}_i + \text{SCY}_i + W} f_{\text{B}}(u) \, du \right) + \sum_{i=n+1}^{n+k} \left(\frac{W}{2} \cdot \int_{\text{SCX}_i + \text{SCY}_i}^{\text{SCX}_i + \text{SCY}_i + L} f_{\text{B}}(u) \, du \right)$$
(B.7)

$$C_{\text{corner}} = \sum_{i=m+1}^{m+k} \left(\frac{L}{2} \cdot \int_{\text{SCX}_i + \text{SCY}_i}^{\text{SCX}_i + \text{SCY}_i + W} f_{\text{C}}(u) \, du \right) + \sum_{i=n+1}^{n+k} \left(\frac{W}{2} \cdot \int_{\text{SCX}_i + \text{SCY}_i}^{\text{SCX}_i + \text{SCY}_i + L} f_{\text{C}}(u) \, du \right)$$
(B.8)

$$\mathbf{SCA} = \frac{1}{W \cdot L} \cdot \left[\sum_{i=1}^{n} \left(W_i \cdot \int_{\mathrm{SC}_i}^{\mathrm{SC}_i + L} f_{\mathrm{A}}(u) \, \mathrm{d}u \right) + \sum_{i=n+1}^{n+m} \left(L_i \cdot \int_{\mathrm{SC}_i}^{\mathrm{SC}_i + W} f_{\mathrm{A}}(u) \, \mathrm{d}u \right) + A_{\mathrm{corner}} \right]$$
(B.9)

$$\mathbf{SCB} = \frac{1}{W \cdot L} \cdot \left[\sum_{i=1}^{n} \left(W_i \cdot \int_{\mathrm{SC}_i}^{\mathrm{SC}_i + L} f_{\mathrm{B}}(u) \, \mathrm{d}u \right) + \sum_{i=n+1}^{n+m} \left(L_i \cdot \int_{\mathrm{SC}_i}^{\mathrm{SC}_i + W} f_{\mathrm{B}}(u) \, \mathrm{d}u \right) + B_{\mathrm{corner}} \right]$$
(B.10)

$$\mathbf{SCC} = \frac{1}{W \cdot L} \cdot \left[\sum_{i=1}^{n} \left(W_i \cdot \int_{\mathrm{SC}_i}^{\mathrm{SC}_i + L} f_{\mathrm{C}}(u) \, \mathrm{d}u \right) + \sum_{i=n+1}^{n+m} \left(L_i \cdot \int_{\mathrm{SC}_i}^{\mathrm{SC}_i + W} f_{\mathrm{C}}(u) \, \mathrm{d}u \right) + C_{\mathrm{corner}} \right]$$
(B.11)

Here, m and n are the number of projections of the well edge along the length and width of the devices, respectively. Moreover, k is the number of corners selected to account for the 'corner' effects.

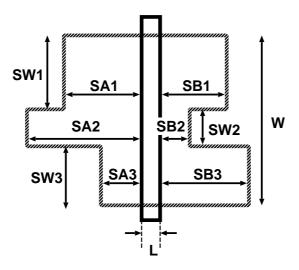


Figure B.1: A typical layout of MOS devices with more instance parameters $(SW_i, SA_i \text{ and } SB_i)$ in addition to the traditional L and W.

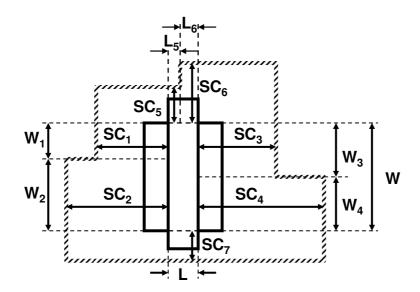


Figure B.2: A typical layout of MOS devices with WPE instance parameters

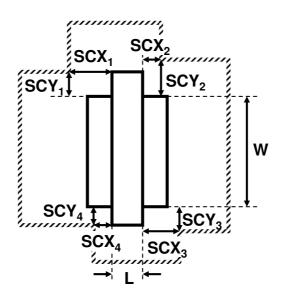


Figure B.3: A layout of MOS devices for corner terms calculation